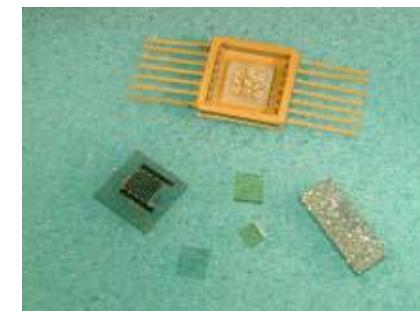
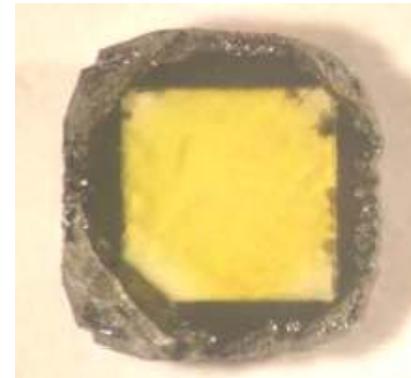


Diamond activities at CEA-list



Philippe.bergonzo@cea.fr, Diamond Sensor Laboratory, CEA-LIST, Saclay

Where ?

CEA/Saclay, near Paris

LIST (Research and
Technology Direction)

Team members :

M. Nesladek,

D. Tromson,

C. Mer,

N. Tranchant,

J.C. Arnault,

S. Saada,

H. Hamrita,

S. Allard,

C. Gesset

Collaborations

CEA/DRECAM (Saclay)

UCL (London)

WSI (Munich)

AIST (Tsukuba)

CNRS-NEEL (Grenoble)

Technion

TRINITI (Moscow)

GEMaC-CNRS (Meudon)

ESRF & SOLEIL

Industriel partners

COGEMA

SGN (AREVA)

ALSTOM

EDF

Diamond synthesis

Plasma CVD → GROWTH

- Precursors : $\text{CH}_4 + \text{H}_2$ (+ $\text{O}_2, \text{Ar}, \text{CO}_2$; etc...)
- Grain growth
- Temperatures : **600- 900°C**



→ Various material types :

- **Homoepitaxy → Single crystals**

μ : $4000\text{cm}^2\text{V}^{-1}\text{s}^{-1}$

but substrates 3x3mm typ 300€



- **Heteroépitaxy → polycrystalline**

- substrates Si, Verre, Quartz, W, Ti etc.

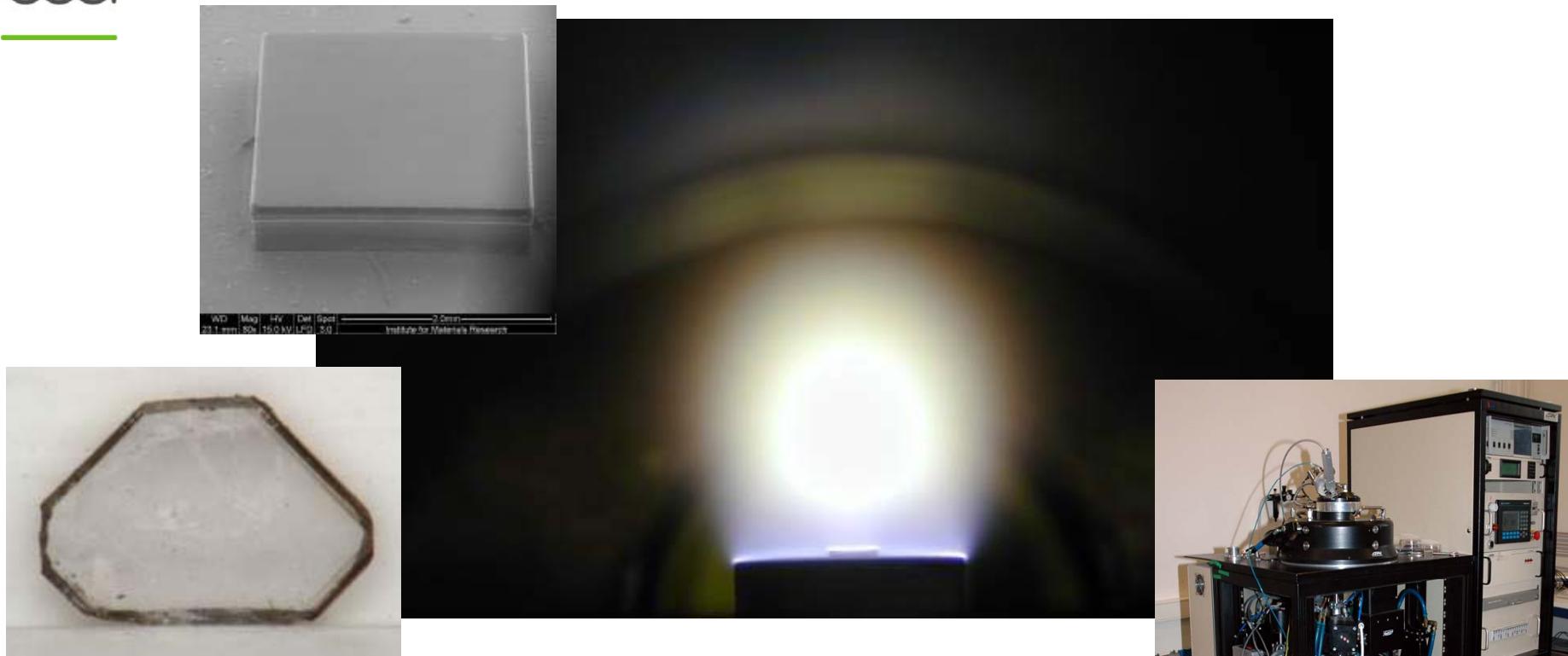
- Highly resistive **$10^{12} - 10^{14} \Omega\cdot\text{cm}$**



- **Nanocrystalline materials:** NCD, UNCD

coatings, bio interfaces etc



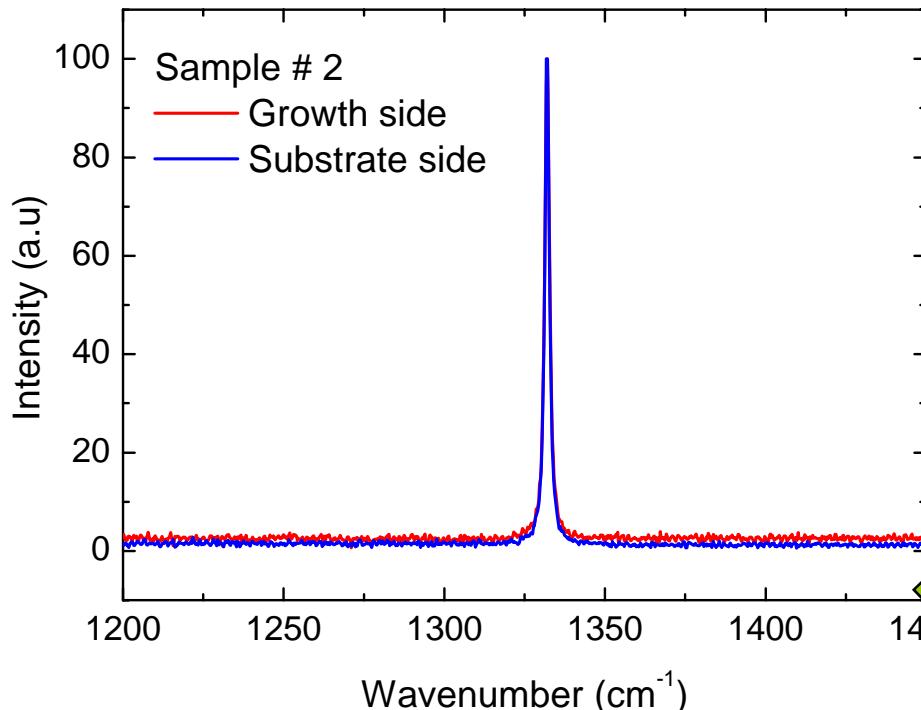


Carbon from methane : CH₄

- 7 growth kits at Saclay: from 2 to 4 inches
- Microwave plasma CVD

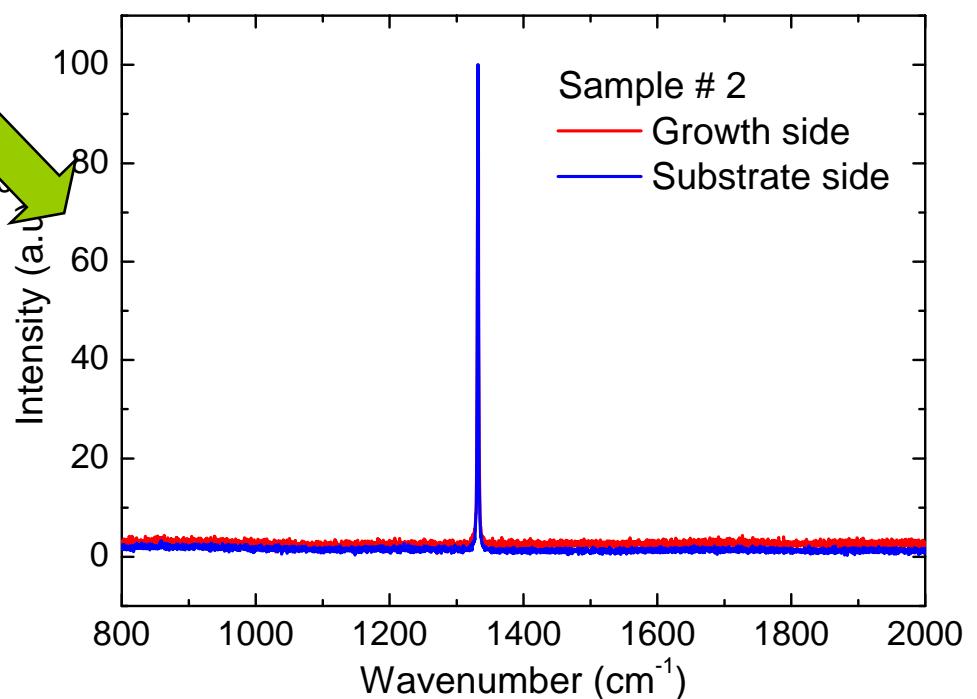


Raman characterization



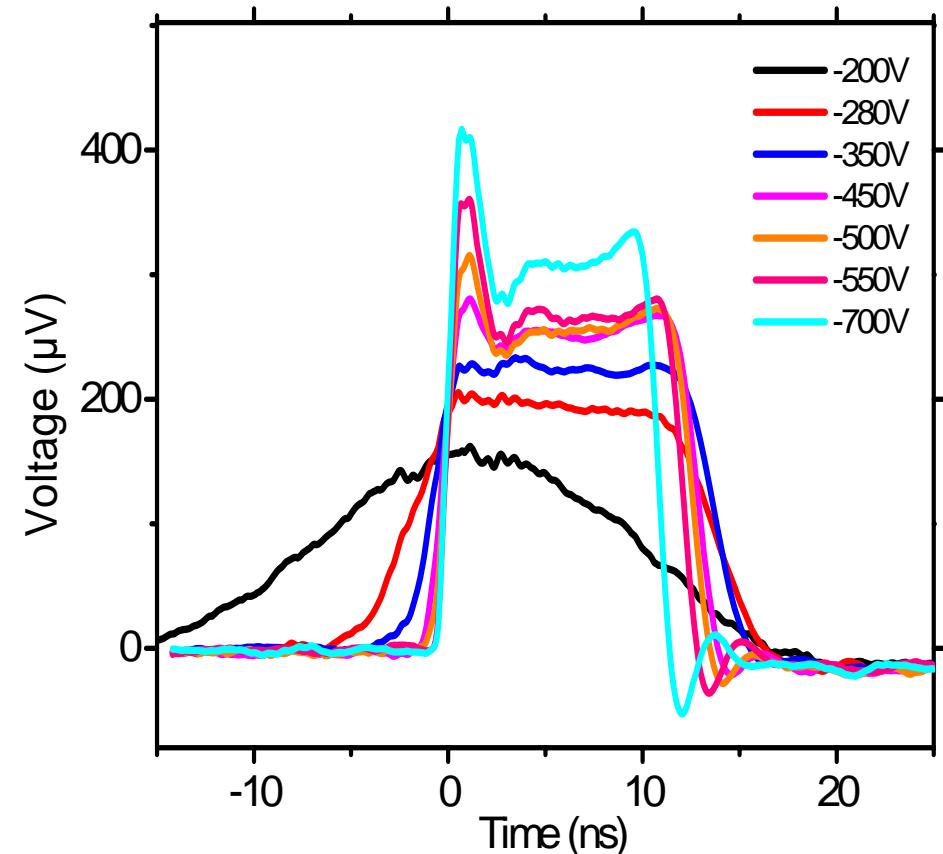
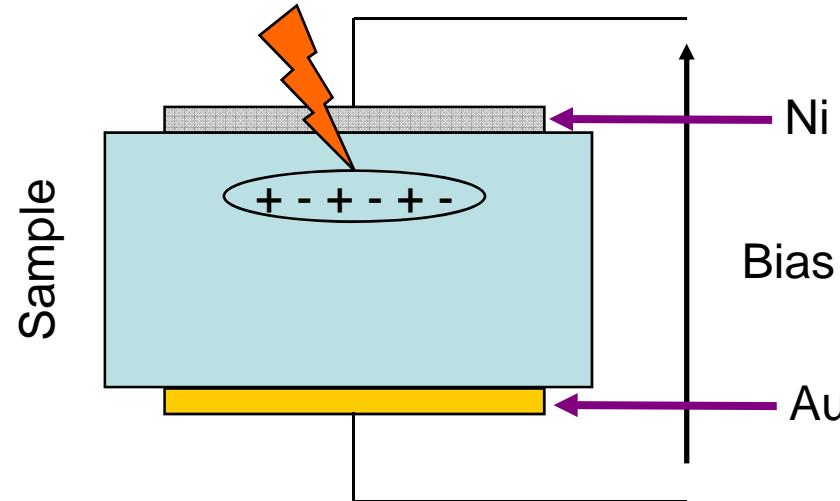
Side	Position	FWHM
Growth	1331.98	1.47
Substrate	1332.03	1.70

- Good crystalline quality
- No graphitic inclusion

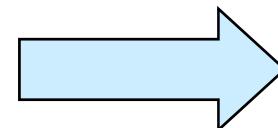


Time Of Flight (TOF) measurements

Alpha particles from
an ^{241}Am source



$$\mu_{(\vec{E})} = \frac{\mu_0}{1 + \frac{\mu_0 E}{v_s}}$$



Least squared fit

μ_0 , mobility at 0 field
 v_s , saturation velocity

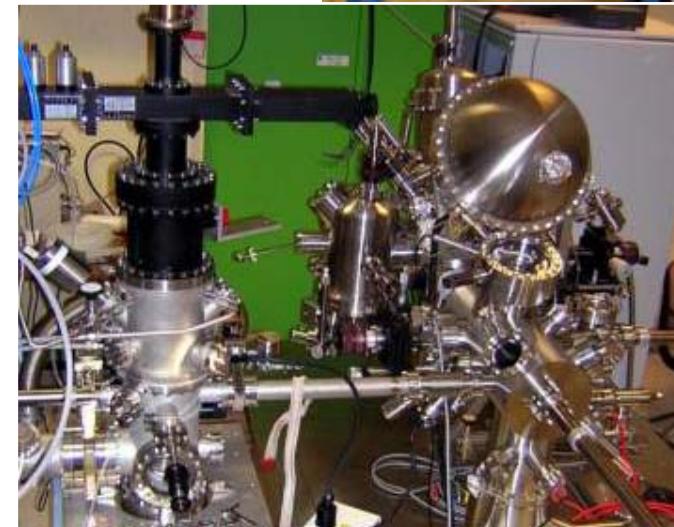
Time Of Flight (TOF) measurements

	Sample # 1	Sample # 2
μ_0^{h+} (cm ² .V ⁻¹ .s ⁻¹)	2450	3200
v_s^{h+} (V.cm ⁻¹)	2,1.10 ⁶	3,5.10 ⁶
μ_0^{e-} (cm ² .V ⁻¹ .s ⁻¹)	1850	2500
V_s^{e-} (V.cm ⁻¹)	2,7.10 ⁶	1,9.10 ⁶

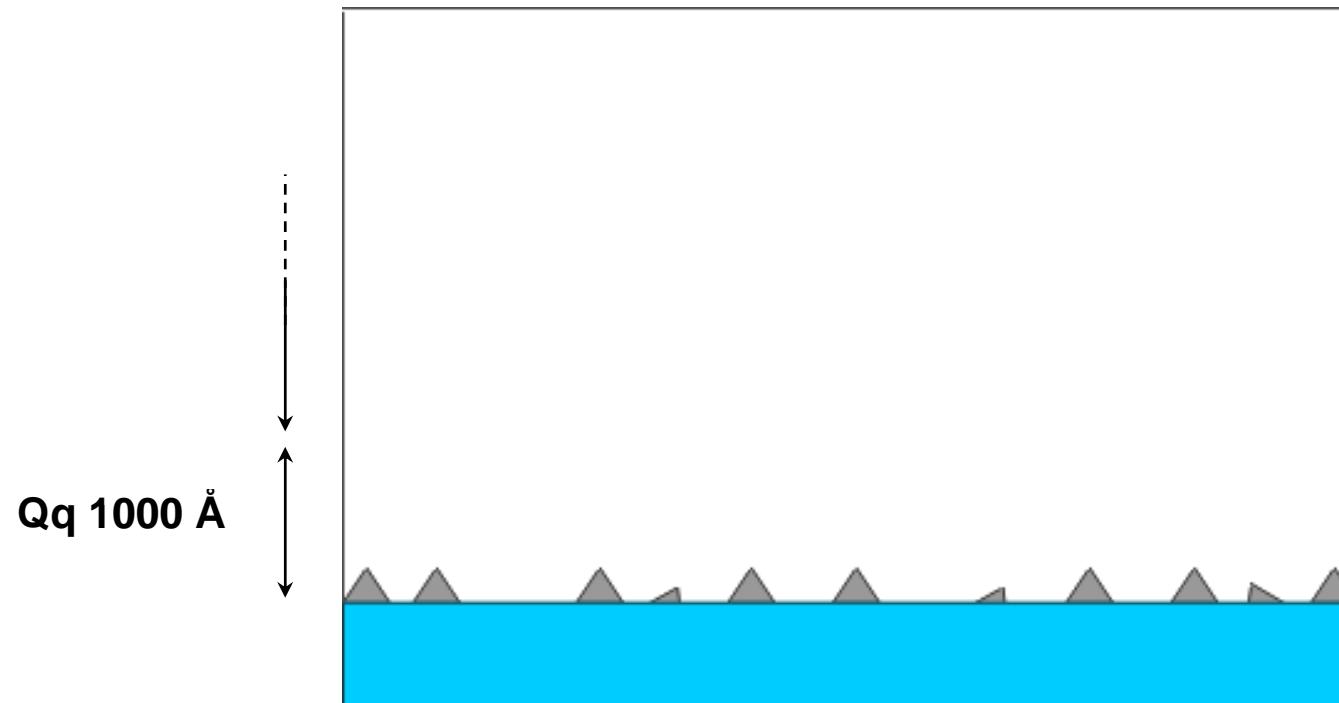
Hole mobility is higher than electron mobility for both
High mobilities values performed → low defect concentration

Growth kits Exclusively microwave CVD

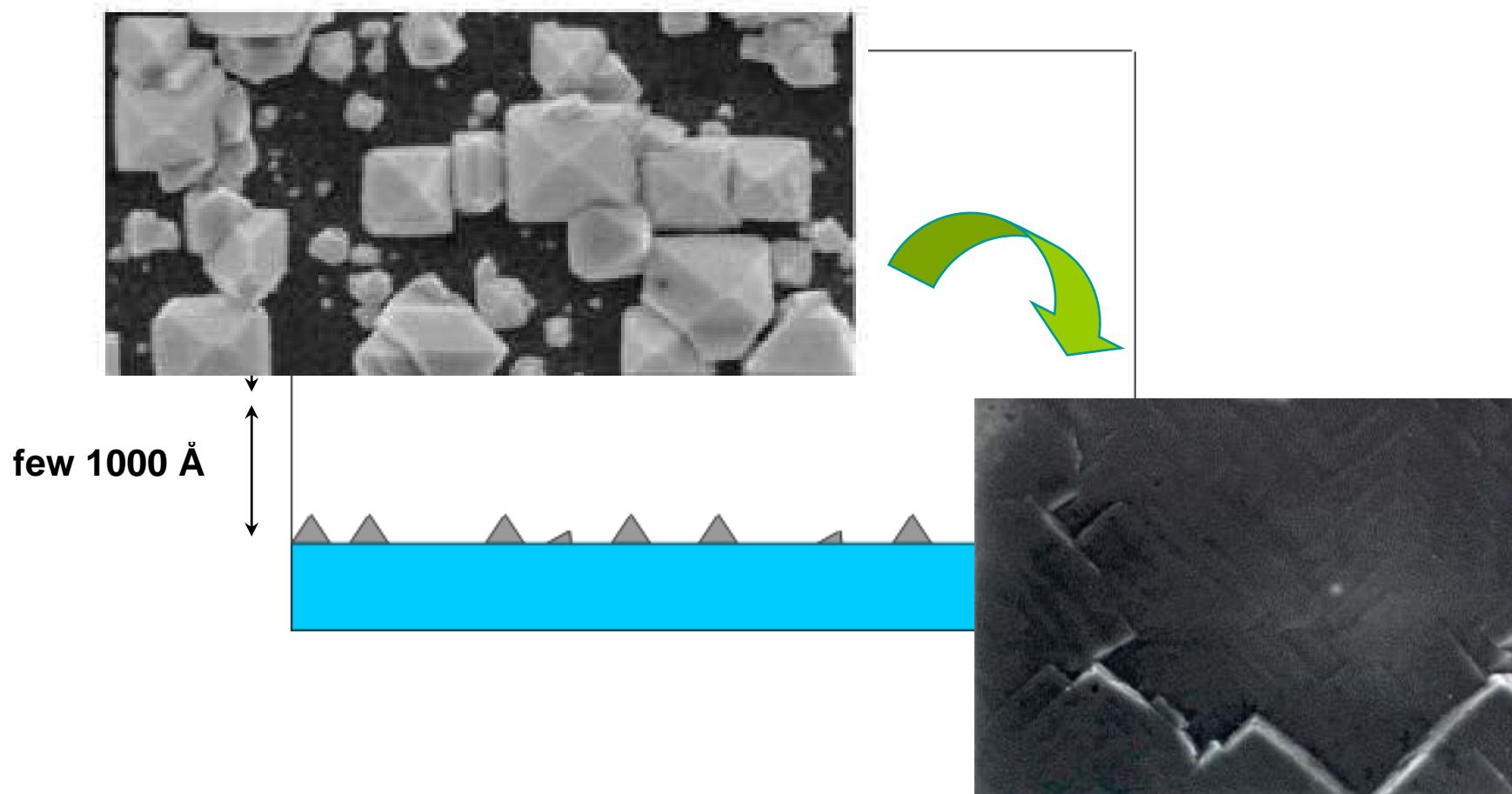
- 3 for intrinsic diamond growth,
(inc one SEKI AX5400)
- 1 dedicated to boron doping,
- 1 dedicated to phosphorous doping,
- 1 large area SEKI 6500 (.. → 3 to 4 inch)
- 1 dedicated to heteroepitaxy (Ir, etc)



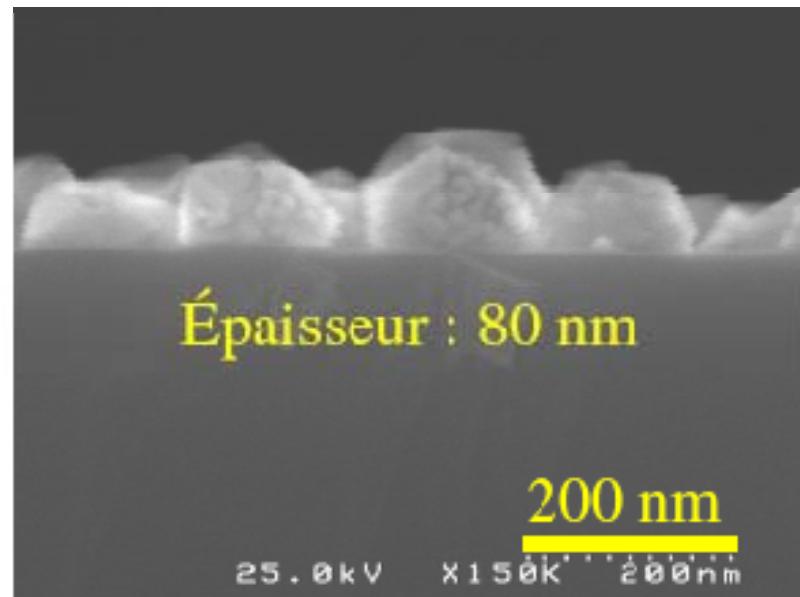
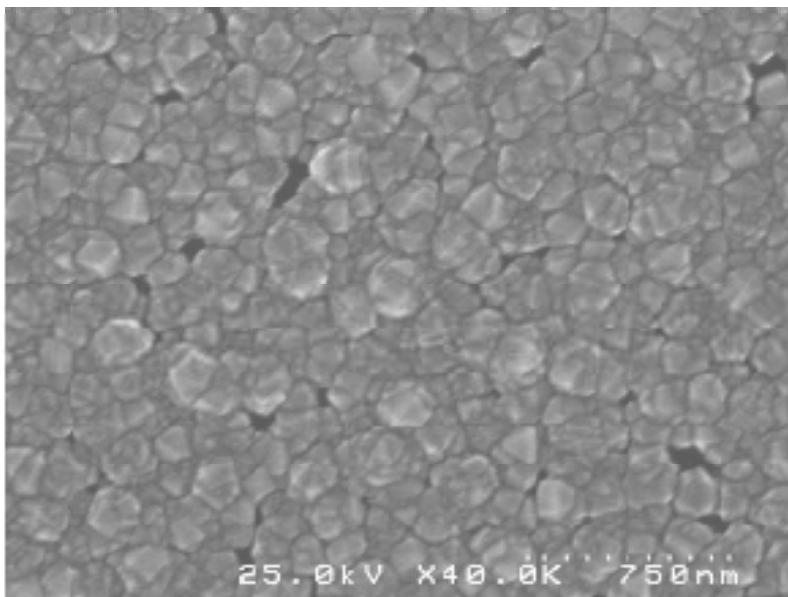
Polycrystalline growth



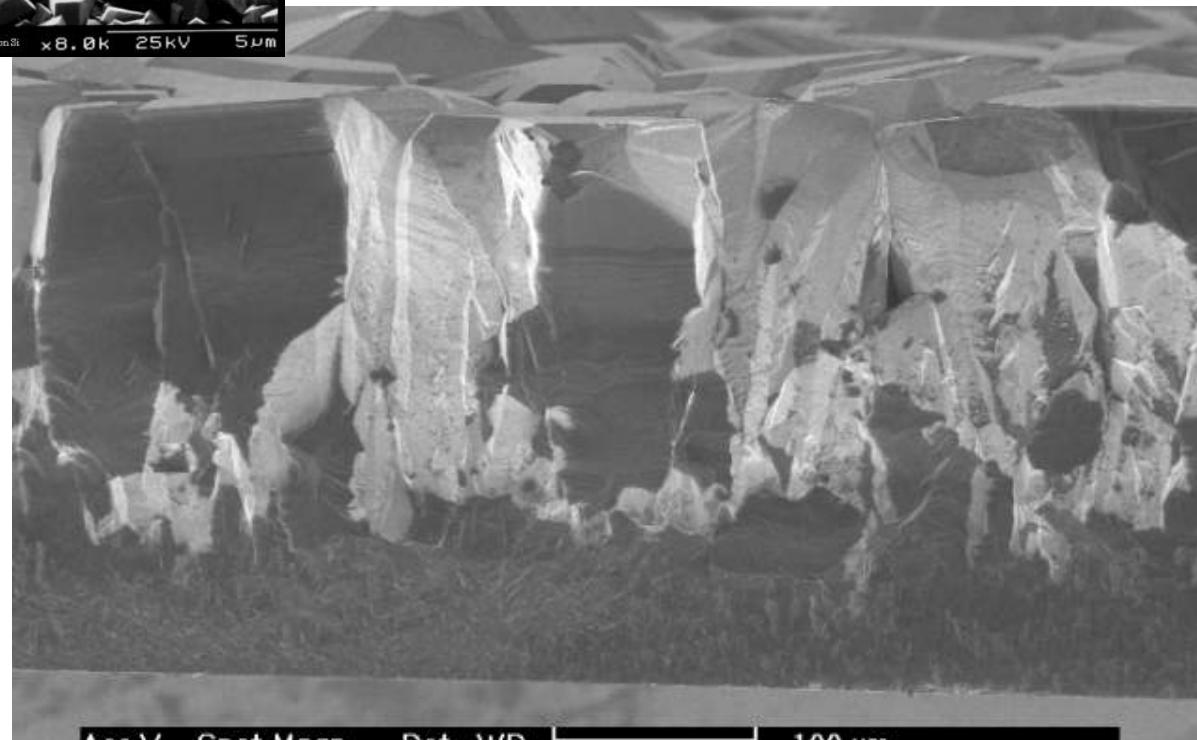
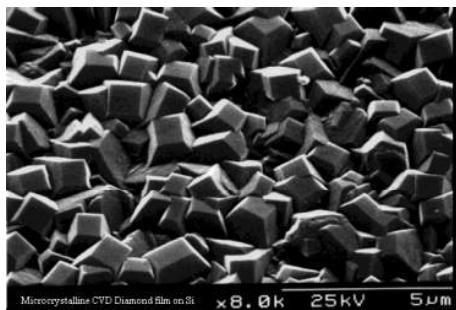
Polycrystalline growth



From very thin layers



To thick films...



Non-uniformity of the sensitivity

X-ray microbeam :

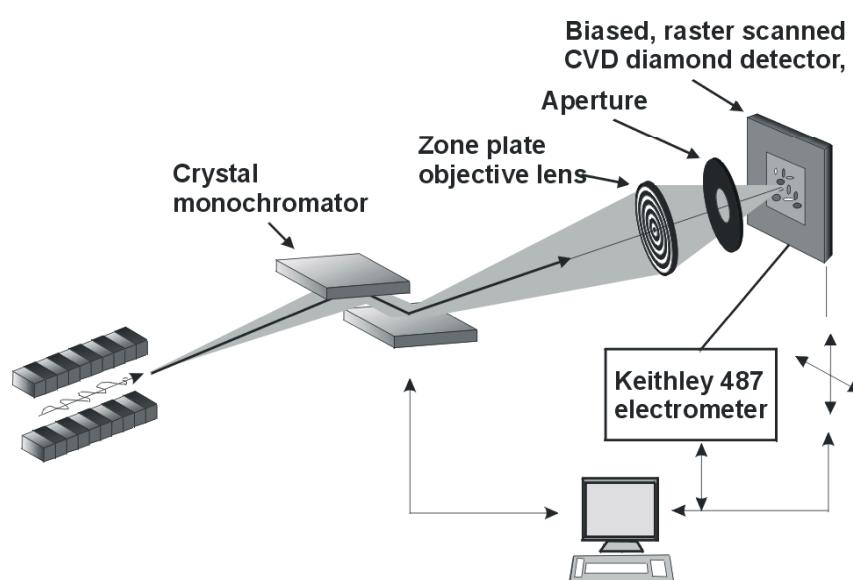
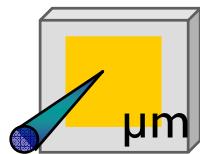
5 keV (Volume)

att. length : 150 μm (1/e)

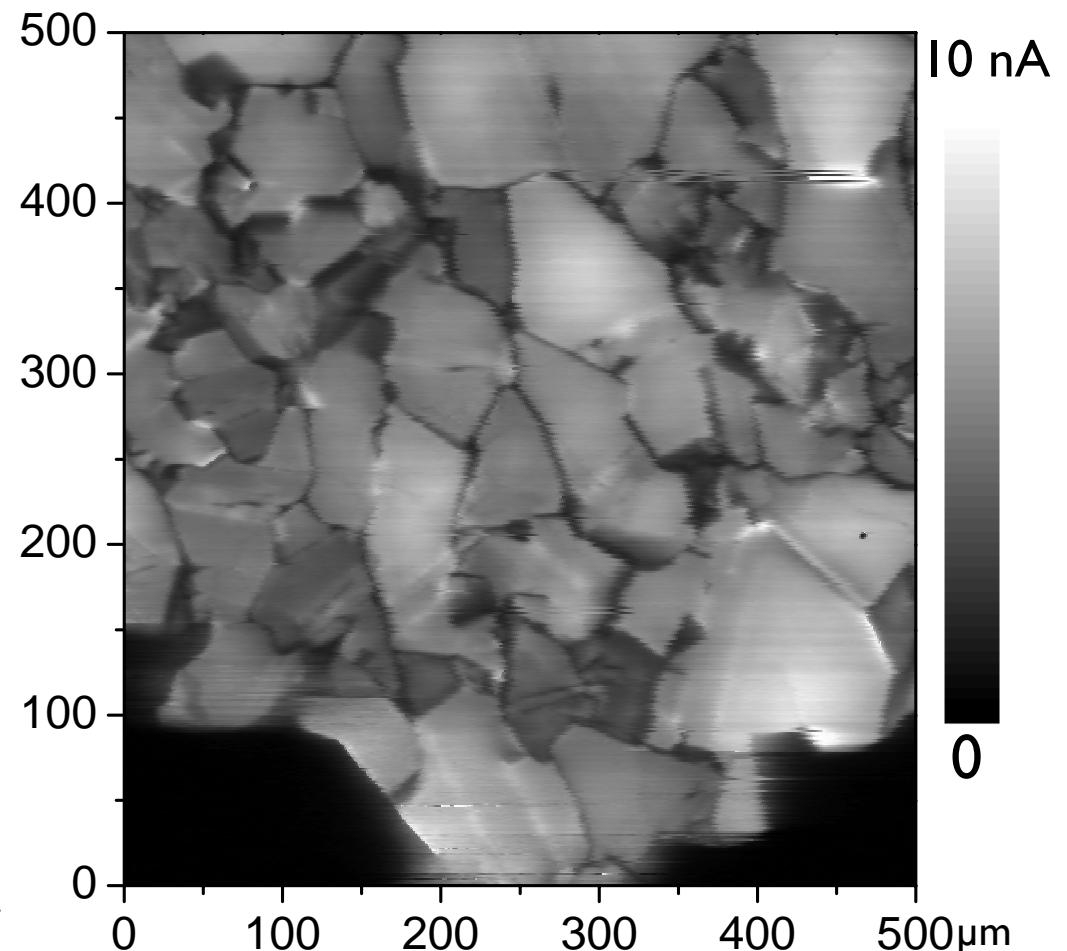
$\approx 1.4 \cdot 10^9 \text{ ph/s}$

beam spot < 1 μm

resolution : 1 μm



→ Comm. Avail. 300 μm Det. Grade

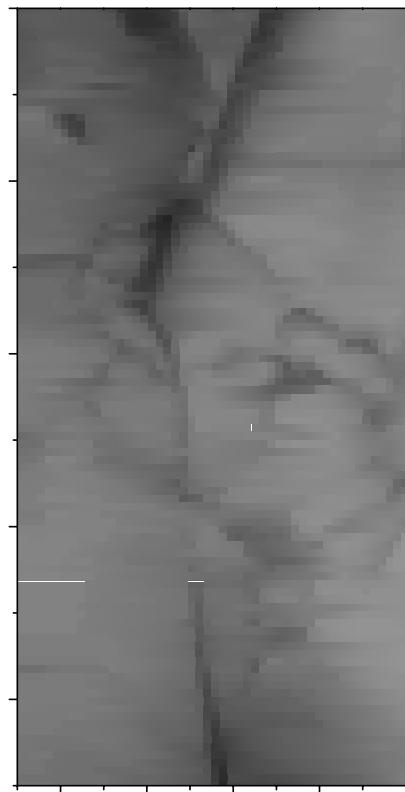


Strong Non-uniformities observed
→ Detrimental for beam metrology

Electric Field Influence

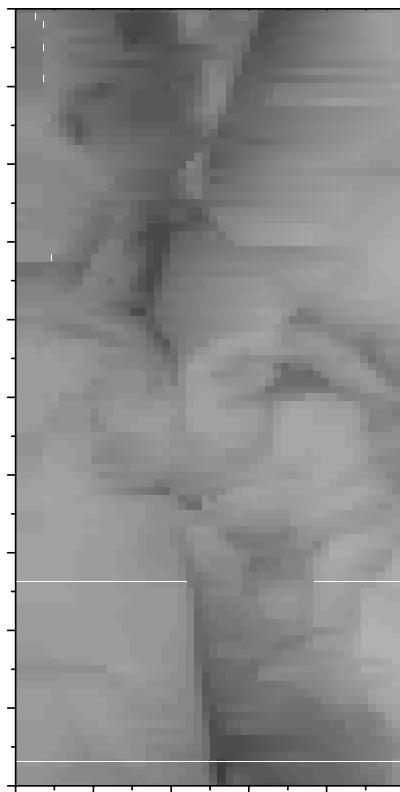
100 V

3.3 kV/cm



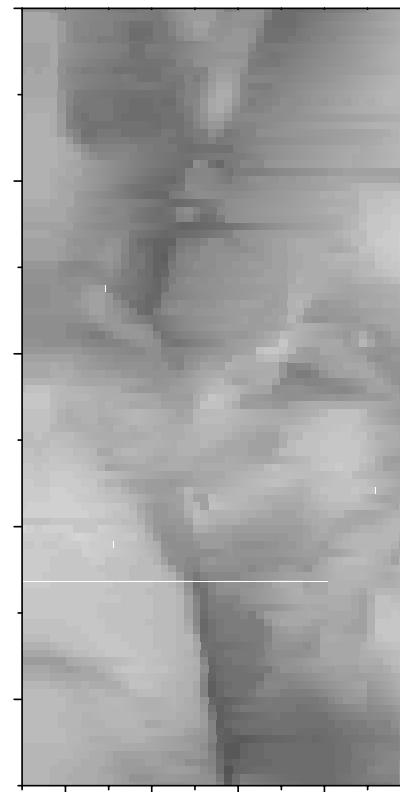
200 V

6.6 kV/cm



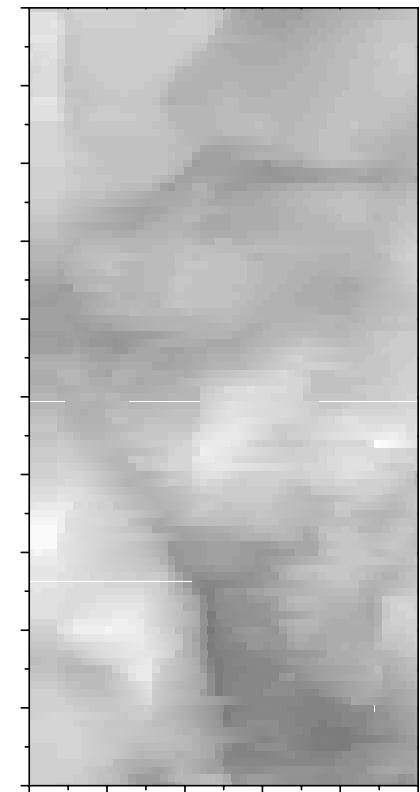
400 V

13.3 kV/cm



800 V

26.6 kV/cm

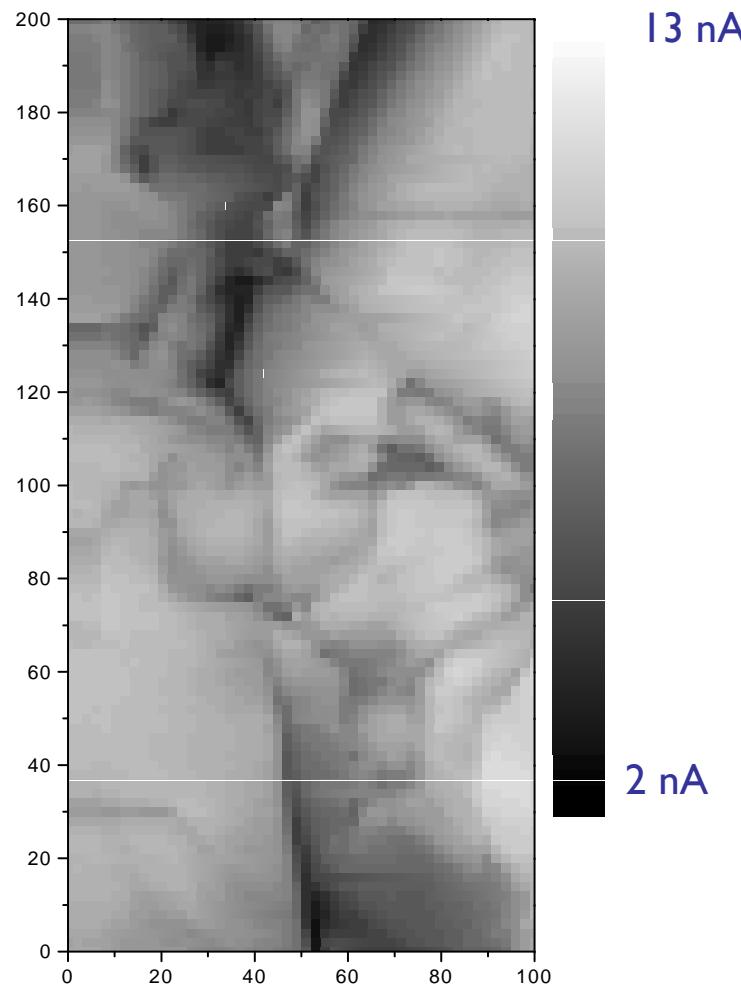


(Identical grey scale : I to 28 nA – log)

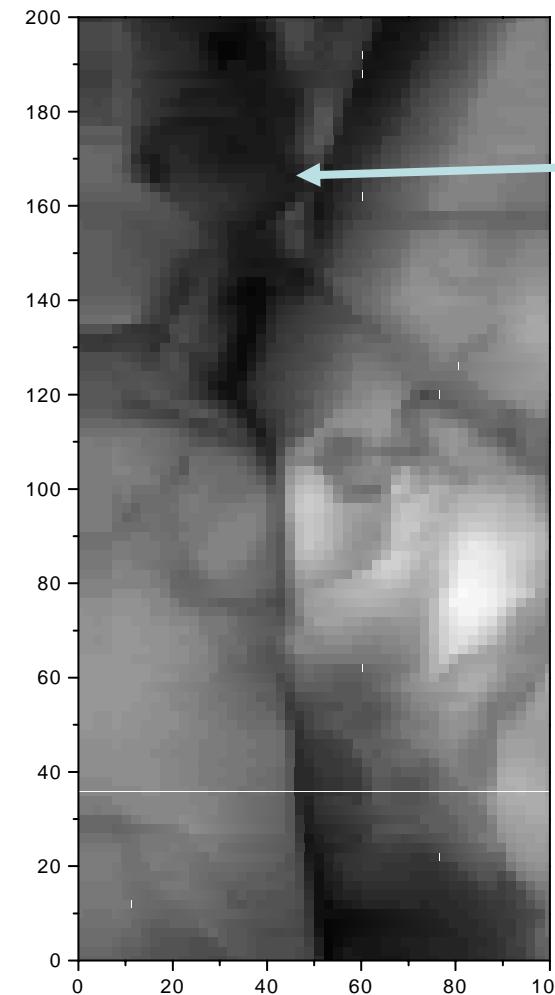
→ Velocity of saturation can be reached locally (likely from 10 kV/cm)

Evidence of charge build-up

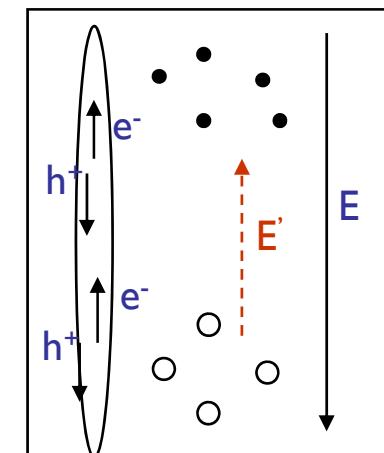
At 200V



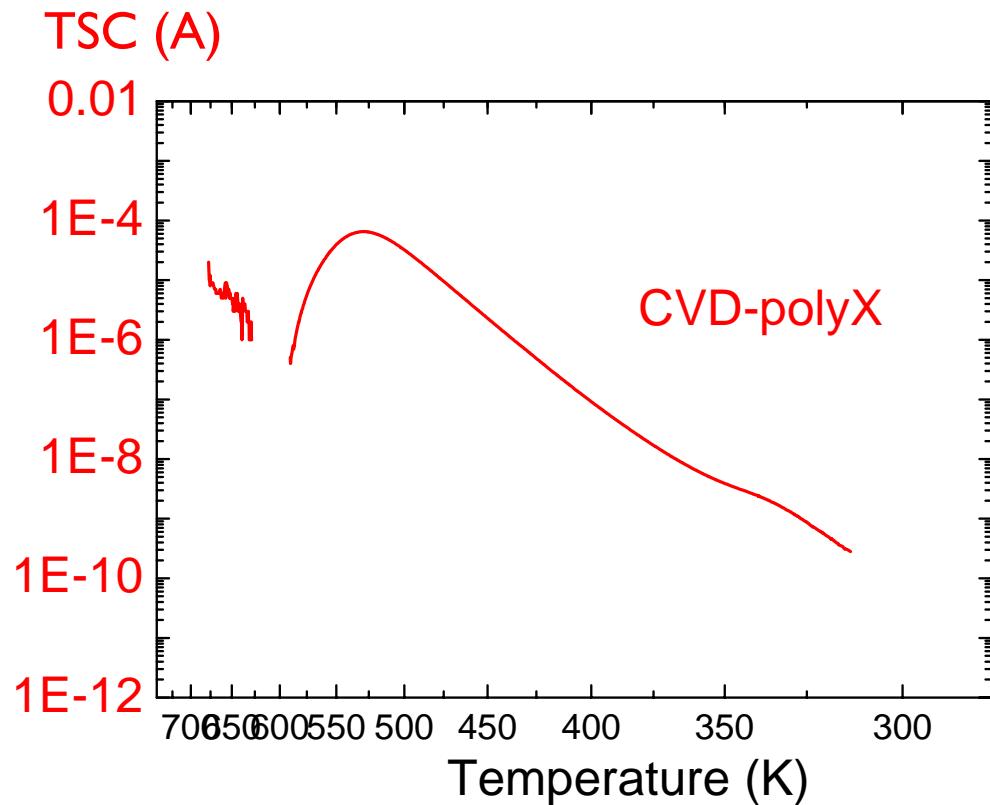
At 200V, after one scan at 800V



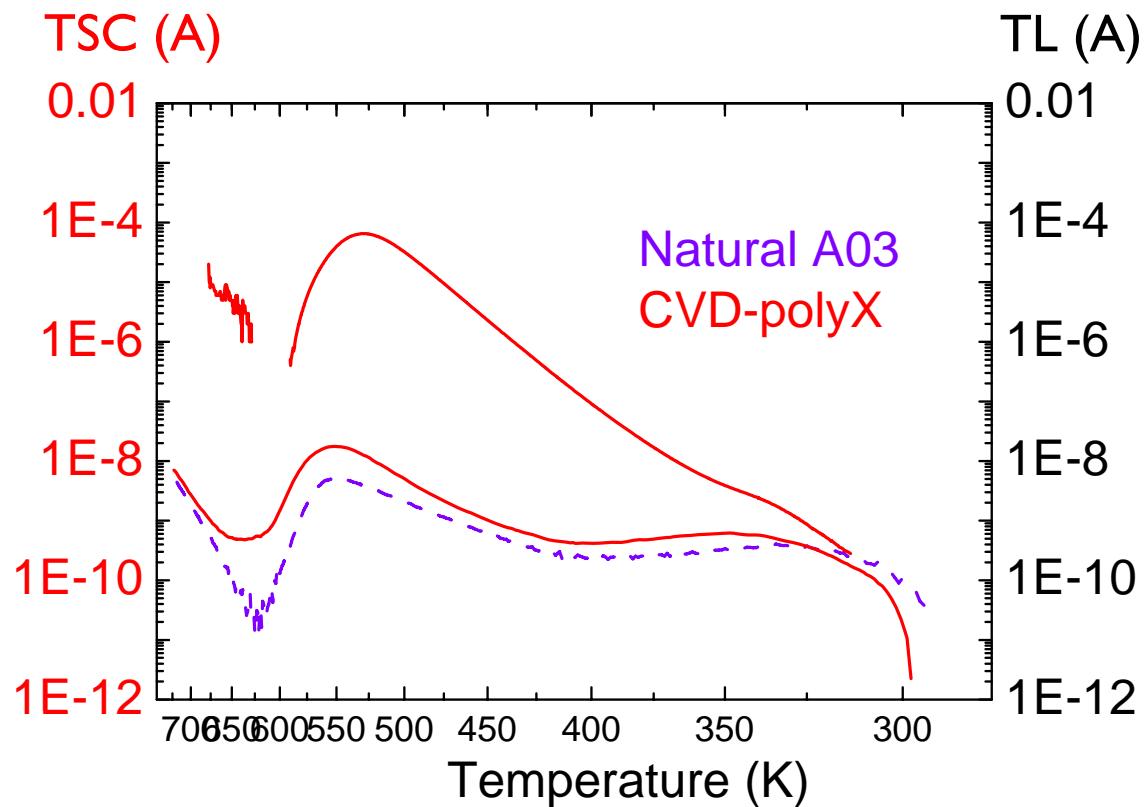
Darker area :
Sensitivity is lower



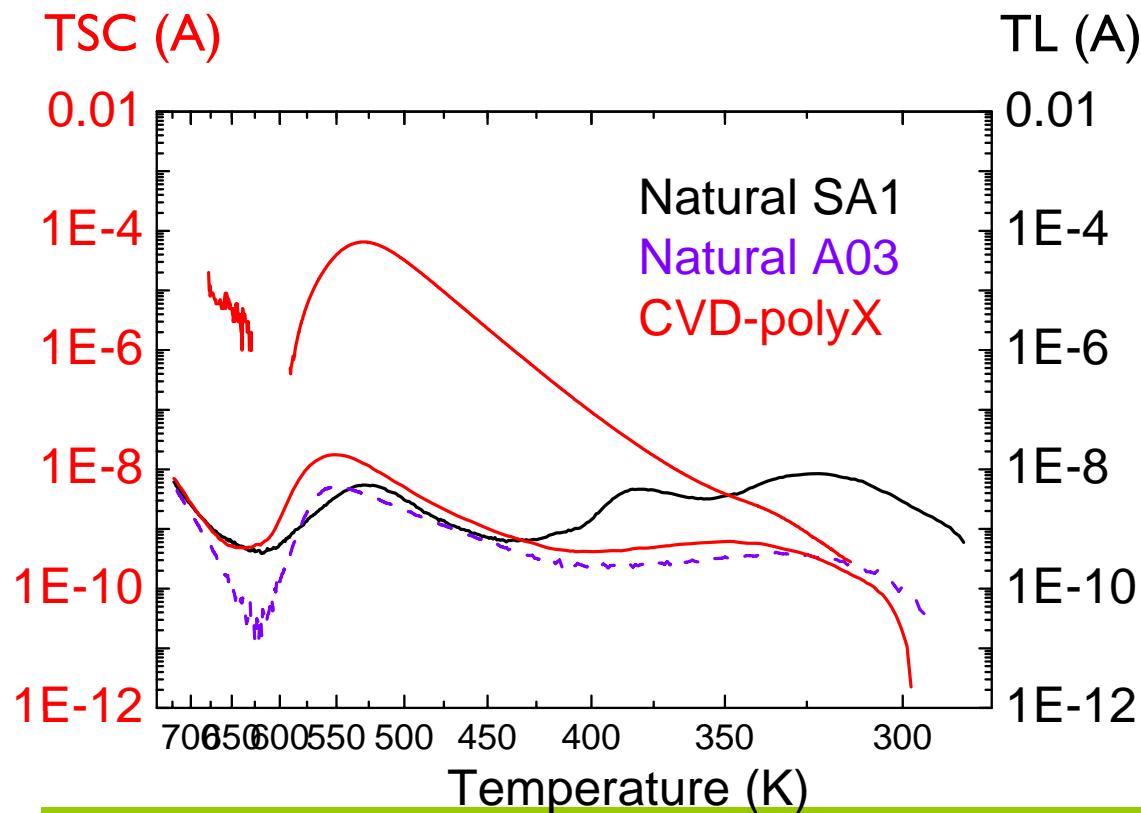
- ☞ CVD materials, as well as high quality IIa type diamonds inherently exhibit defect levels



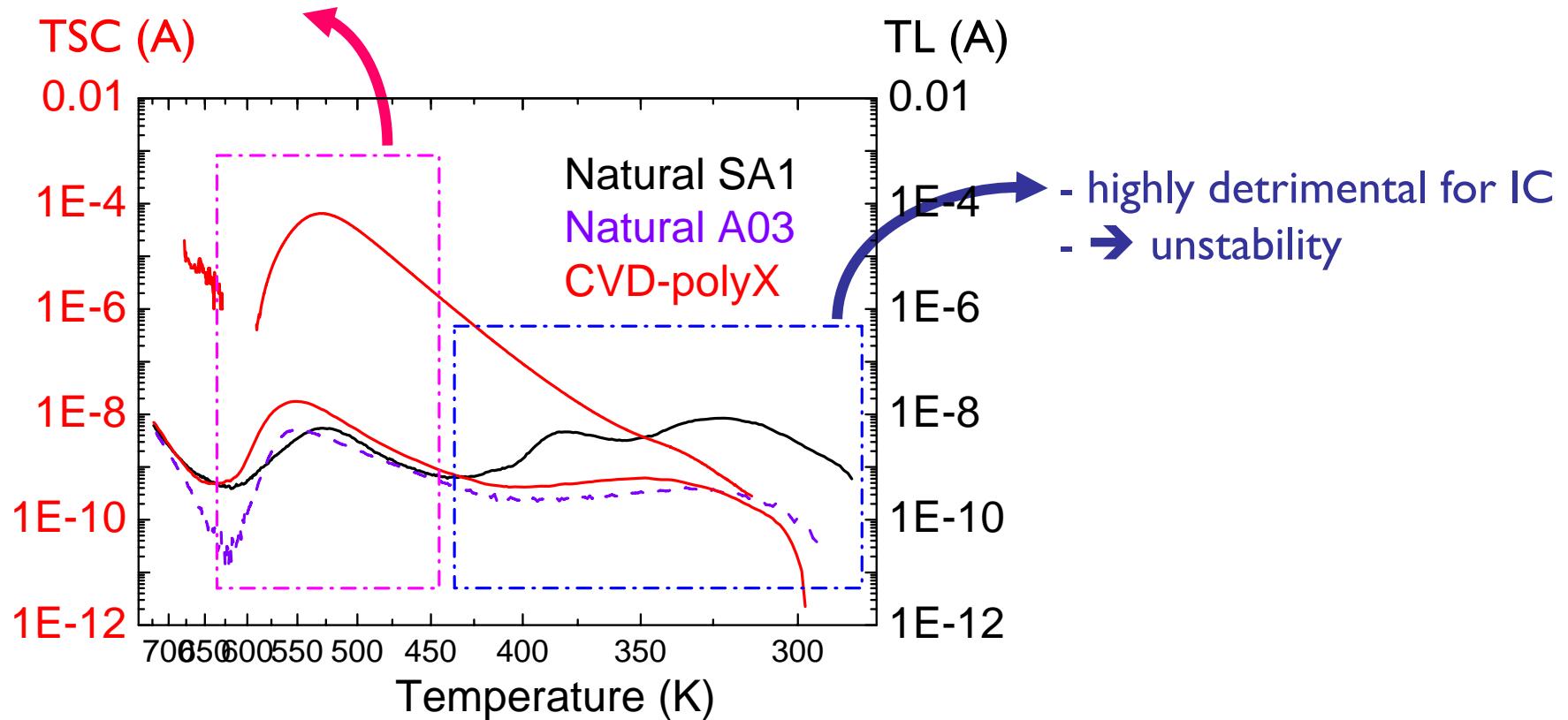
- ☞ CVD materials, as well as high quality IIa type diamonds inherently exhibit defect levels



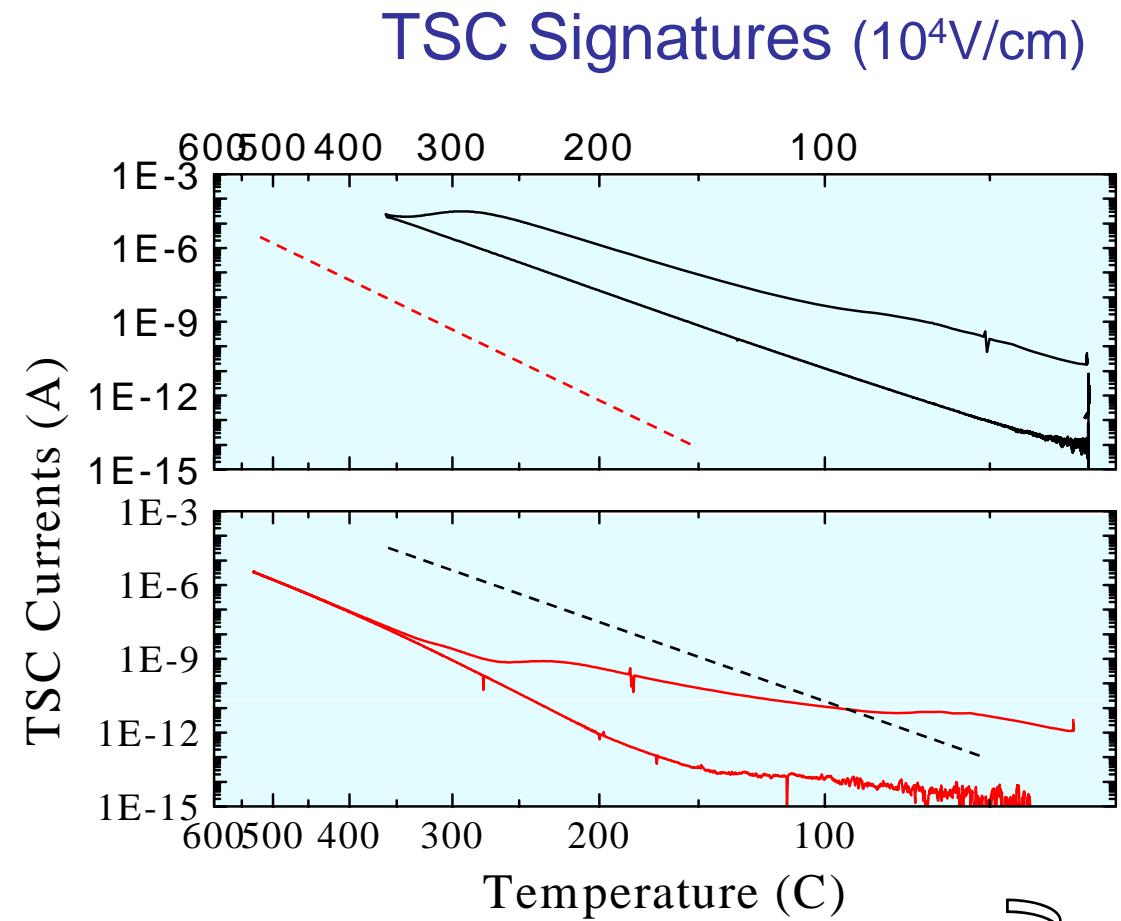
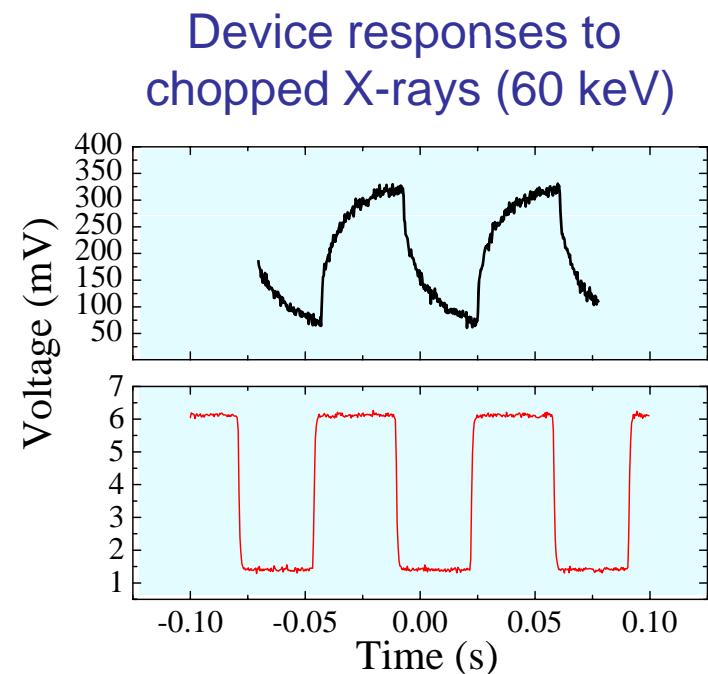
- ☞ CVD materials, as well as high quality IIa type diamonds inherently exhibit defect levels



- ☞ CVD materials, as well as high quality IIa type diamonds inherently exhibit defect levels
 - of interest for TL dosimetry
 - stable at RT



Impurities : effect on the response time

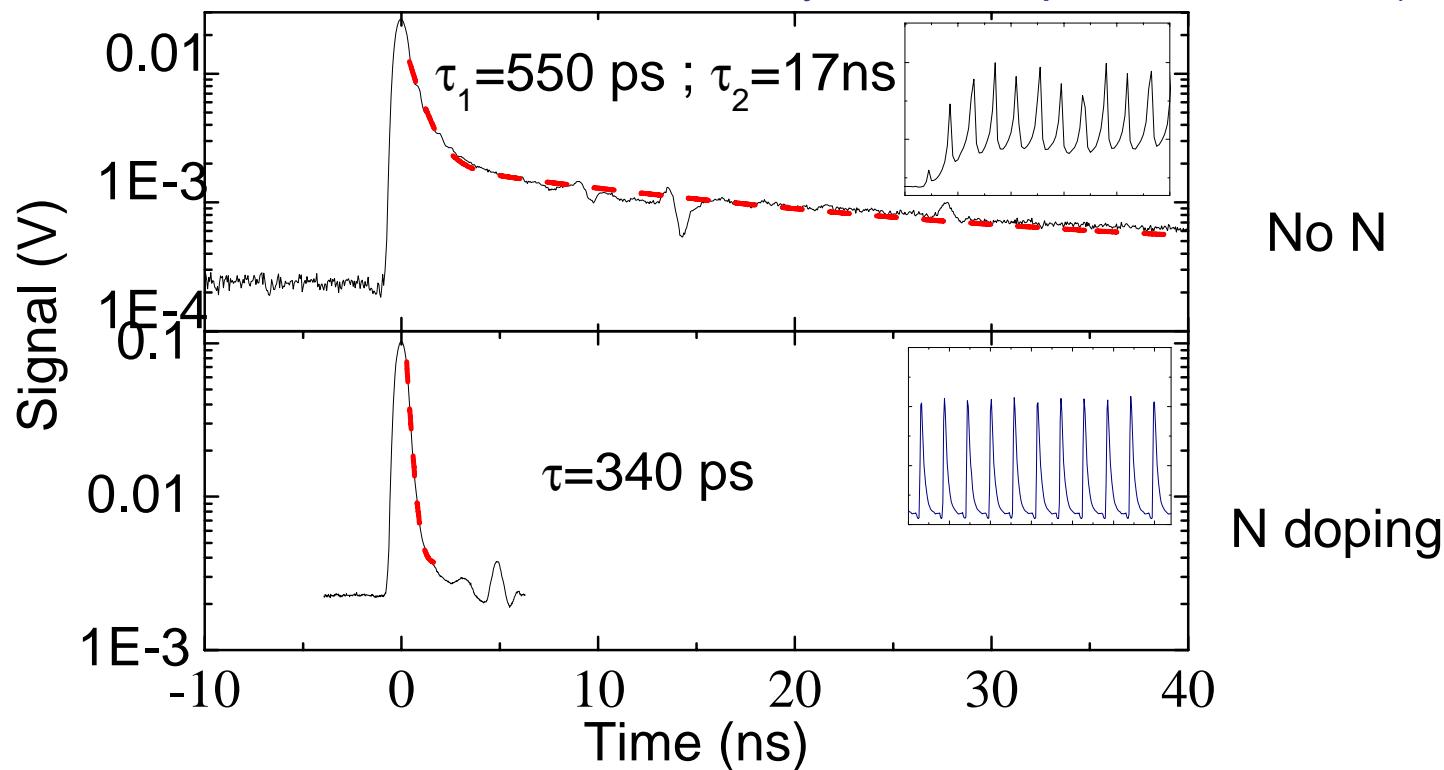


Defects and response time

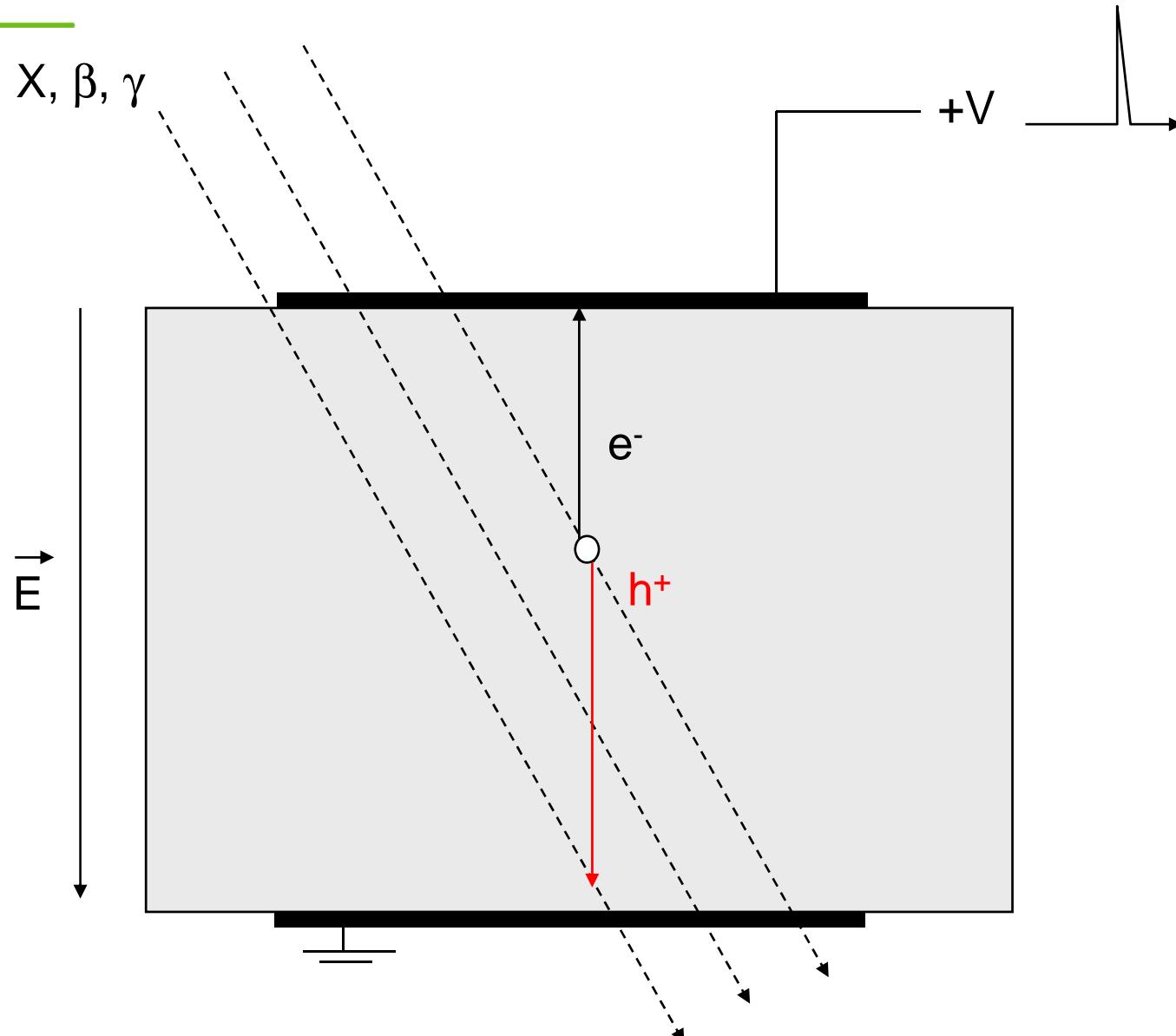
Defects strongly influence the signal temporal decay :

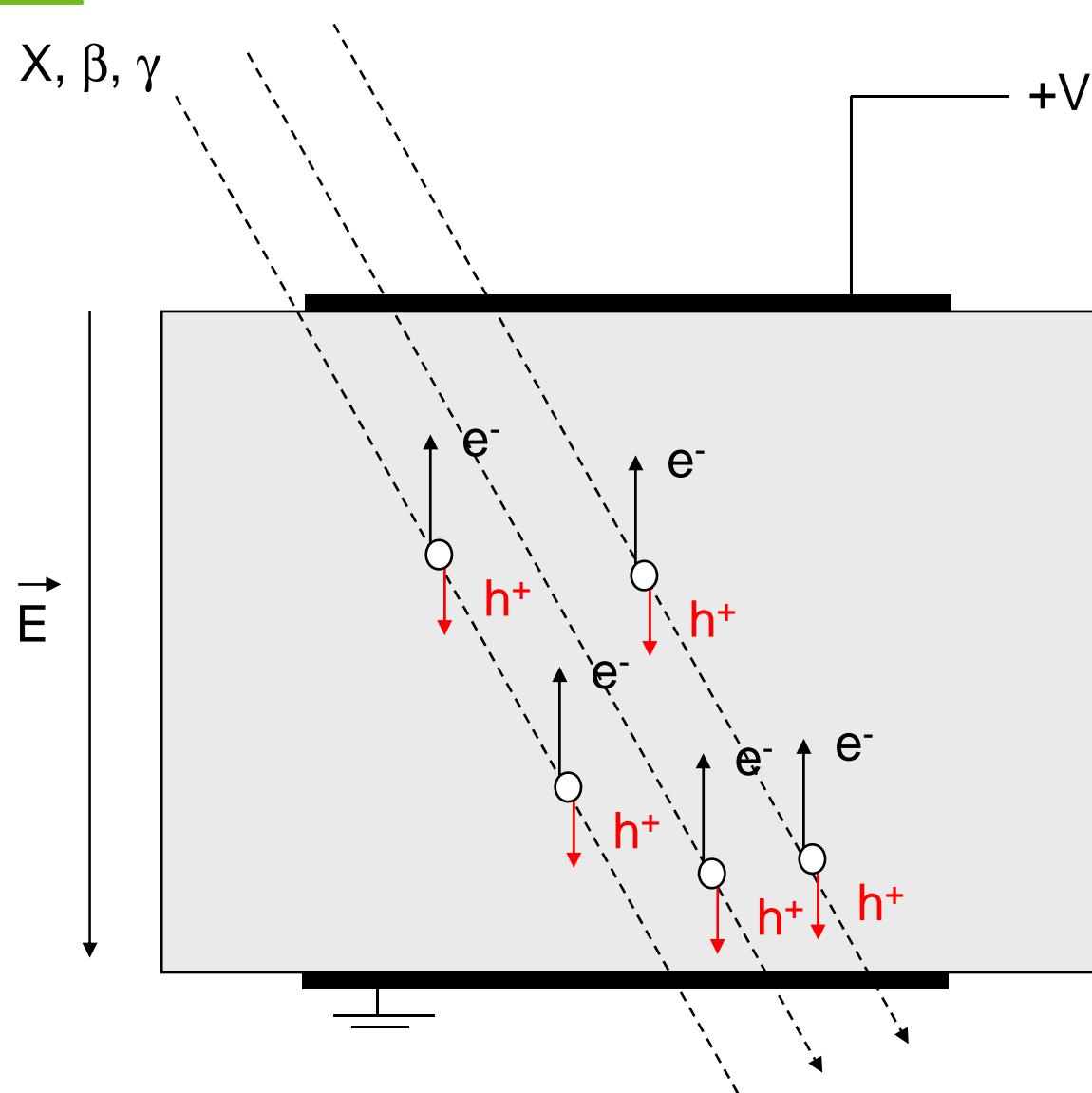
If Nitrogen is added to the gas phase during growth

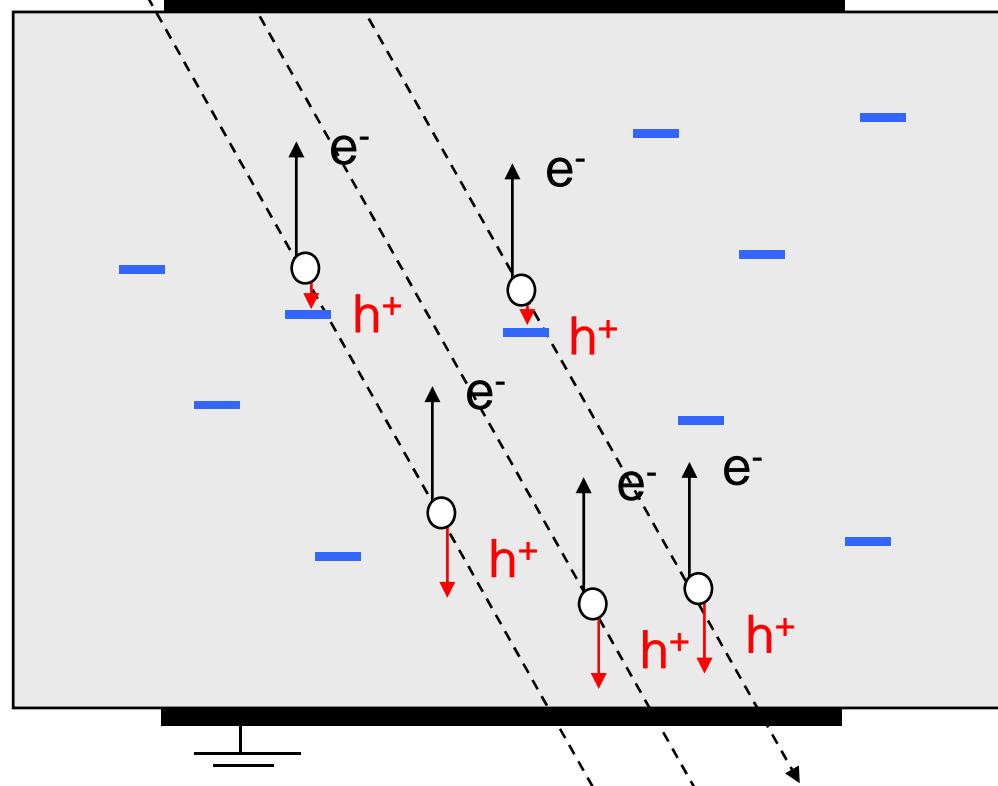
2 CVD polycrystalline diamonds,
Synchrotron pulses at LURE (≈ 1 keV),



Basics of signal formation

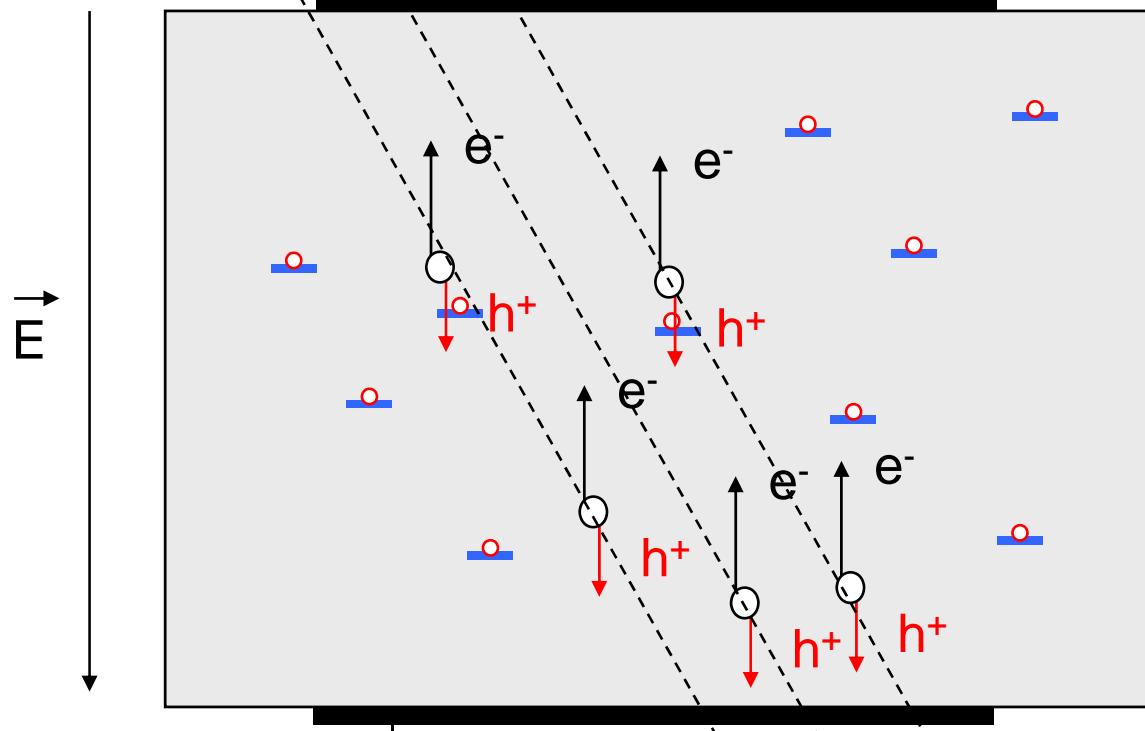




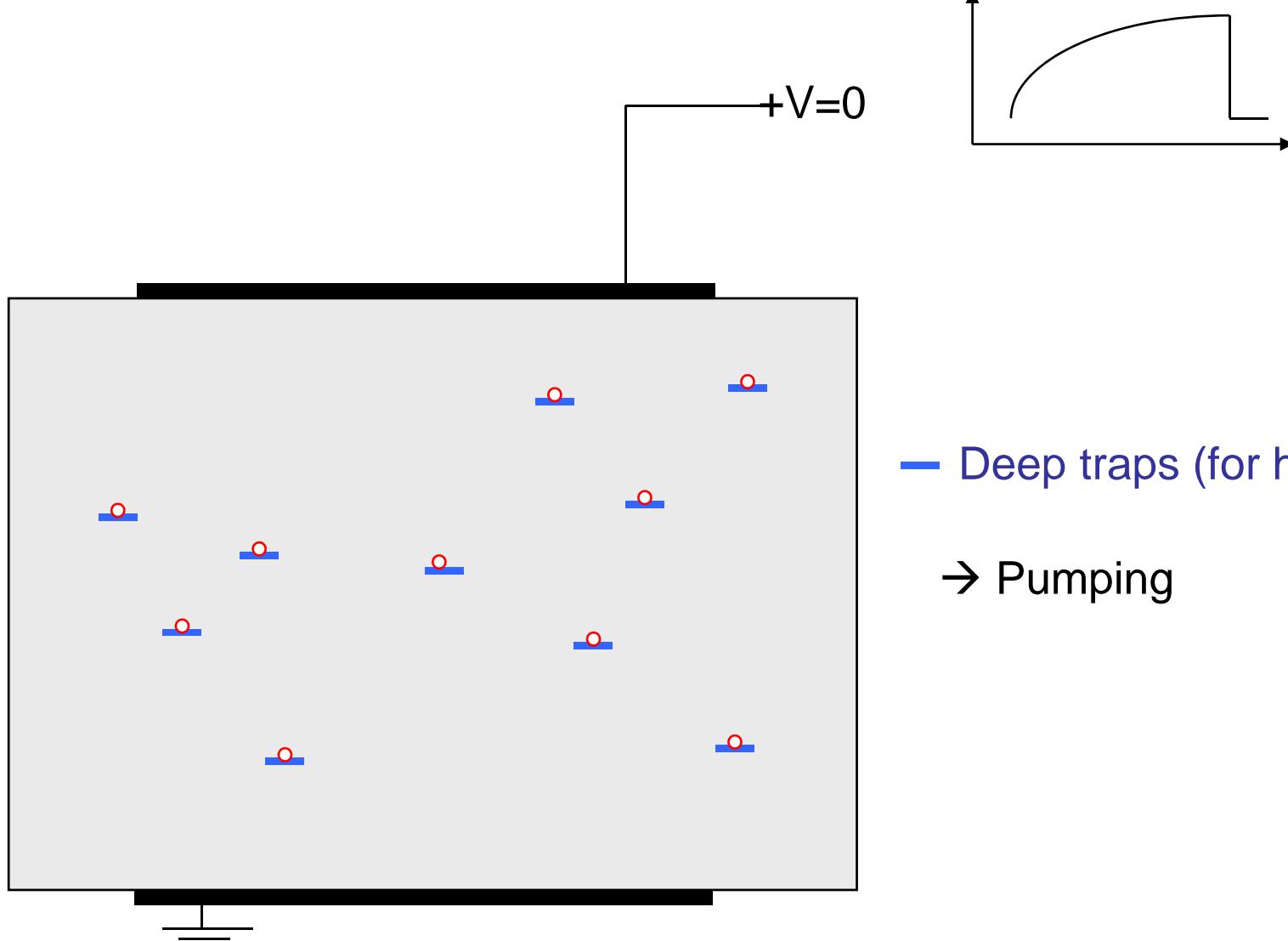
X, β, γ $\downarrow E$ 

— Deep traps (for holes)

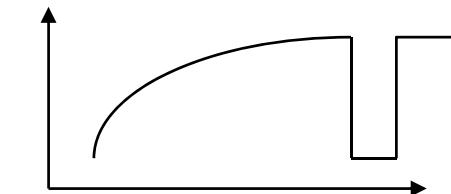
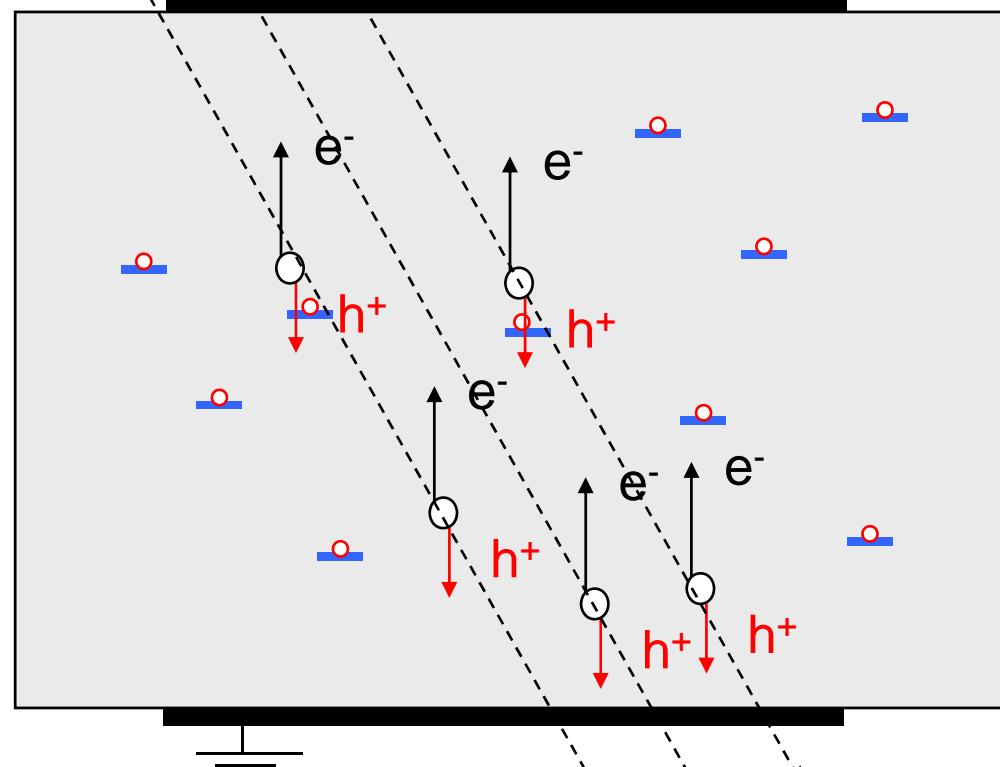
See DRM 16 (2007) 1038–1043

X, β, γ 

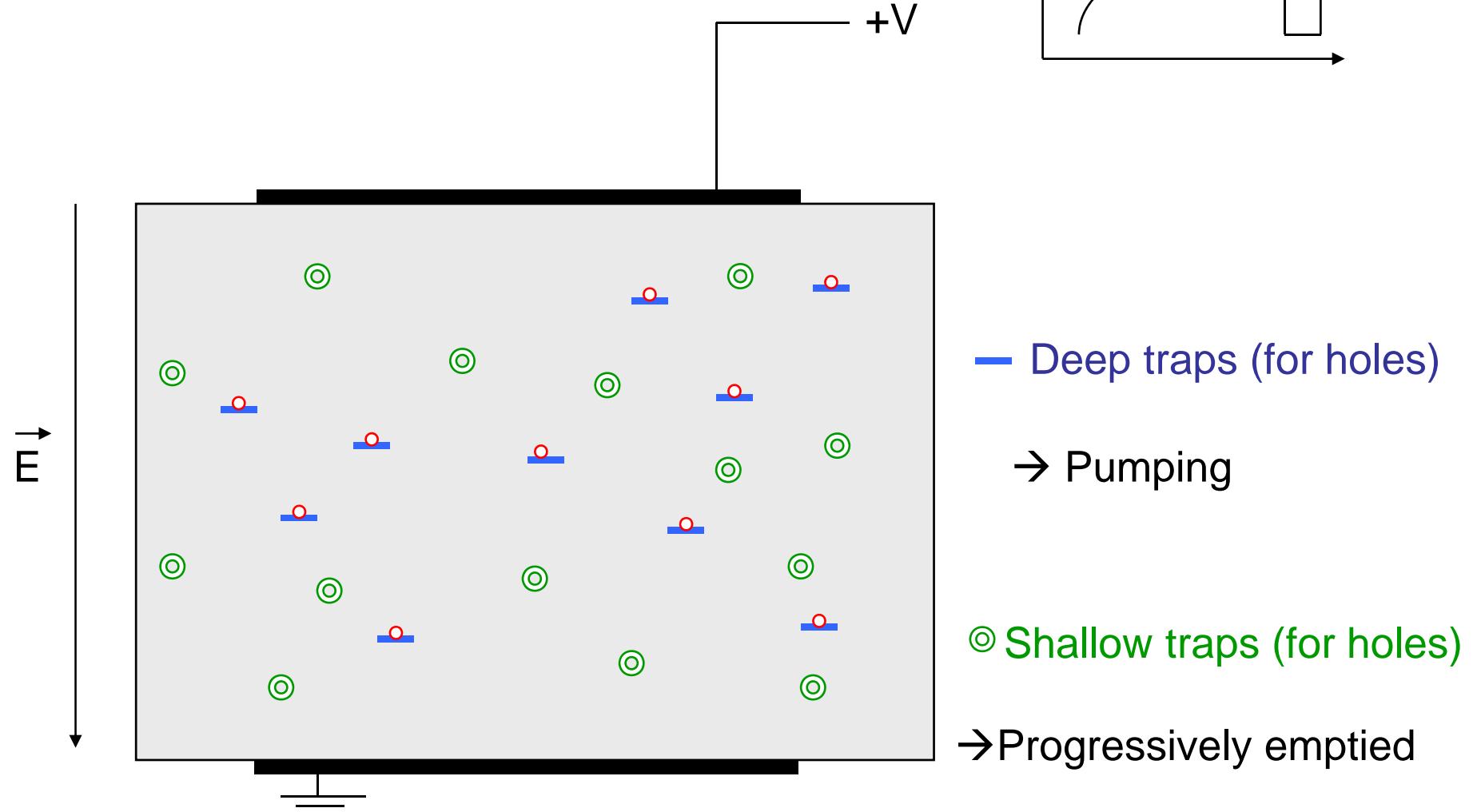
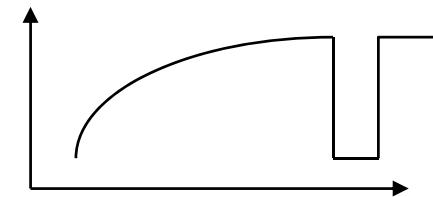
— Deep traps (for holes)
→ Pumping



See DRM 16 (2007) 1038–1043

X, β, γ $\rightarrow E$ 

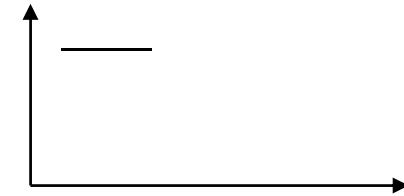
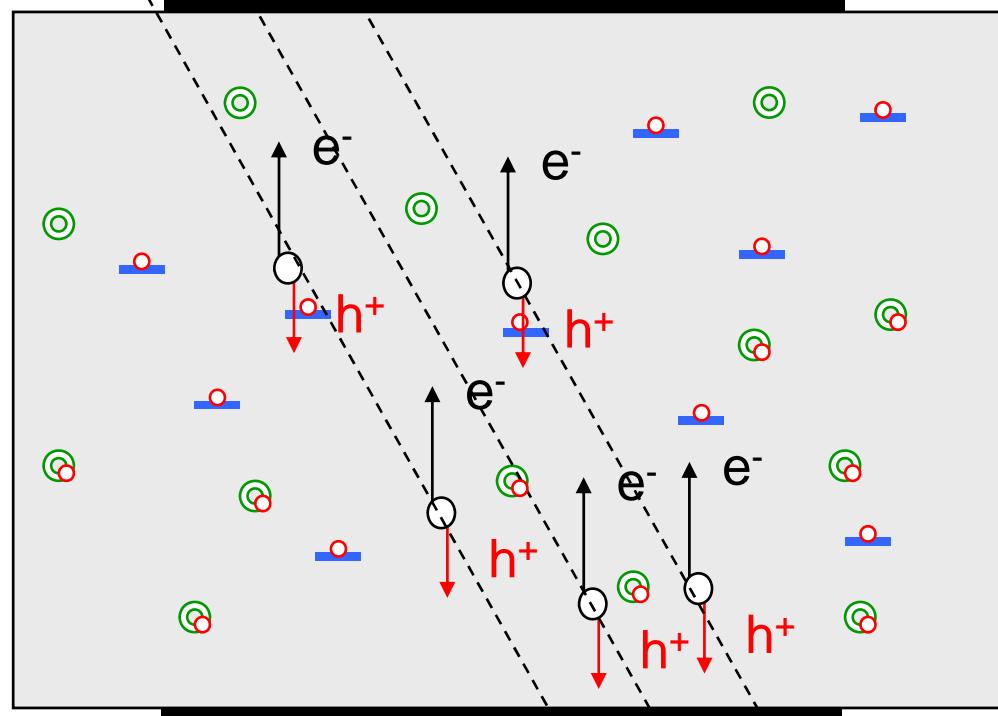
— Deep traps (for holes)
→ Pumping



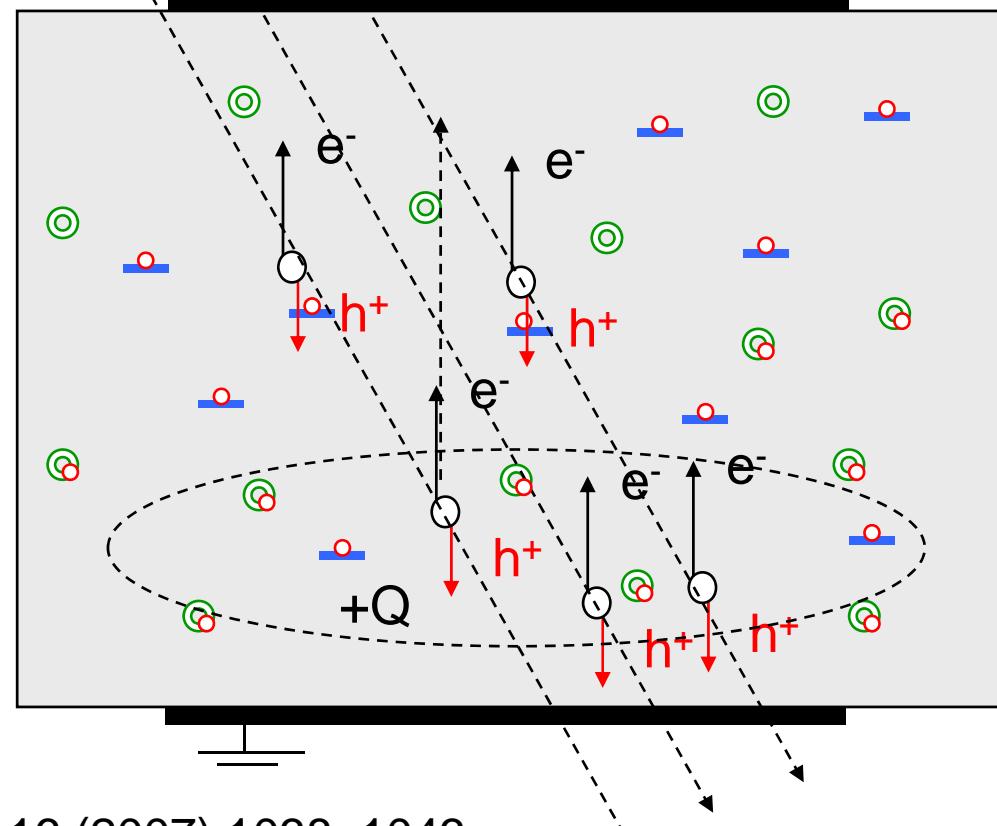
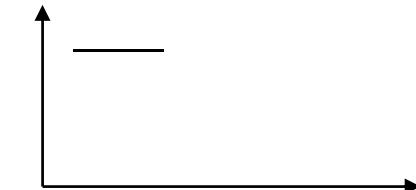
See DRM 16 (2007) 1038–1043

X, β, γ

+V

 $\rightarrow E$ 

See DRM 16 (2007) 1038–1043

X, β, γ E $+V$ 

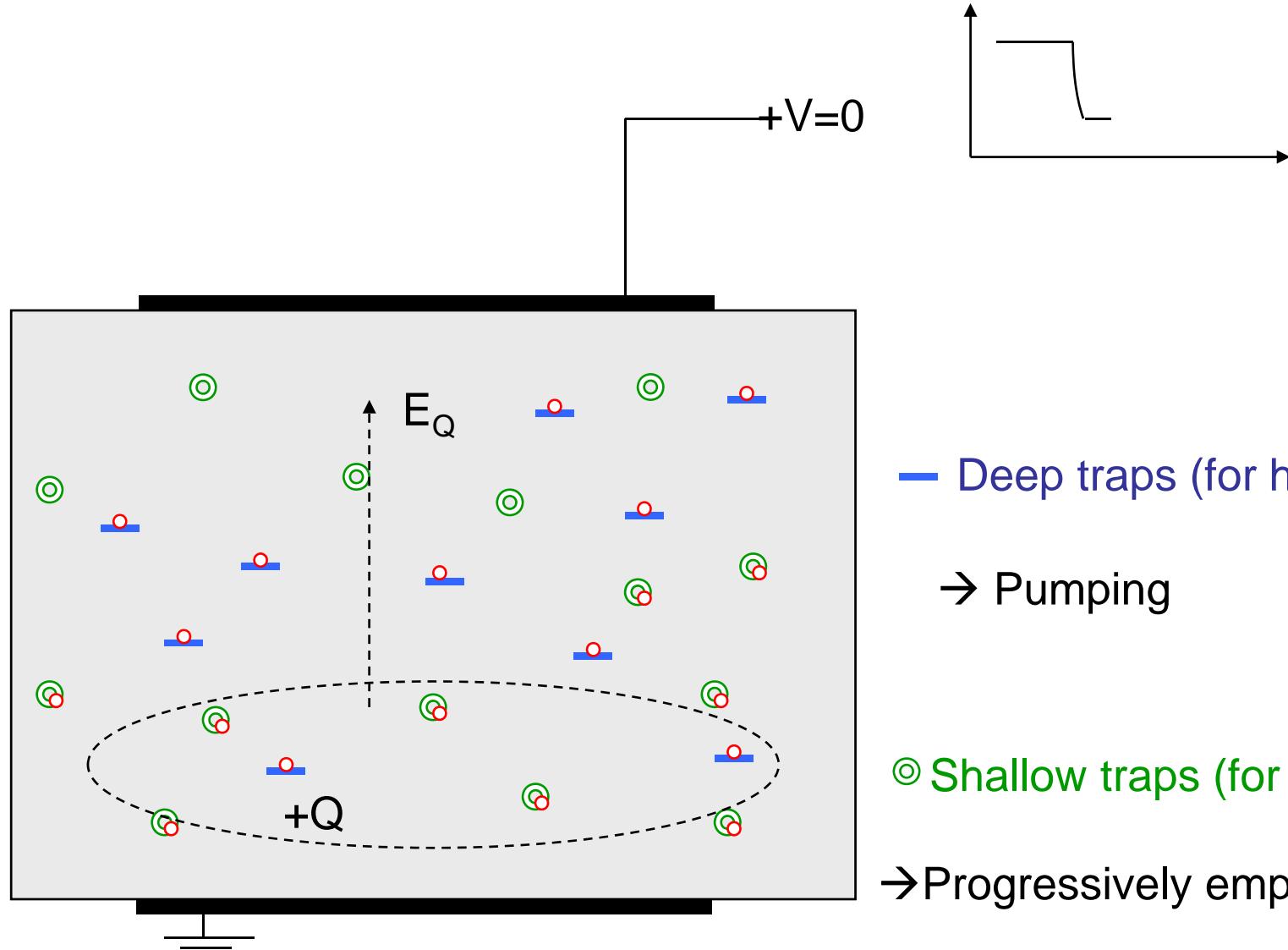
→ Deep traps (for holes)

→ Pumping

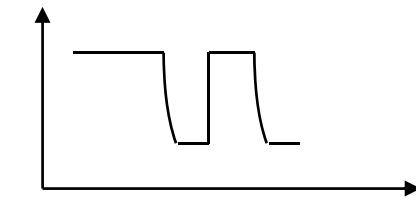
◎ Shallow traps (for holes)

→ Progressively emptied

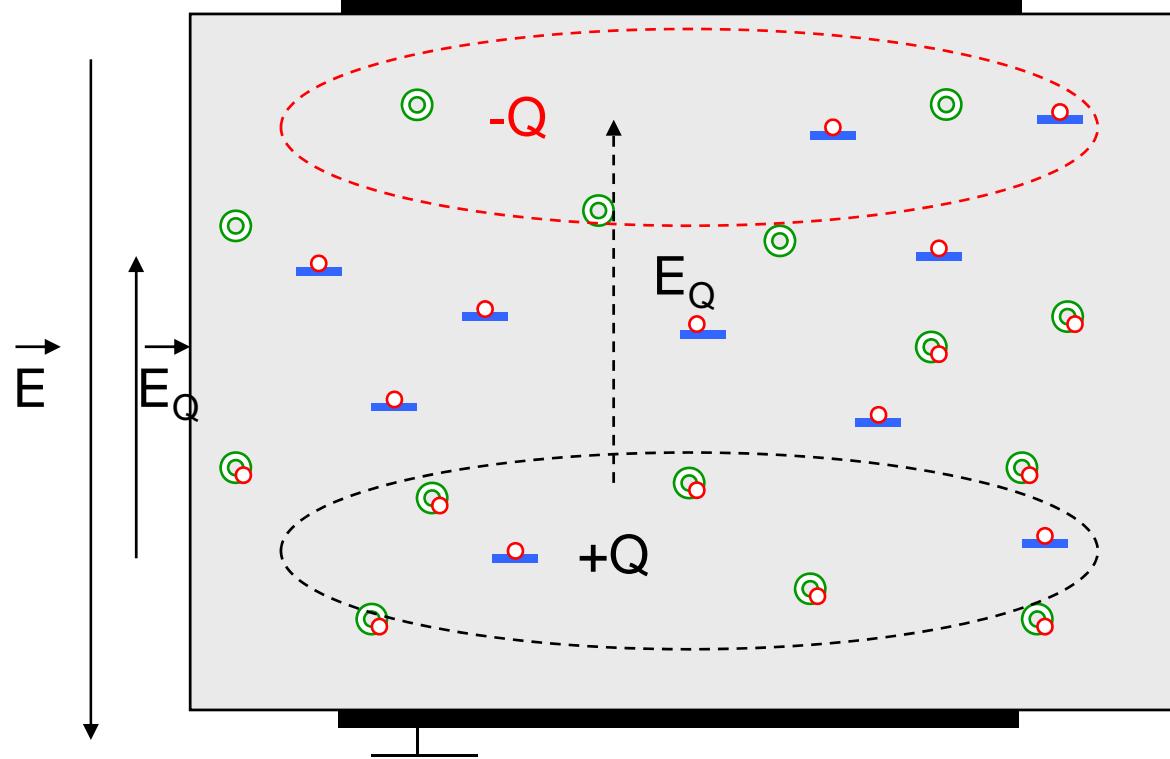
See DRM 16 (2007) 1038–1043



See DRM 16 (2007) 1038–1043

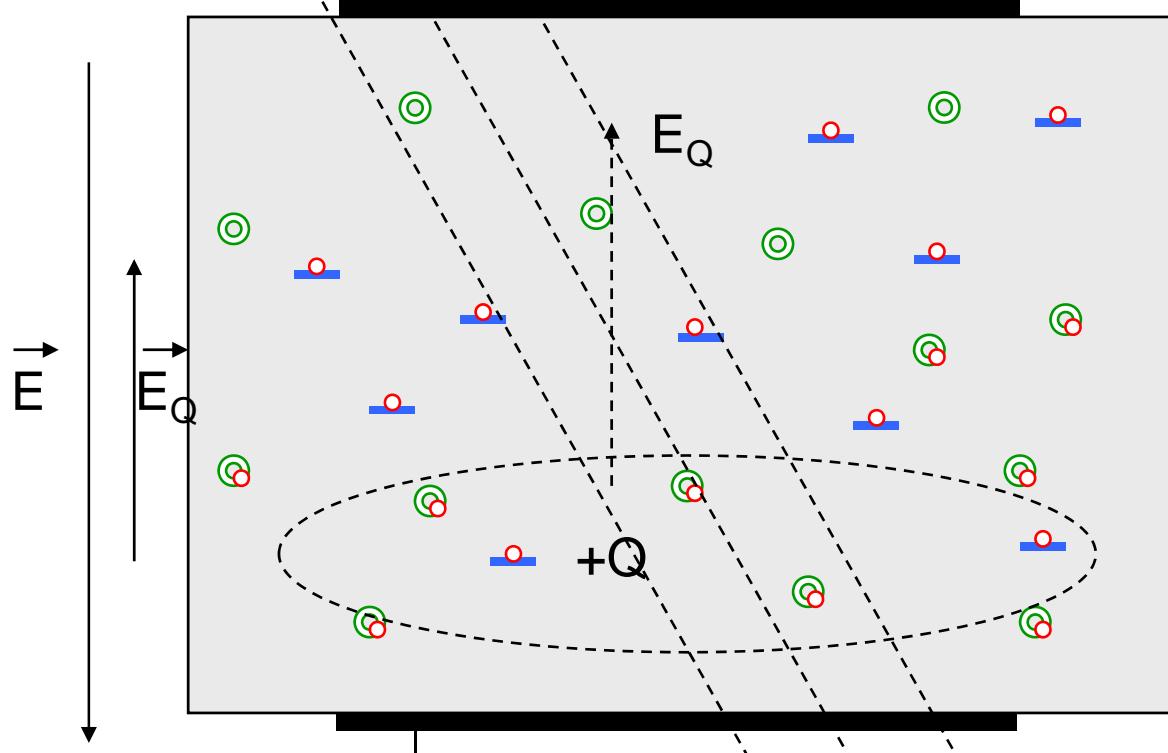


Same discussion on electrons...



- Deep traps (for holes)
- Pumping
- ◎ Shallow traps (for holes)
- Progressively emptied

See DRM 16 (2007) 1038–1043

X, β, γ 

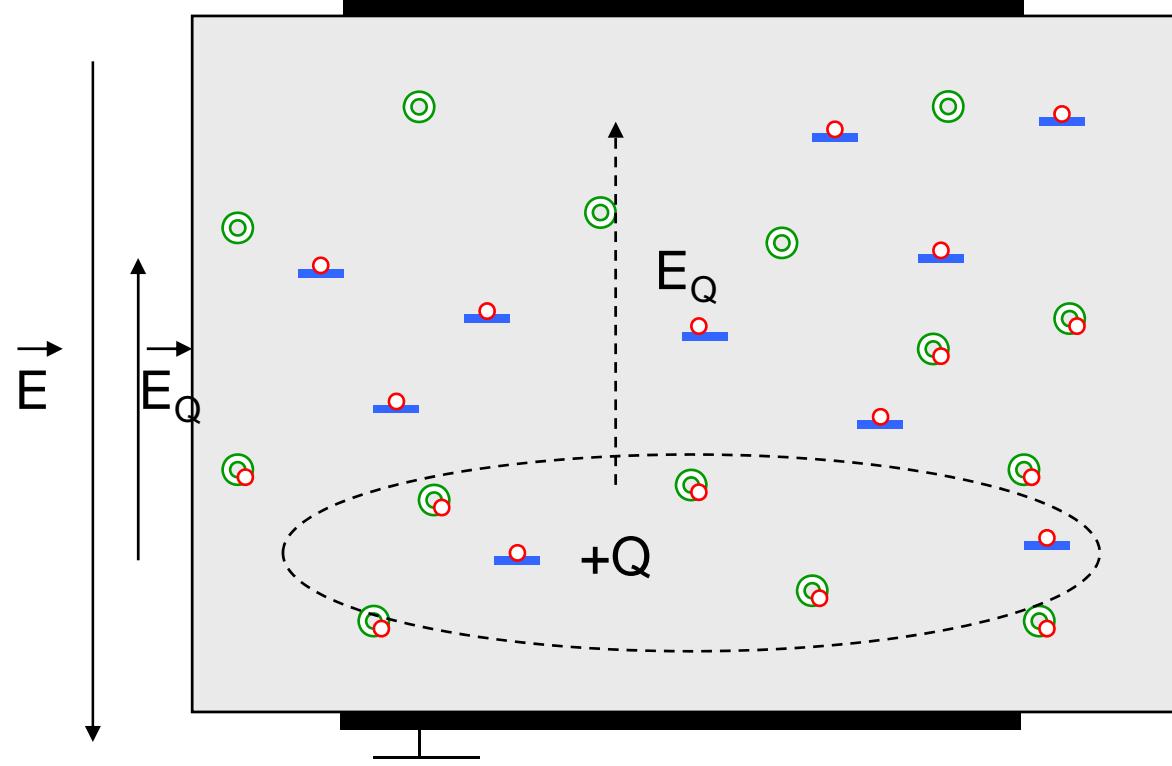
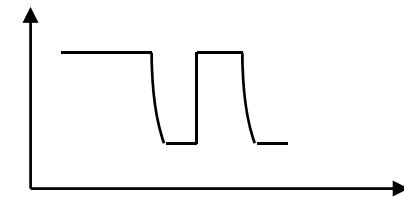
→ Deep traps (for holes)

→ Pumping

◎ Shallow traps (for holes)

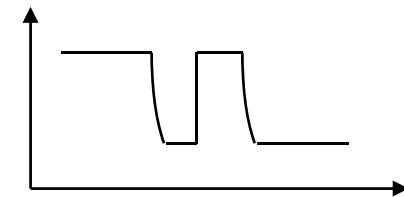
→ Progressively emptied

See DRM 16 (2007) 1038–1043

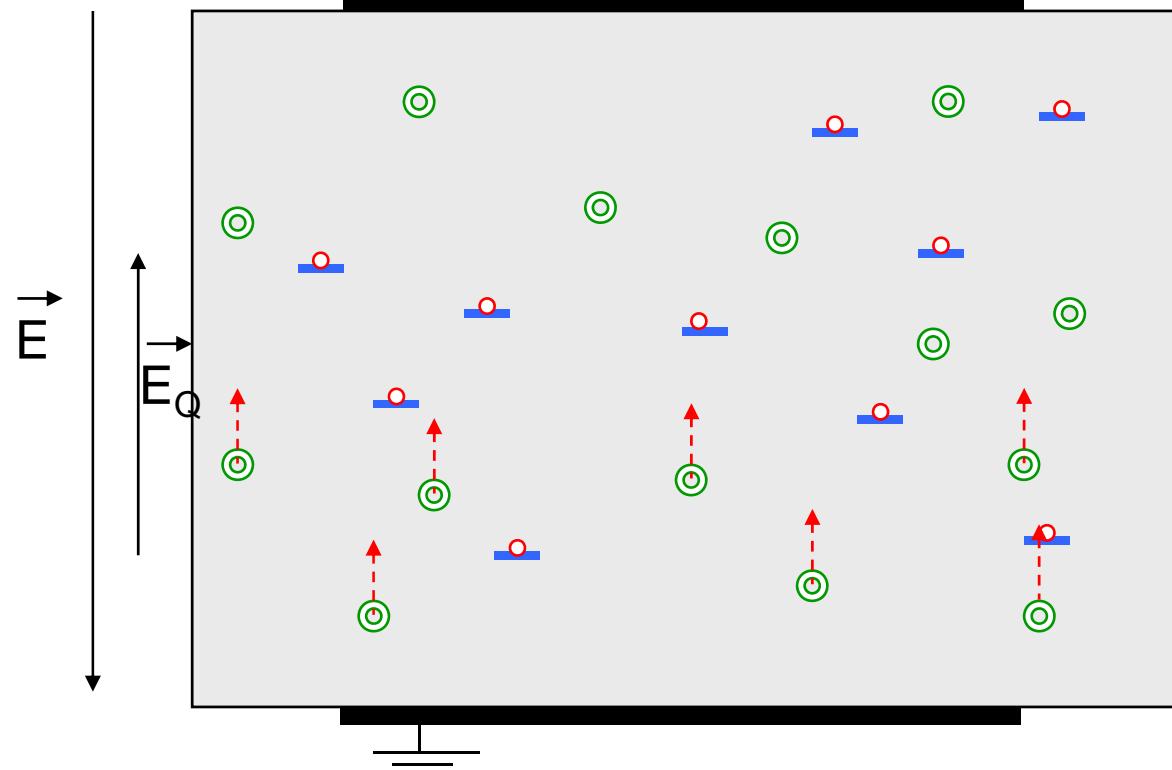


- Deep traps (for holes)
- Pumping
- ◎ Shallow traps (for holes)
- Progressively emptied

See DRM 16 (2007) 1038–1043

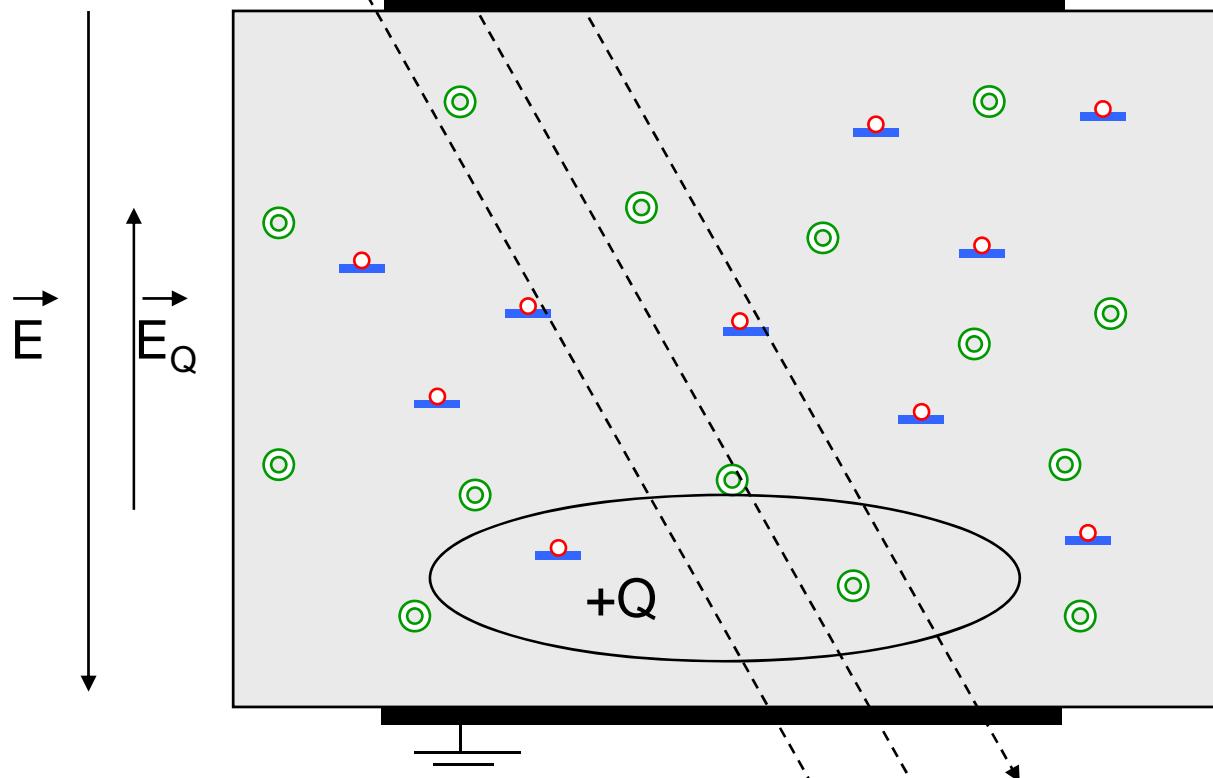


+V=0



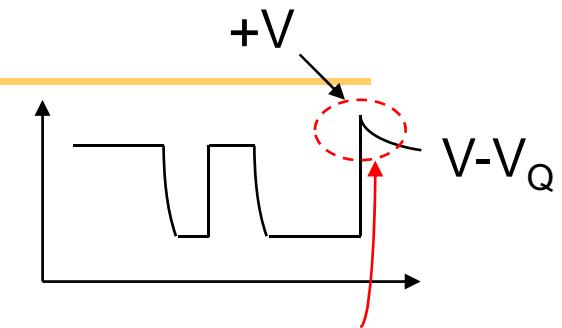
- Deep traps (for holes)
- Pumping
- ◎ Shallow traps (for holes)
- Progressively emptied

See DRM 16 (2007) 1038–1043

X, β, γ 

See DRM 16 (2007) 1038–1043

list

**"overshoot"**

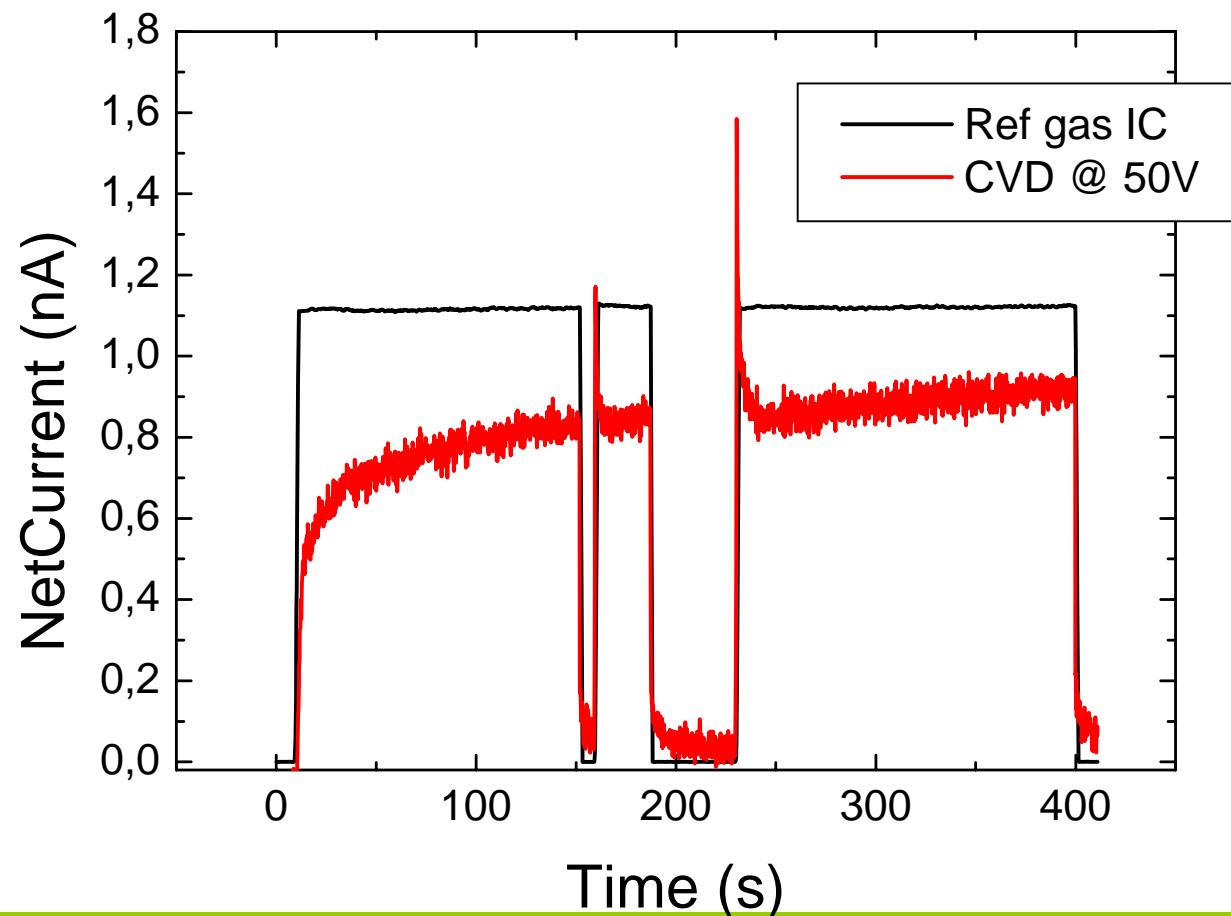
- Deep traps (for holes)
- Pumping
- ◎ Shallow traps (for holes)
- Progressively emptied

It comes :

- The ON state is related to an equilibrium between carrier trapping and de-trapping :
- Sensitivity is strongly affected by transiting charges
- Equilibrium also varies with dose levels
 - Non linearities
- Stability is strongly varying with the device temperature :
 - This is one way to improve the signal stability : work at Temperatures at which shallow levels are emptied.
 - OK but not always applicable

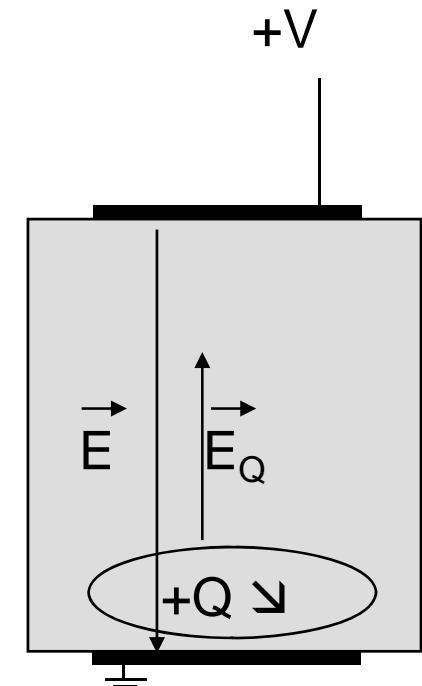
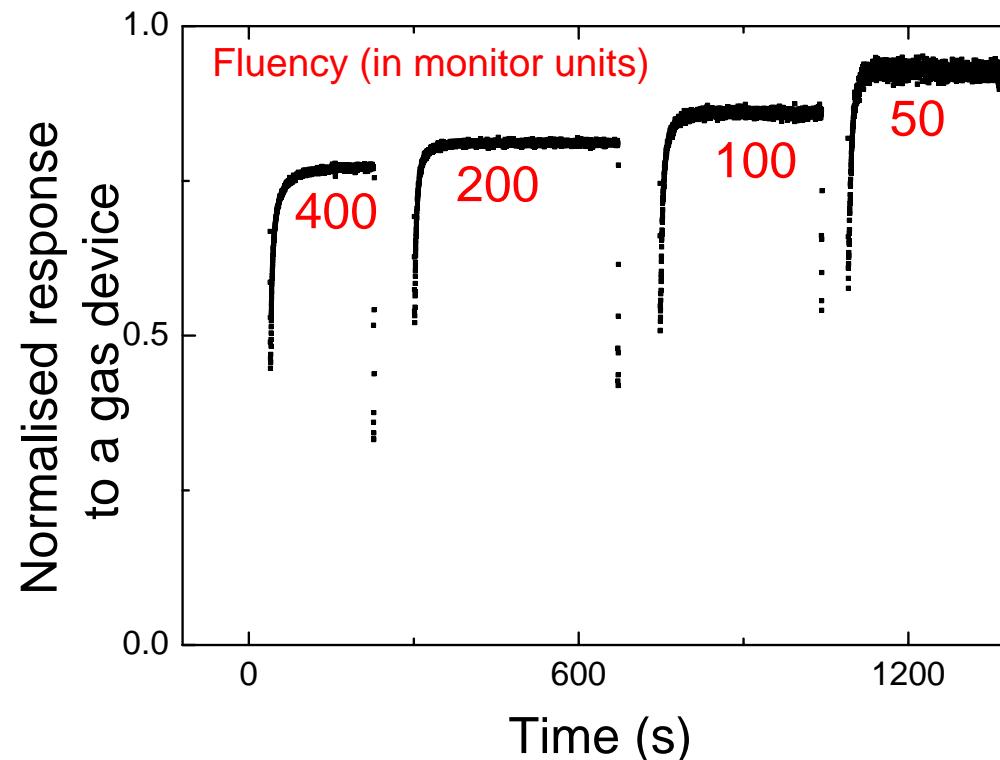
Steady state measurements

Experiments performed under 6 MeV photon beams.
Comparing a diamond device to a reference gas ionisation chamber
Typ. dose rate is = 3Gy/min



Effect of the dose rate

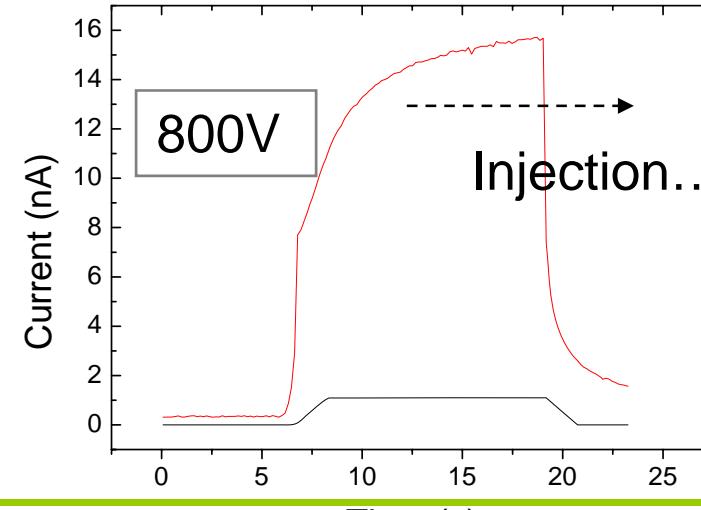
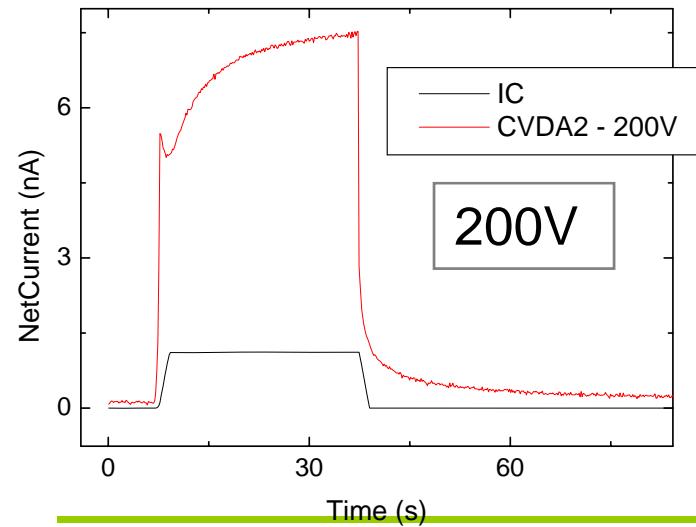
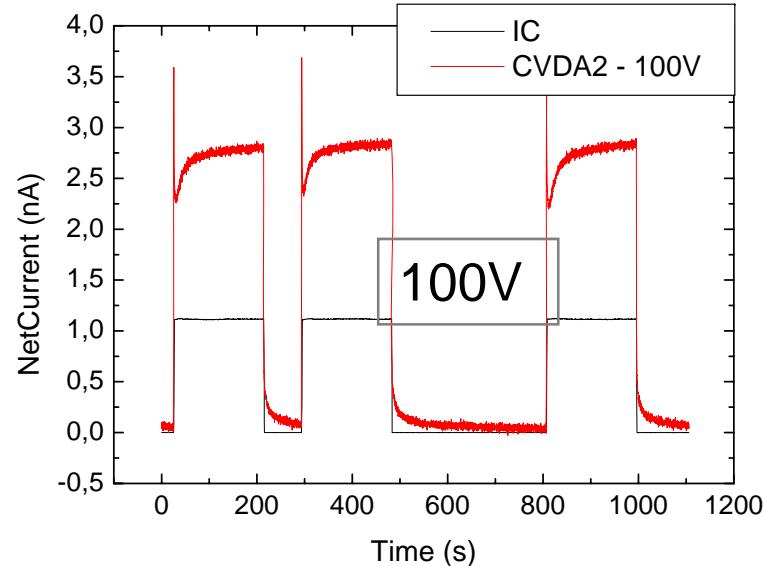
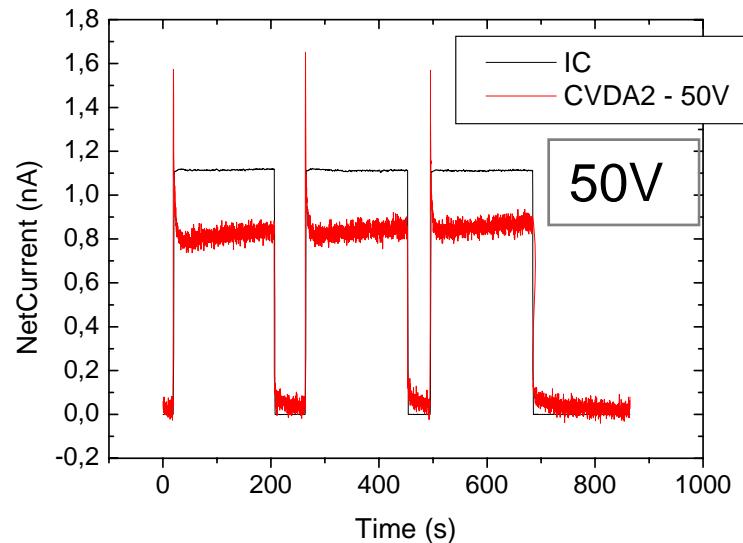
E_Q is only created by the carriers transiting through the device
→ Therefore the greater the signal the greater E_Q



→ The lower the fluency, the lower the signal :
 → the lower the trapped charge,
→ higher signals after stabilisation (E_Q vanishes)

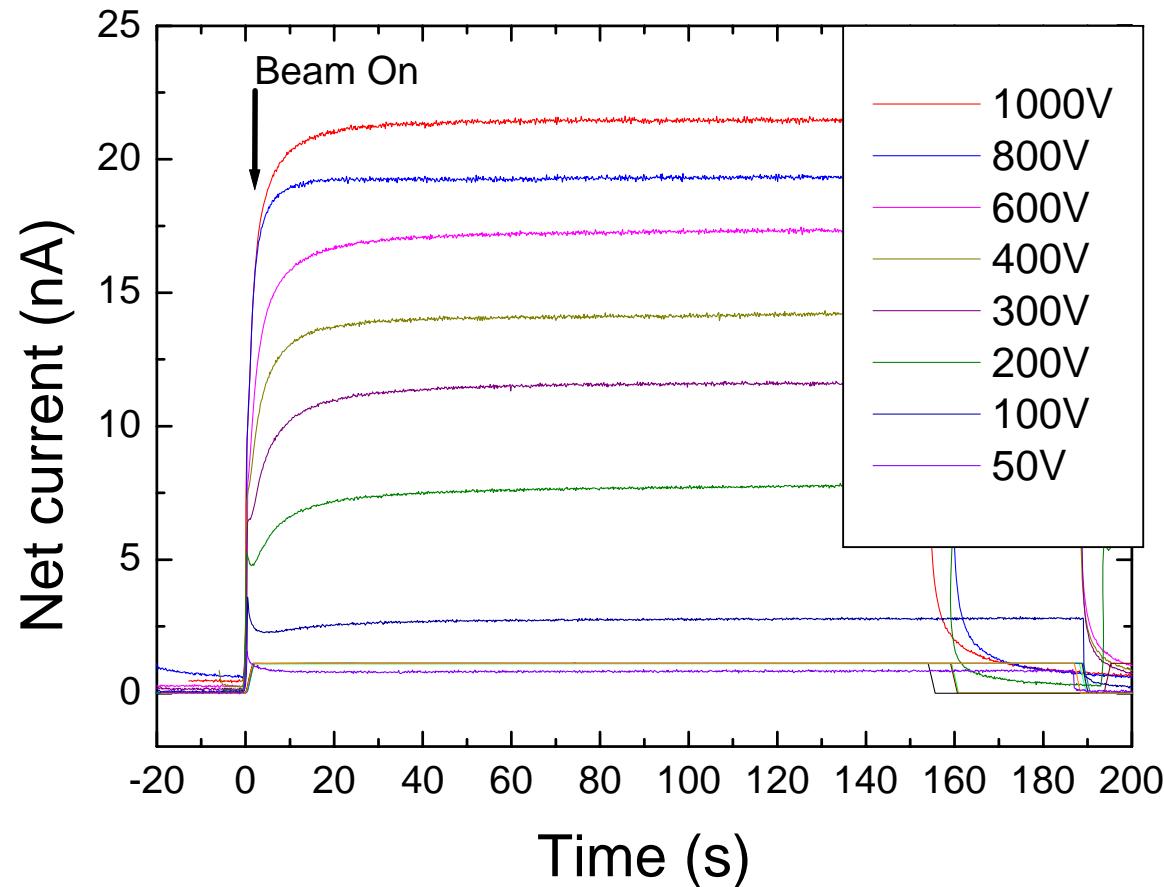
Effect of the E field

At low E fields, the overshoot is predominant, and vanishes at high E fields

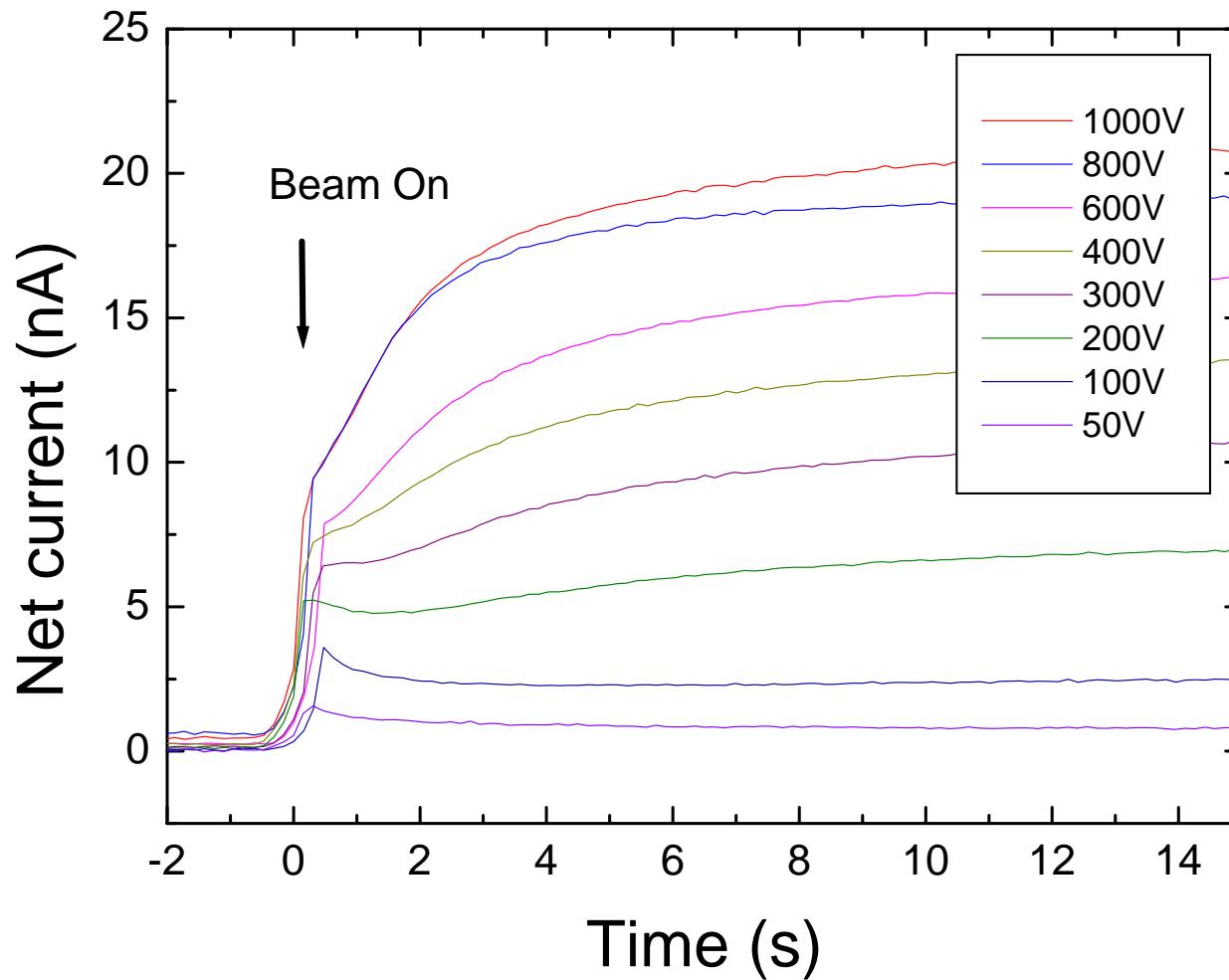


Effect of the E field

At low E fields, the overshoot is predominant, and vanishes at high E fields

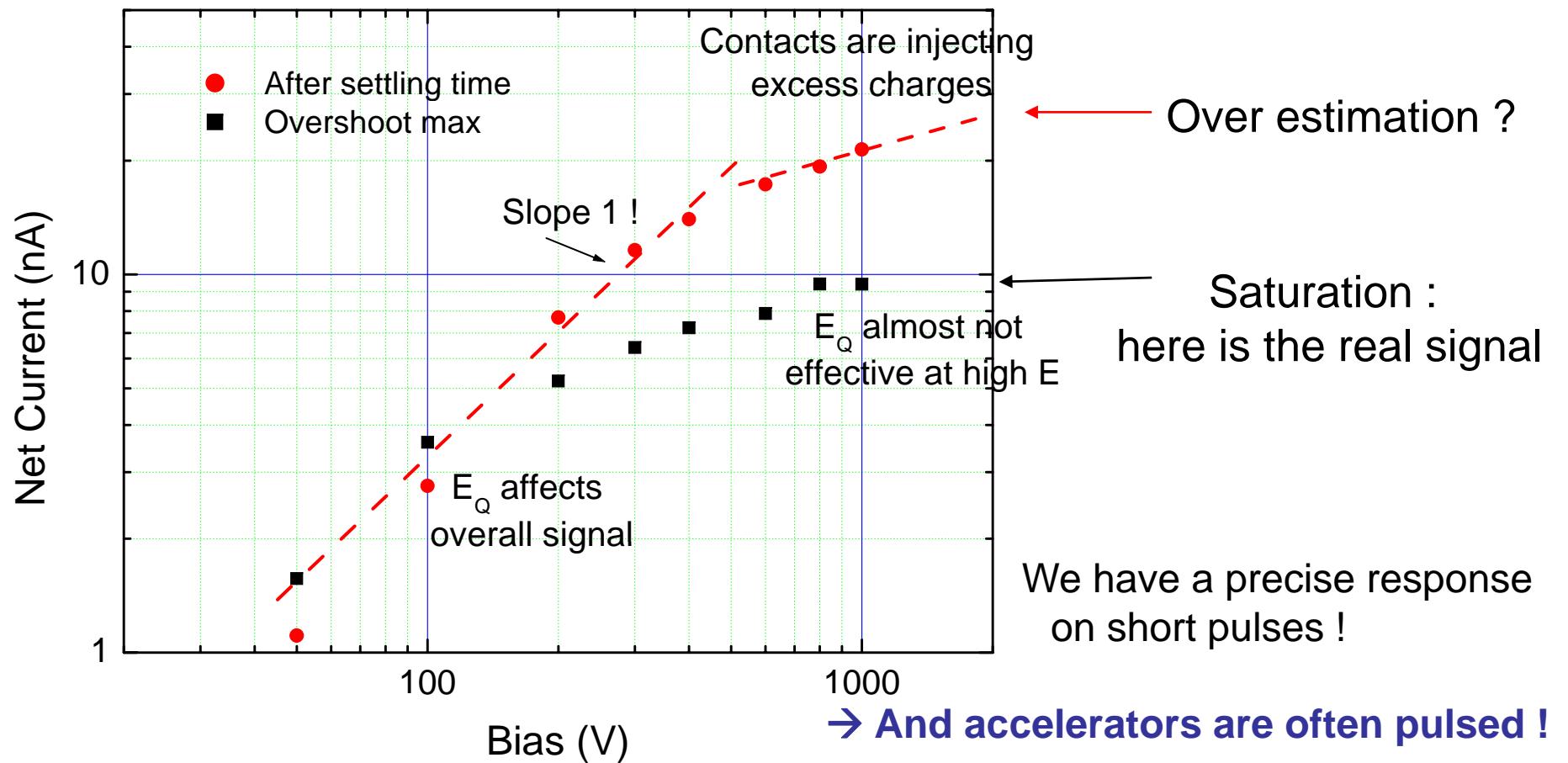


Effect of the E field



Effect of the E field

The overshoot is caused by the absence of E_Q , and drops during E_Q build-up.
However E_Q is only created by the carriers transiting through the device
→ Therefore the greater the signal the faster the overshoot drops

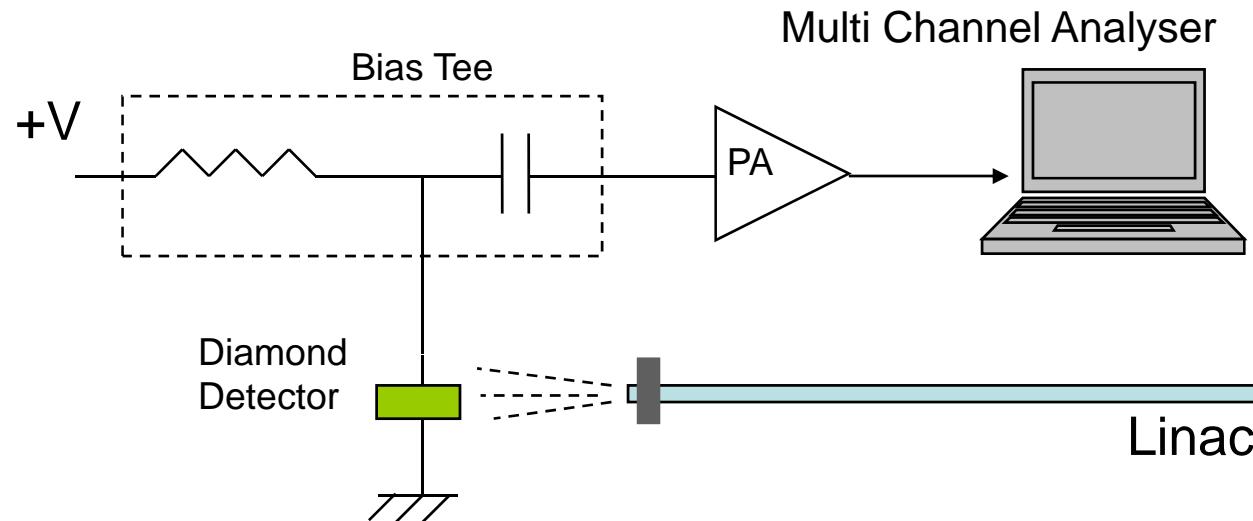


Response to a pulsed excitation

Tests on the SAPHIR accelerator (Saclay)

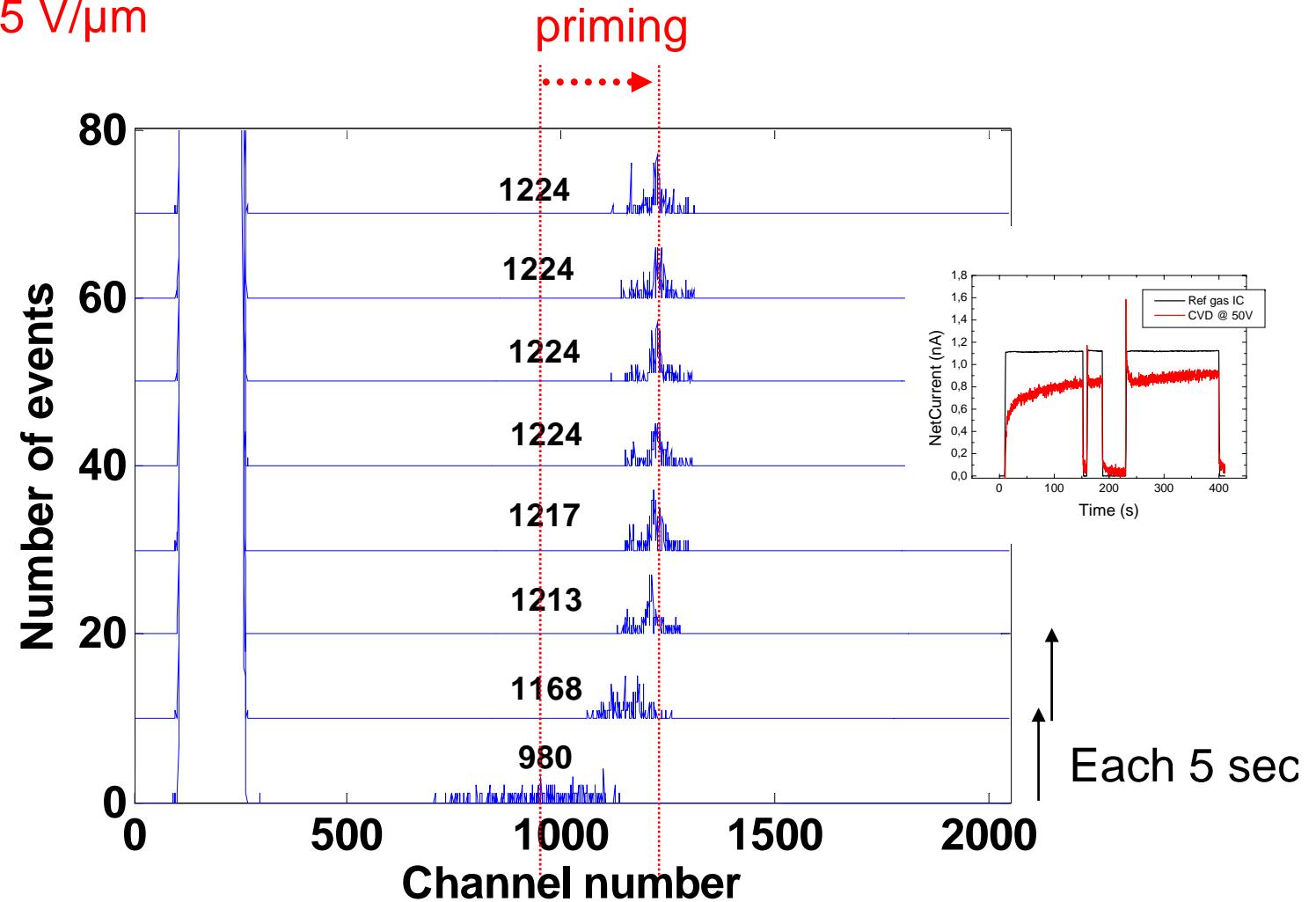
Pulsed X-rays, 17MV accelerator

Pulses are $2\mu\text{s}$ long, at 25 Hz

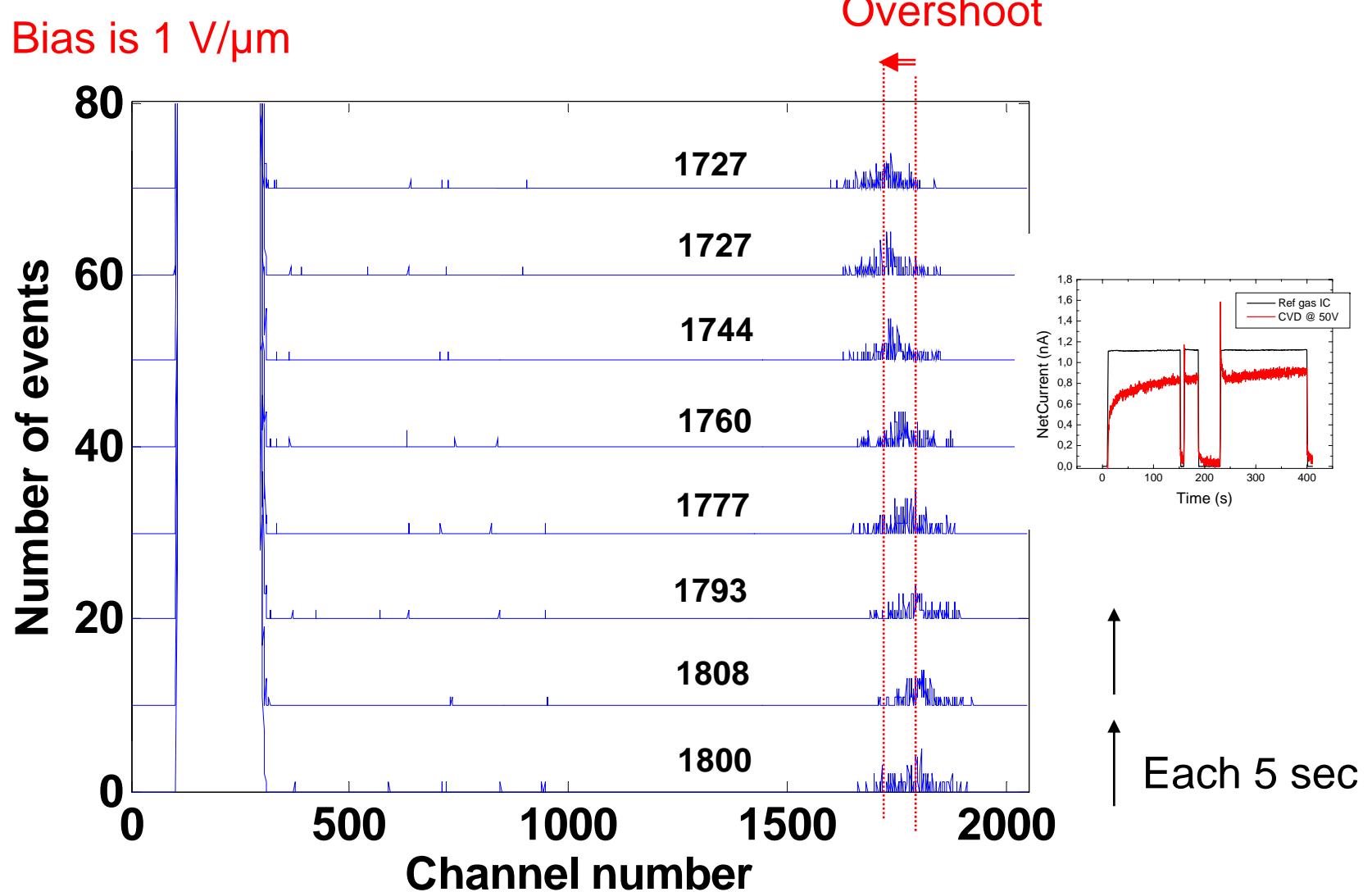


Pulsed height spectra under DC bias

Bias is 0.5 V/ μ m



Pulsed height spectra under DC bias

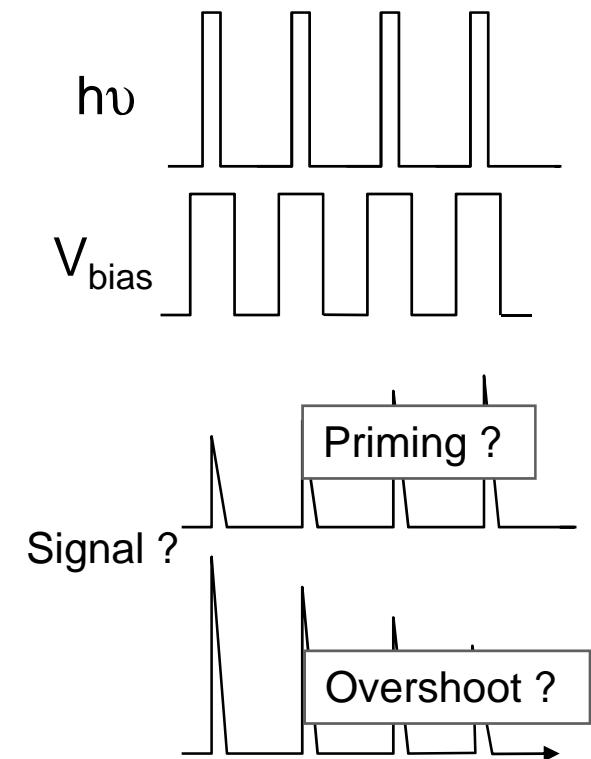
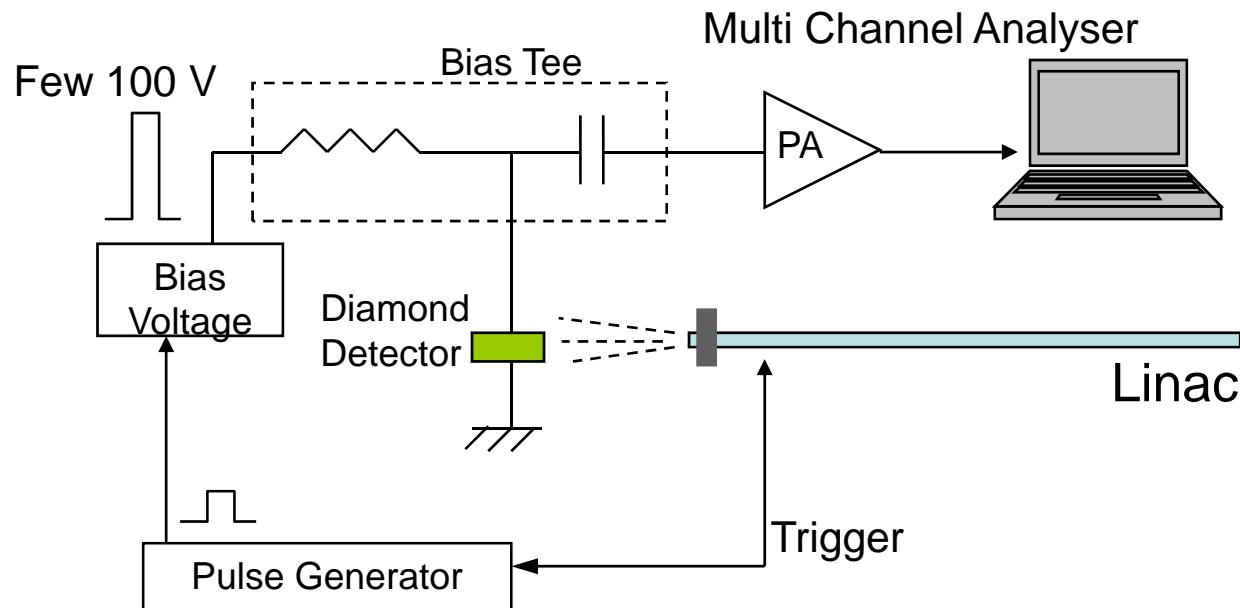


Response to pulsed excitation

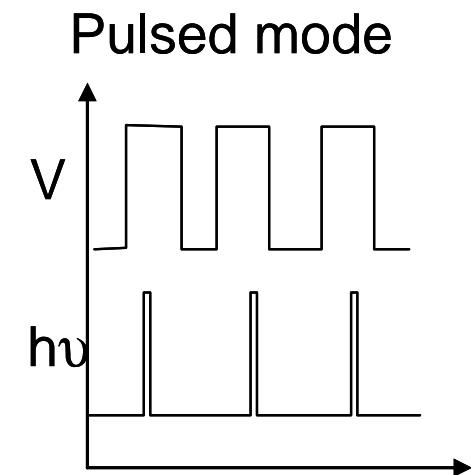
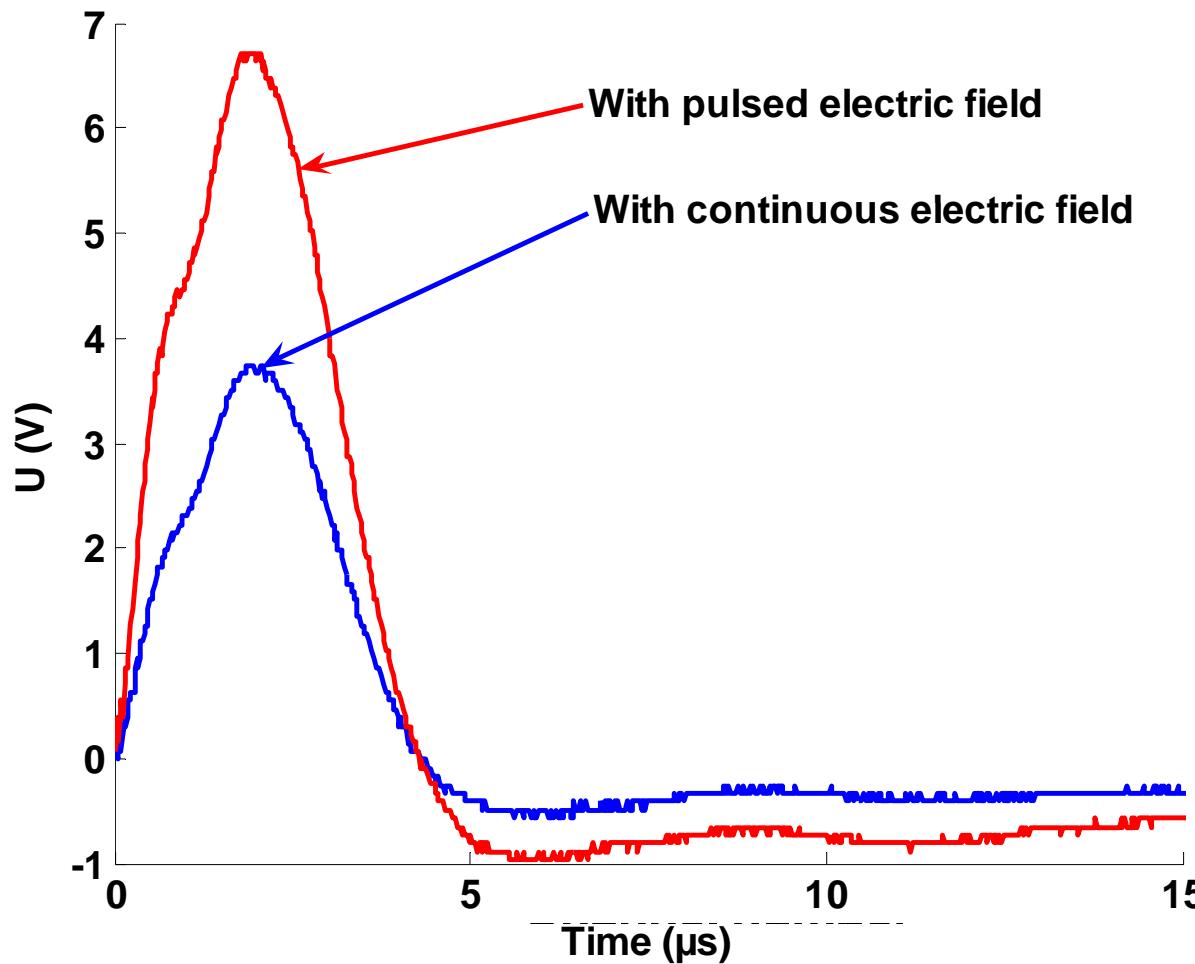
Tests on the SAPHIR accelerator (Saclay)

Pulsed X-rays, 17MV accelerator

Pulses are $2\mu\text{s}$ long, at 25 Hz

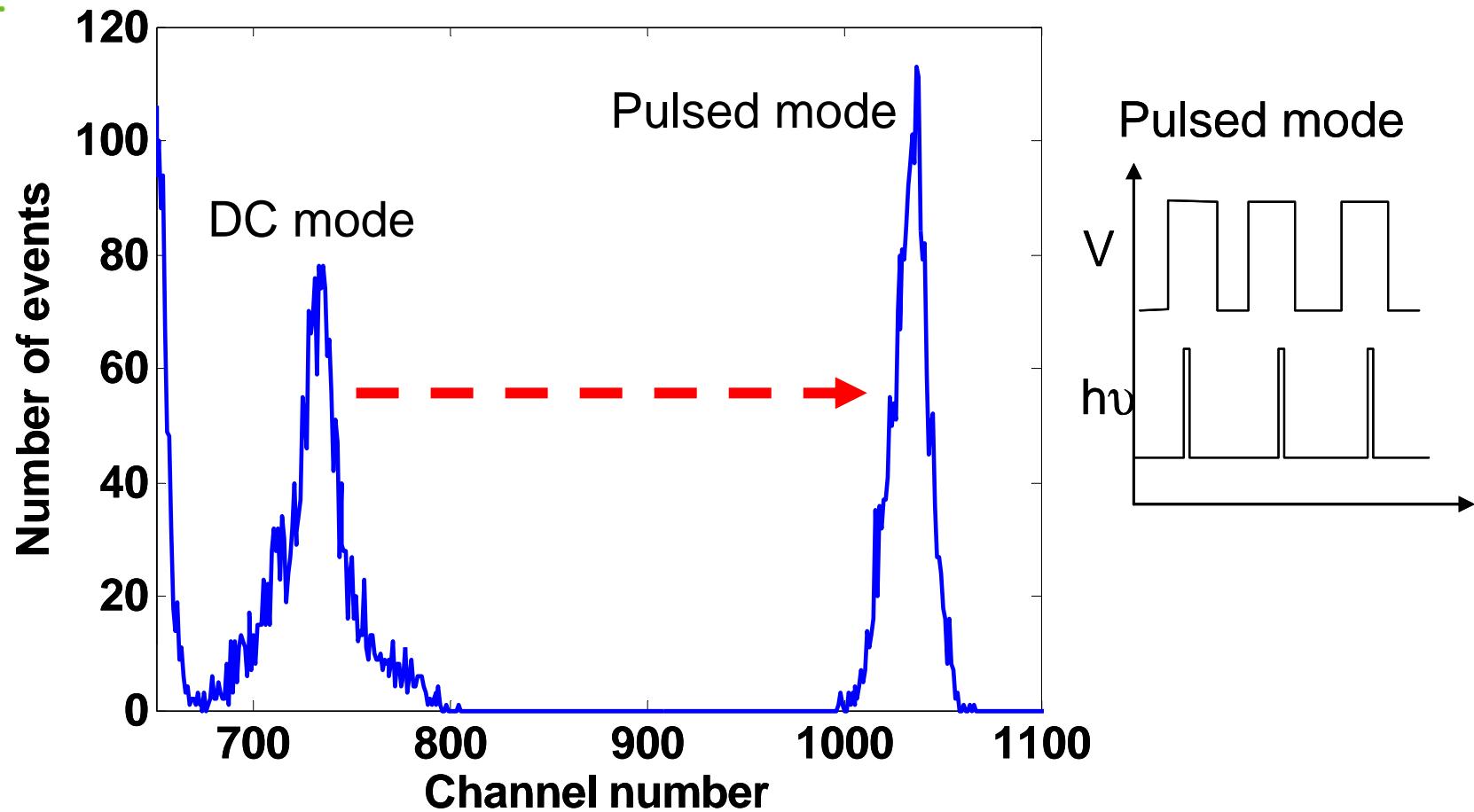


Pulsed height spectra under pulsed bias



→ Strong improvement of the photosensitivity

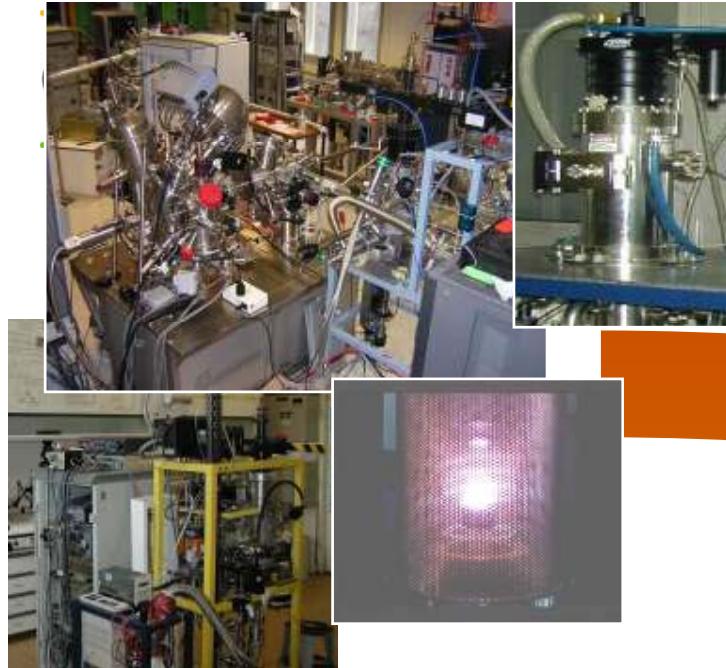
Pulsed height spectra under pulsed bias



→ Strong improvement of the photosensitivity

It comes :

- Shallow levels are effectively altering the photoresponse
 - But simply pulsed biases improve the response stability
- Unstable effects are observed in polyX devices
- they are not constituting a problem when
pulsed excitations are used !!



Diamond at LIST in Saclay

PROCESS



DETECTORS and SENSORS



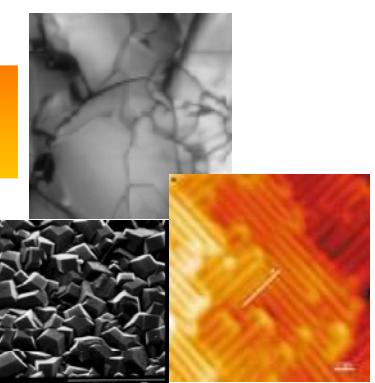
APPLICATIONS

Electronique
Extreme environments

Interfaces
Bio fonctionnalisation

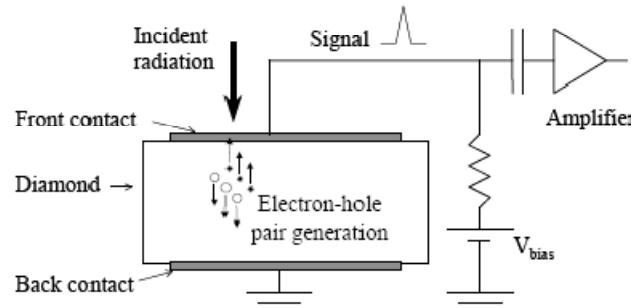
Sensors and transducers

R&D on épitaxy,
Single crystal growth, doping



Devices for confinement plasma monitoring

Ultrafast pulse monitors

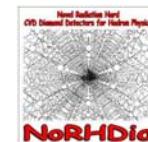


*Detectors for
Alpha monitoring
in corrosive media*



*Micro
-dosimeters*

Heavy ion physics



*Semi transparent devices
For beam monitoring*

Alpha measurements in corrosive media



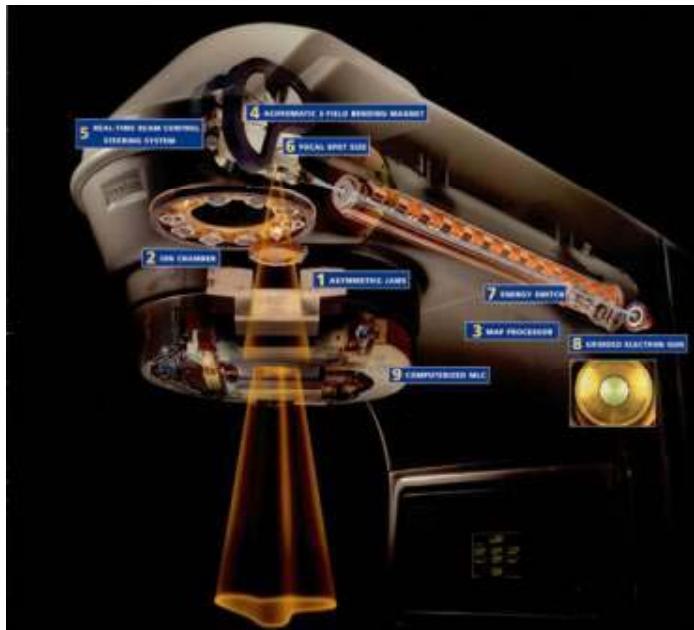
- 2004 : delivering devices to the Rokkasho Mura reprocessing plant
- Application : On-line alpha measurement
- pros of diamond : withstand extreme conditions (HNO_3 , 5N, 5bars, 80°C)



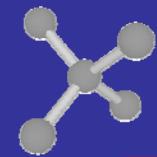
Radiotherapy : Maestro

Maestro : EU IP VIth Framework

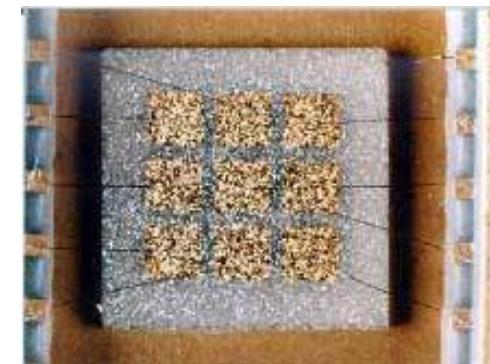
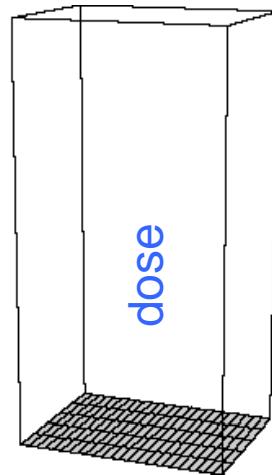
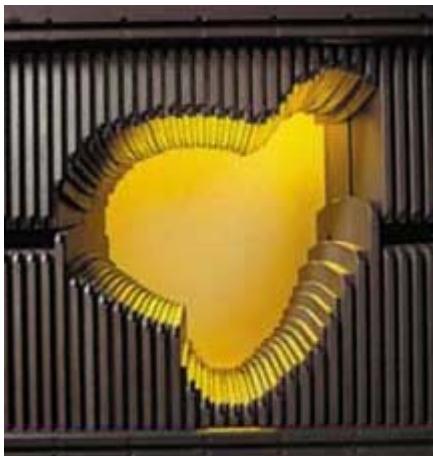
*Methods and Advanced Equipment for
Simulation and Treatment in Radio Oncology*



- Dose resilient
- Tissue equivalent
- Chemically inert
- Compatible with in-vivo
- Arrays

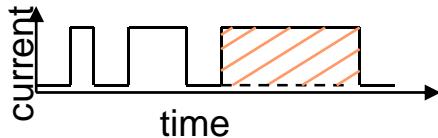


Accurate & real
time dose
monitoring

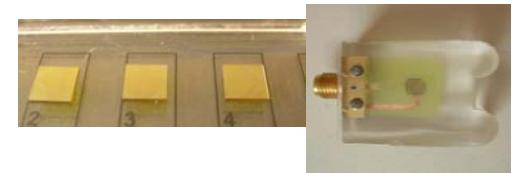


Evaluation of dosimetric parameters for SCDD

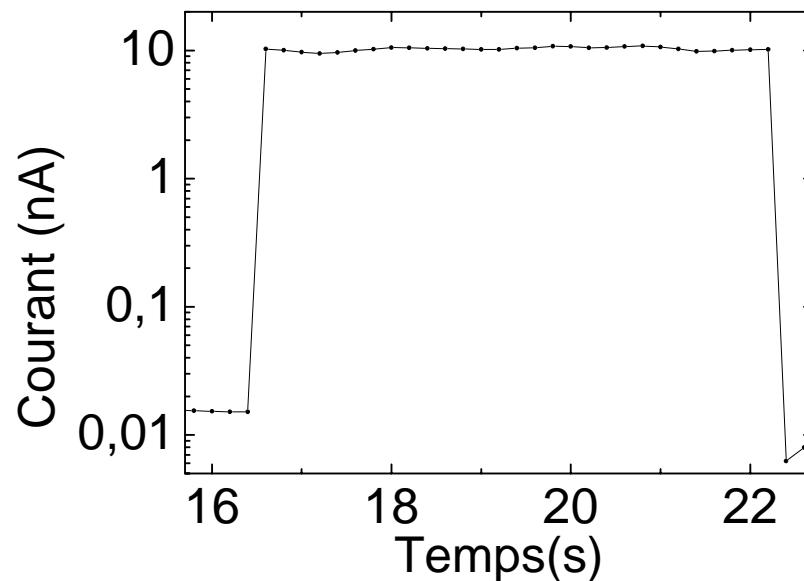
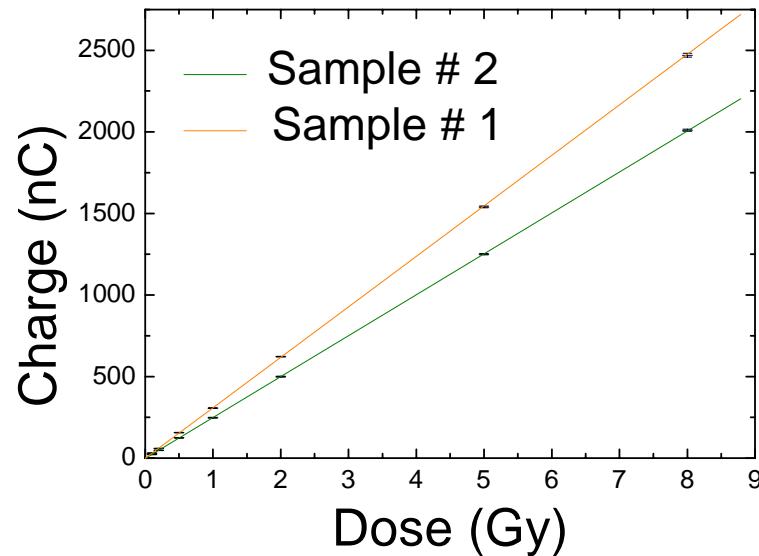
→ Dose dependence



Dose calculated from area
under curve at fixed dose rate



Exp conditions :
2Gy/min - 6MV photons beam
Doses from 0.1 to 8 Gy

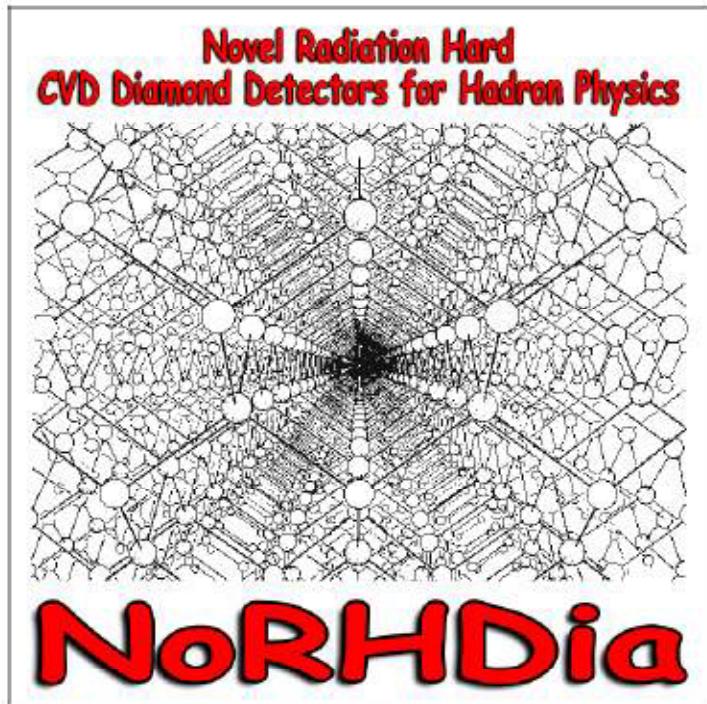


Linear behaviour : $R = 0.99999$

Signal to noise > 1000
Response time < 200ms

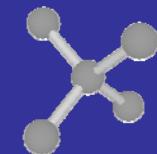


Similarly : for heavy ion beams



**NORHDIA : one of the 29 activity of
the I3HP project
"Integrated Infrastructure
Initiative on Hadron Physics"**

- Dose resilient
- Tissue equivalent
- Chemically inert
- Compatible with in-vivo
- Arrays

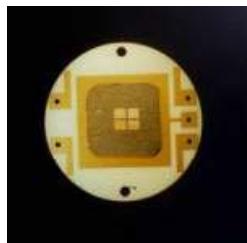


Real time and
accurate monitoring
of heavy ion beams
(position, fluency,
etc)



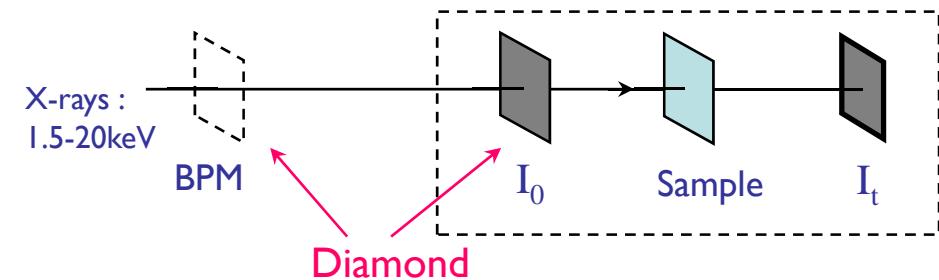
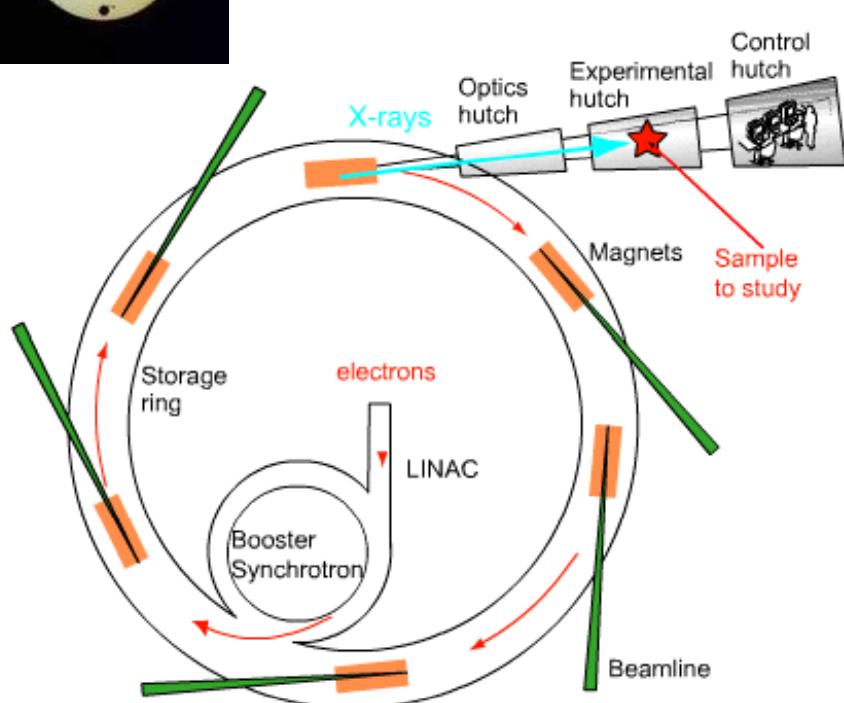
+ EU Network :
INFN, GSI, CERN,
ESRF, DESY, TUM,
Karlsruhe Univ, etc





Aiming at probing the beam characteristics (position, intensity, profile) at low energies and with a semitransparent material

- in front end (white light, high fluences – 10^{17} ph./s)
- in beam lines (monochromatic light, 10^8 – 10^{13} ph/s)



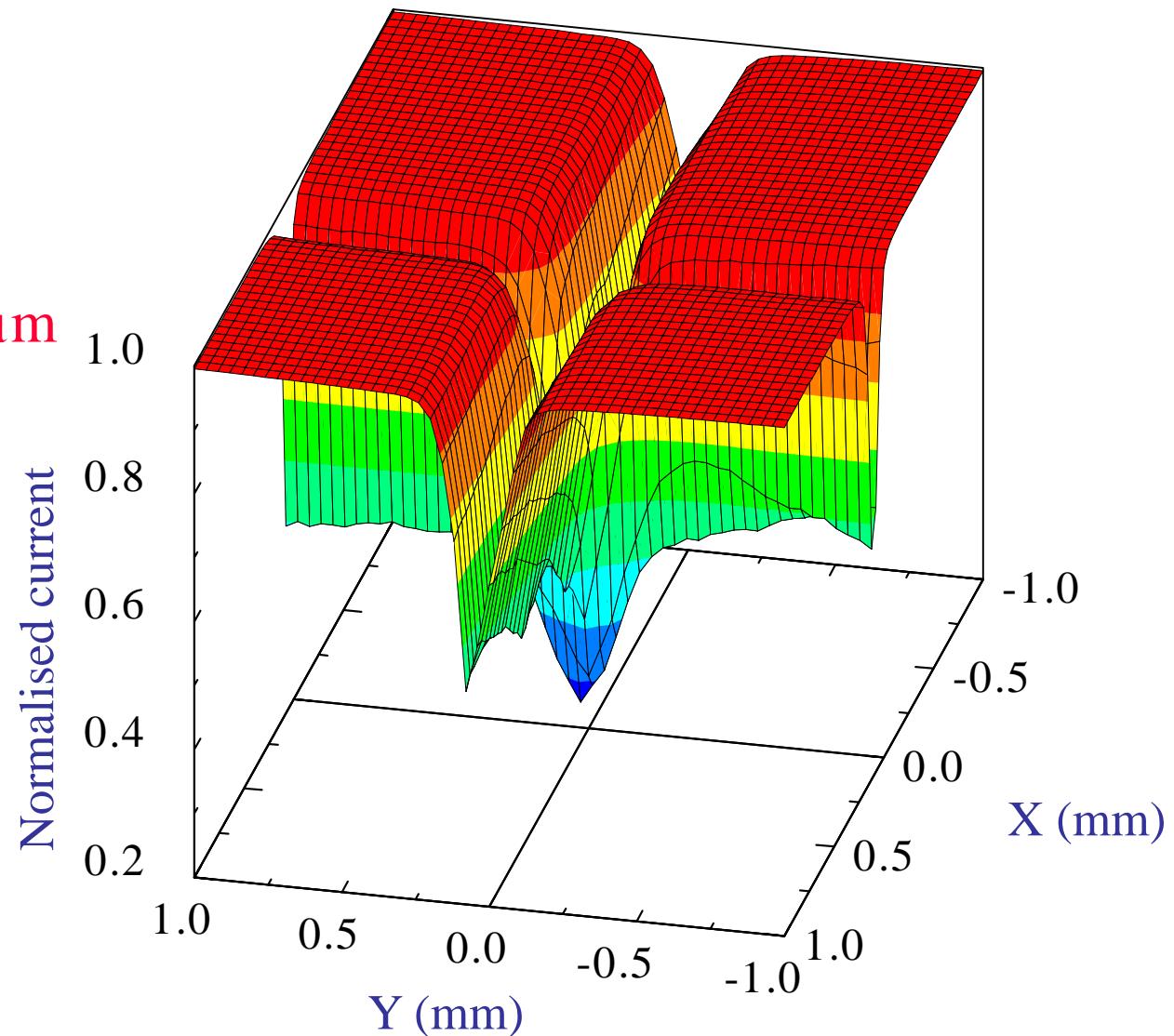
Monitoring devices must exhibit :

- high transparency (low Z)
 - fluence hardness
 - temperature hardness
 - mechanically resilient,
- Realisations have included
- Intensity monitors
 - Beam position monitors (2 μ m resol.)
 - Beam Profile monitors



Measured 3D scan response

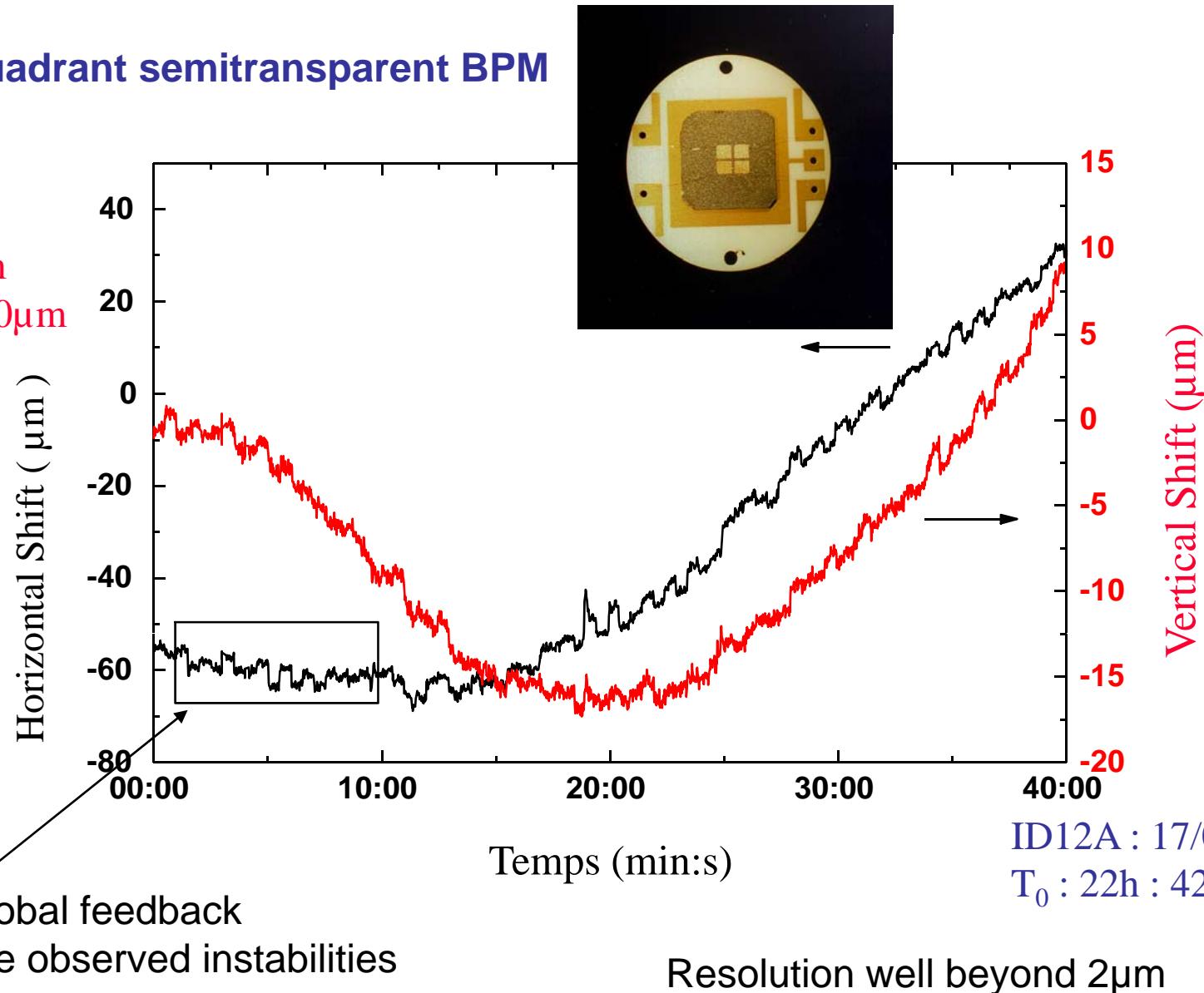
- square beam
- $200\mu\text{m} \times 200\mu\text{m}$
- 4 keV X-ray



Probing the beam instabilities

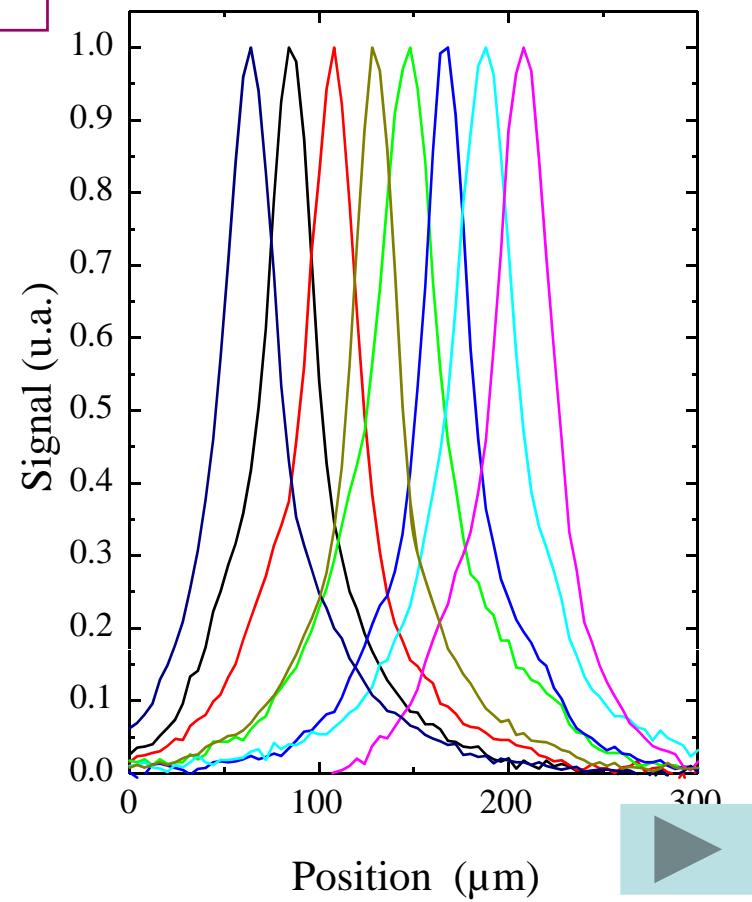
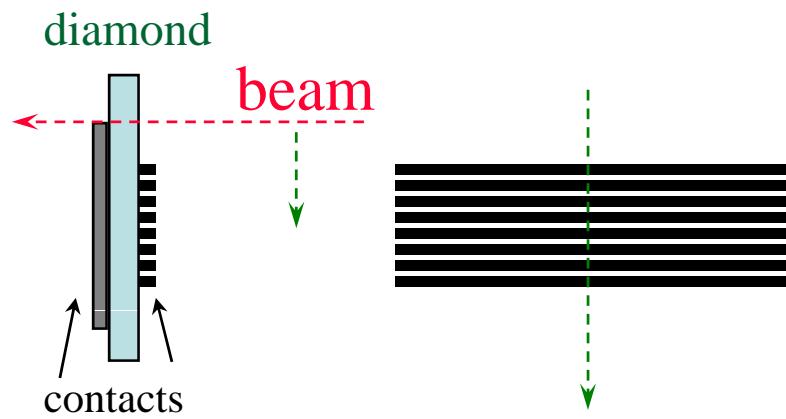
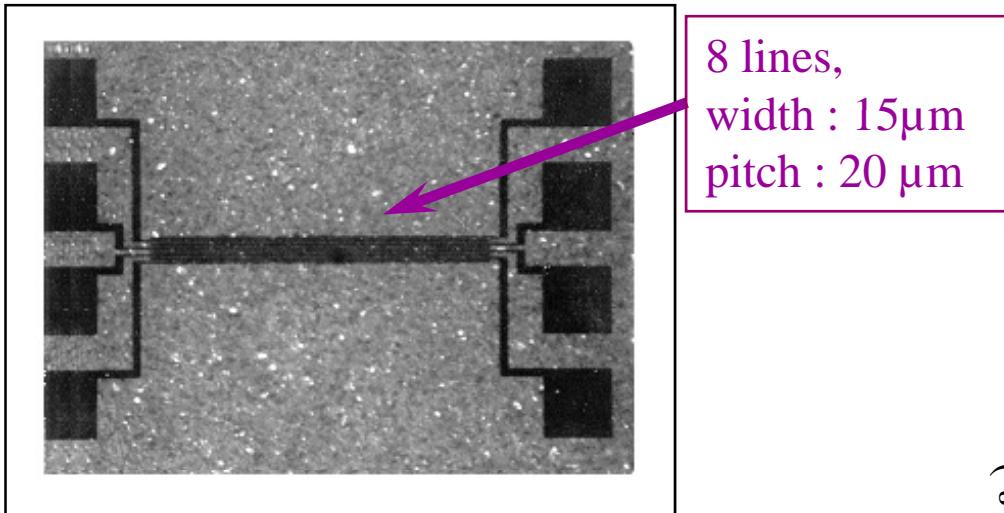
4 quadrant semitransparent BPM

- Square beam
- $200\mu\text{m} \times 200\mu\text{m}$
- 4 keV



Beam Profile Monitors

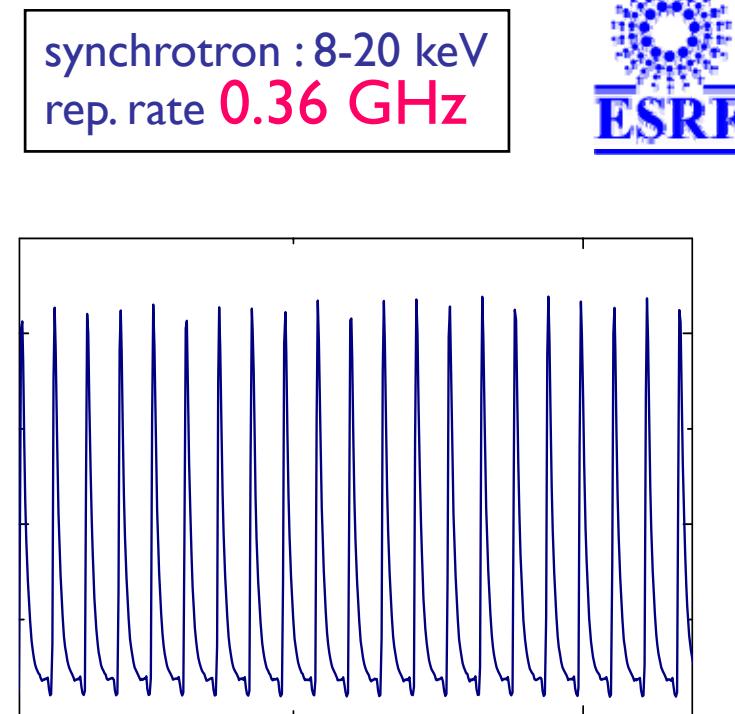
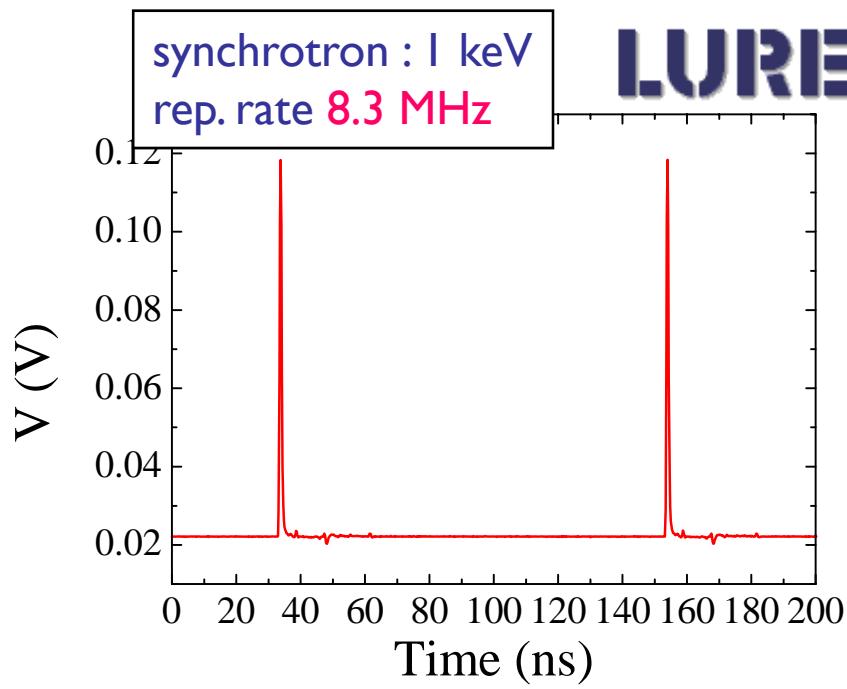
May efficiently be coupled with BPM



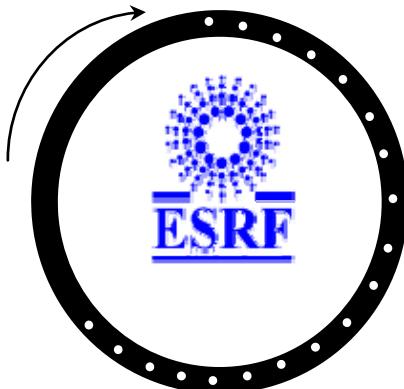
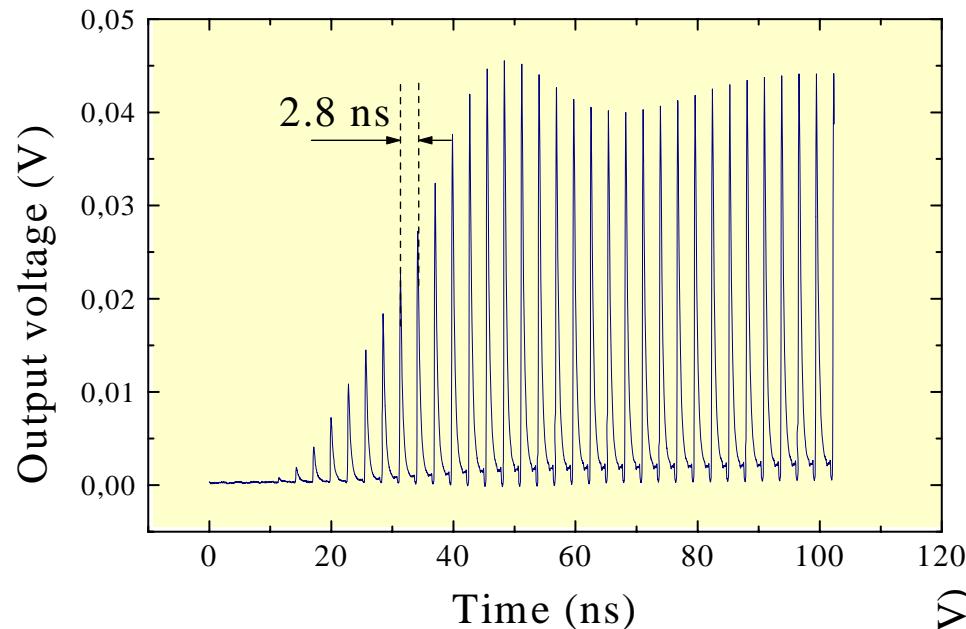
Ultra-fast pulse metrology



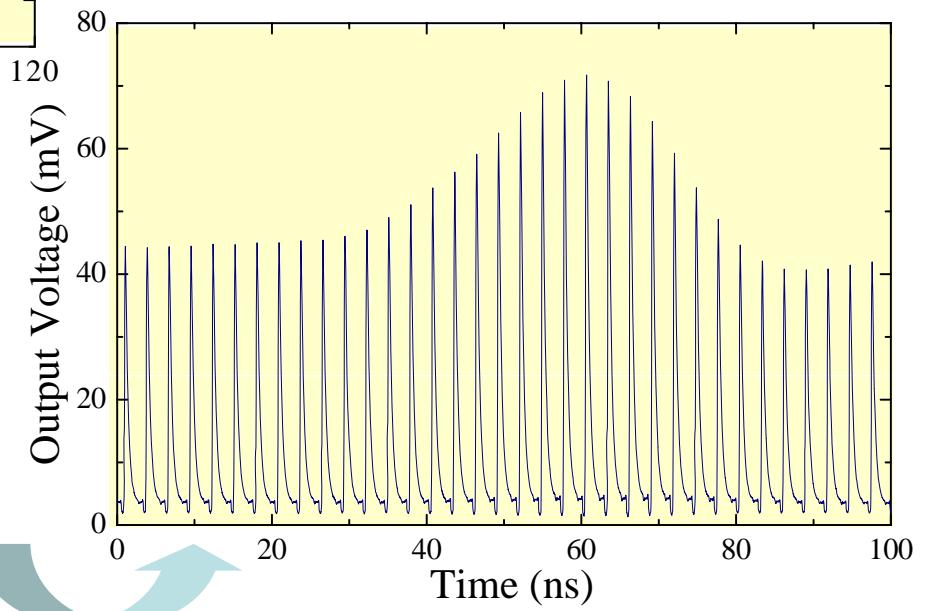
**Application to synchrotron machine diagnostics
(e.g., LURE, ESRF)**



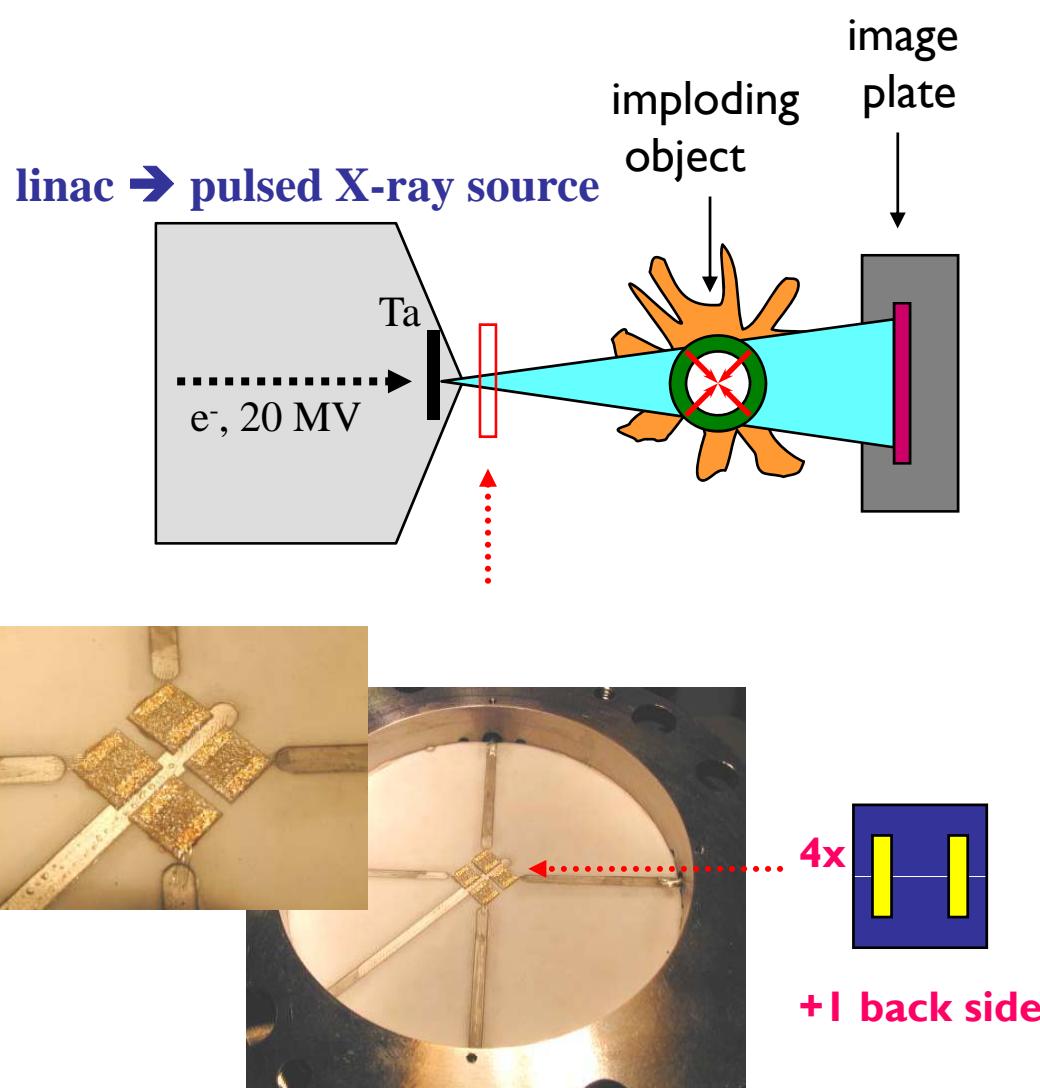
Bunch temporal distribution



ESRF (2/3rd filling)
BM5
White light
Device Temperature > 170°C



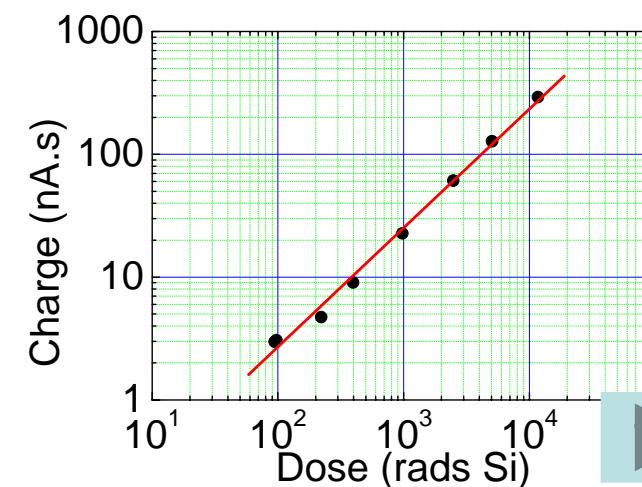
Flash X-Ray radiography diagnosis tool (defence)



AIRIX (Accélérateur à Induction de Radiographie pour l'Imagerie X)

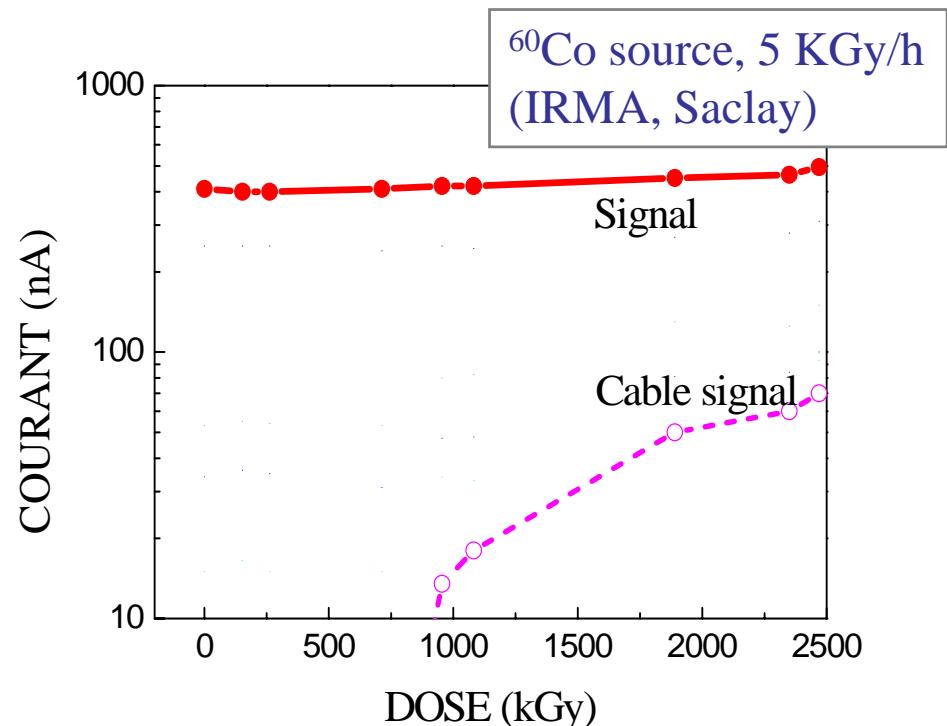
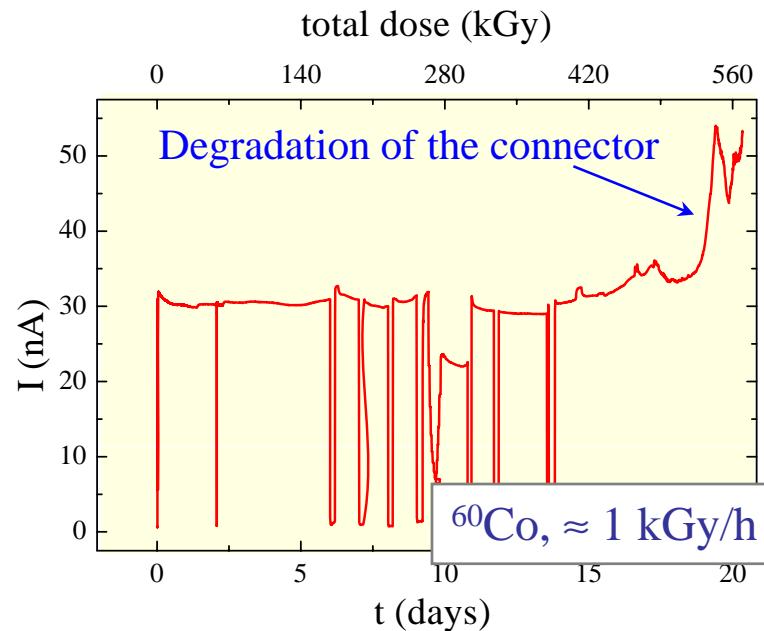
Demanding specifications

- typ. \approx 1 MeV
- Dose (< 5 krad (Si)/flash)
- Duration : typ. 50ns FWHM
- 500 shots / yr / 15 yrs (> 15Mrad)
- Resilient (EMC and shock 10g)
- High transmission (< 0.1 g/cm² (W))



Radiation Hardness

Dose measurements under γ photons

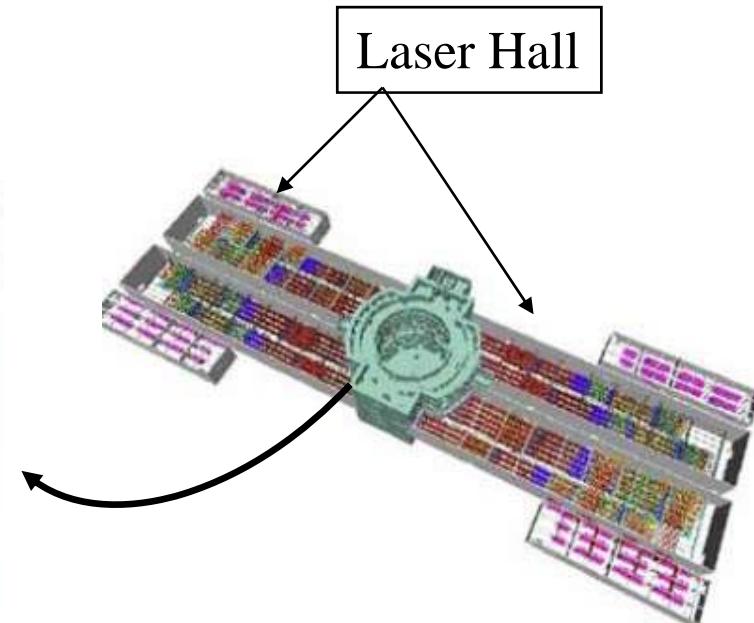
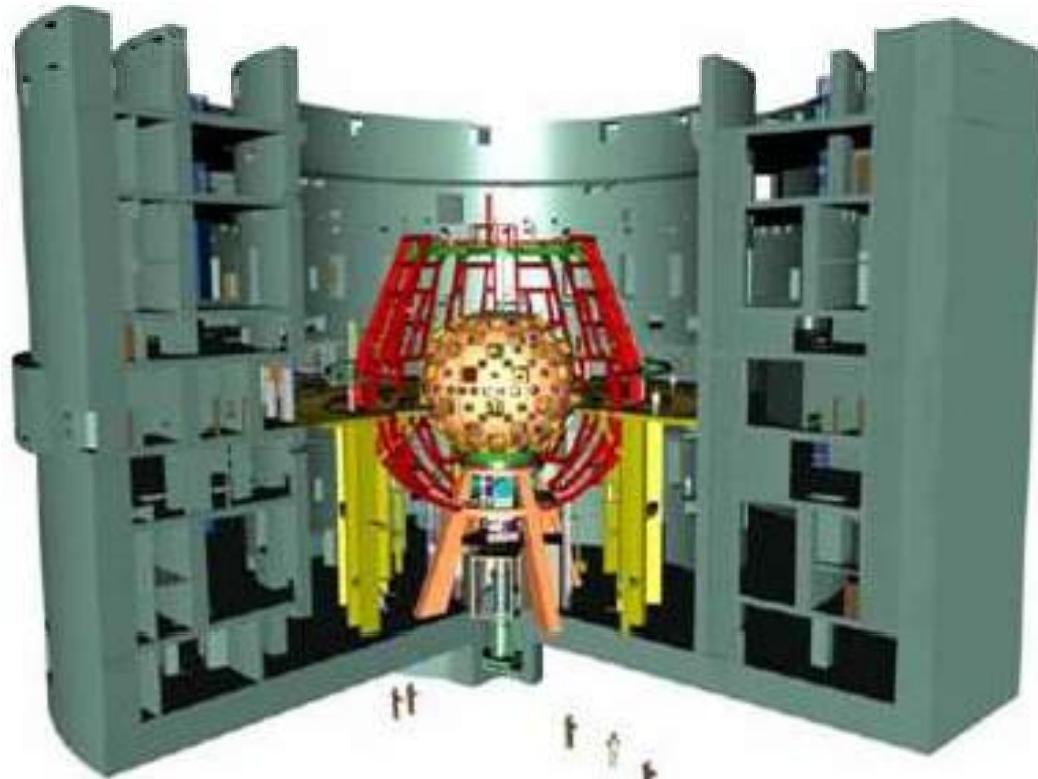


- Stable device response
- altered by cable degradation

No degradation of the detector signal after
a 2,5 MGy integrated dose



- First experiment in 2011



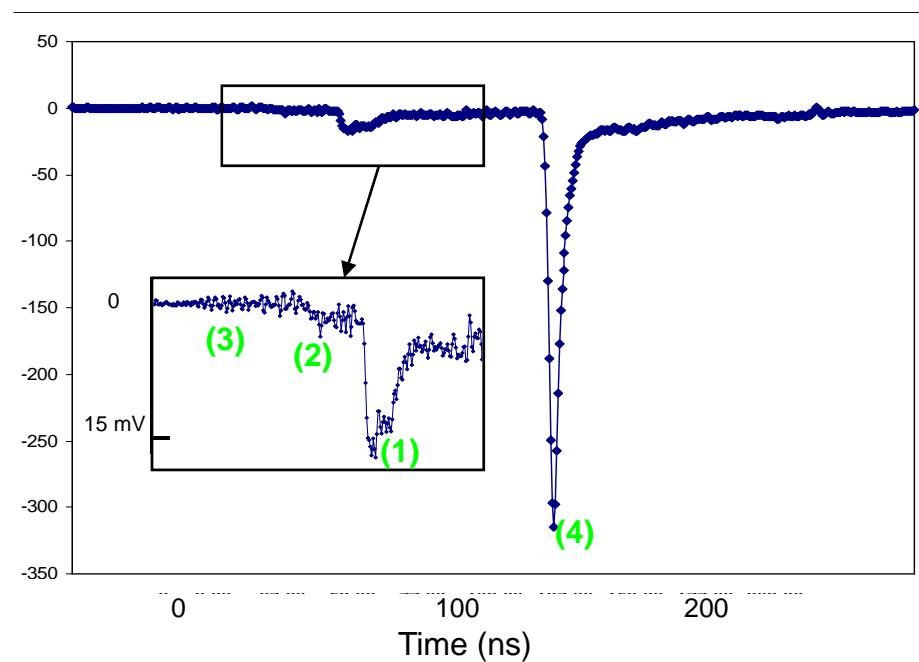
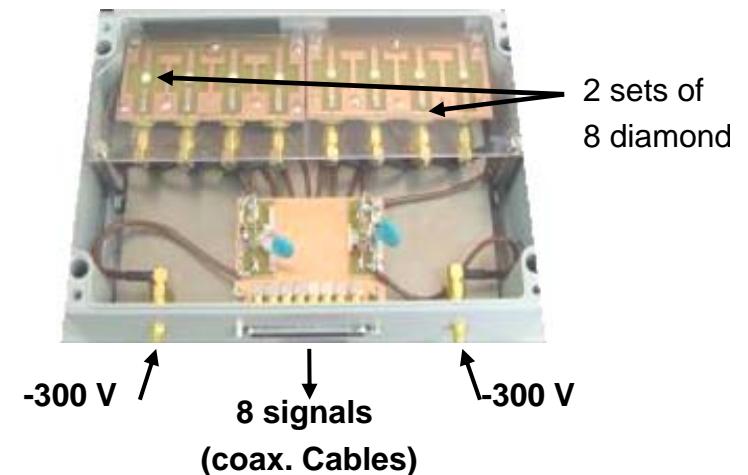
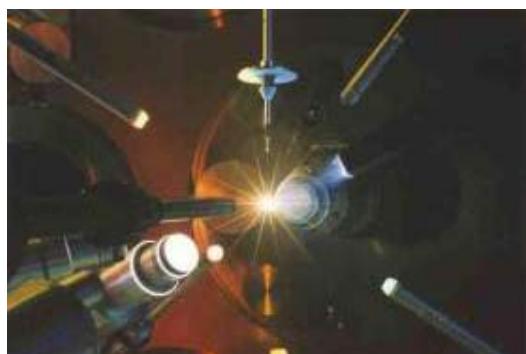
Plasma de fusion par confinement
e.g. $(D,T) \rightarrow n$ (14MeV)

Fast Neutrons

- Based on the ^{12}C (n, α) → high n/γ selectivity
- For n time of flight measurement

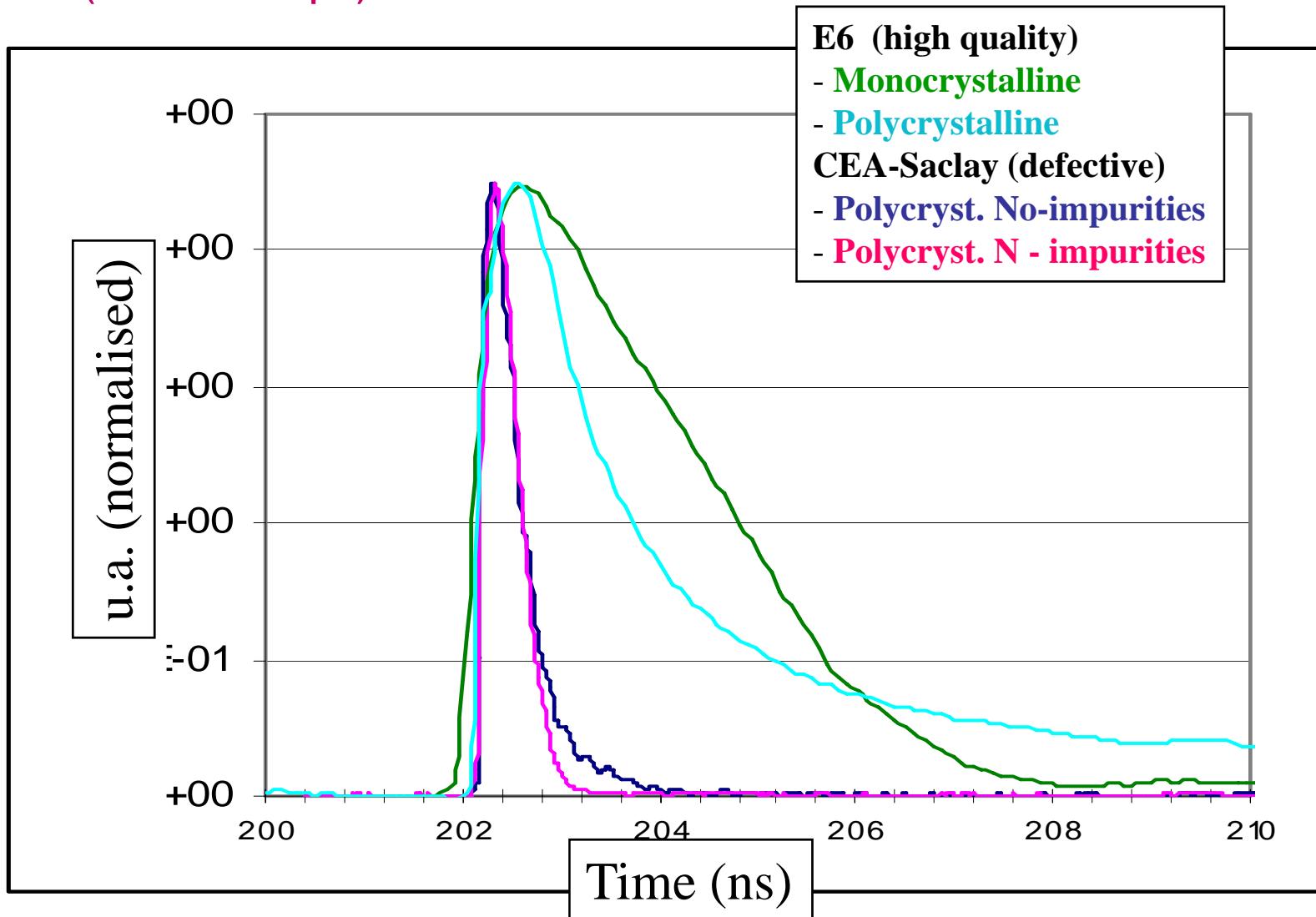


*Rochester (30kJ<1ns)



Response to fast 16 MeV electron pulses

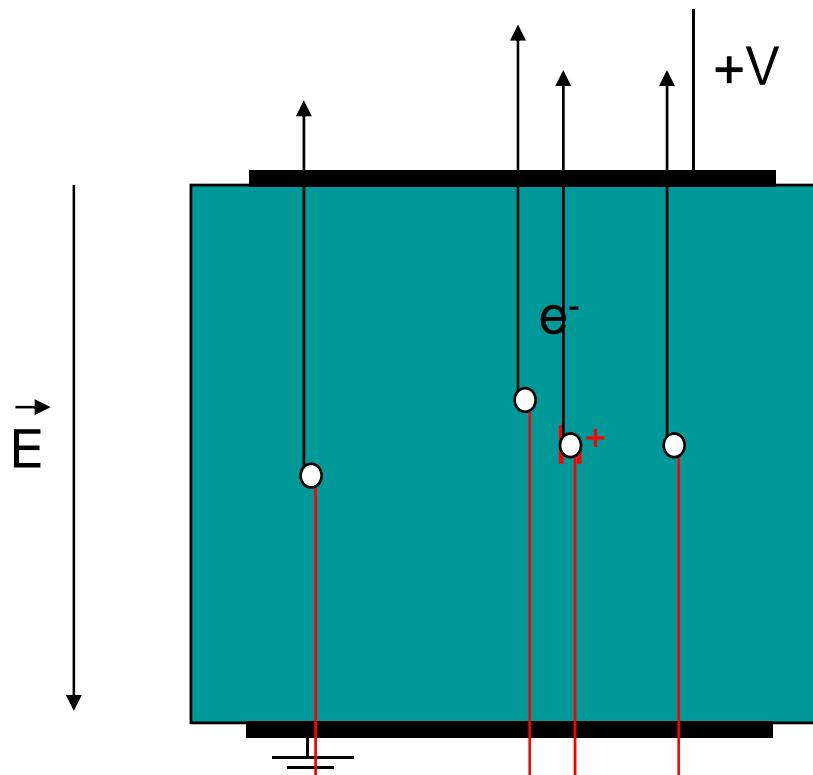
(FWHM=40ps)



"Carriers transiting through the device must do it quickly ! "

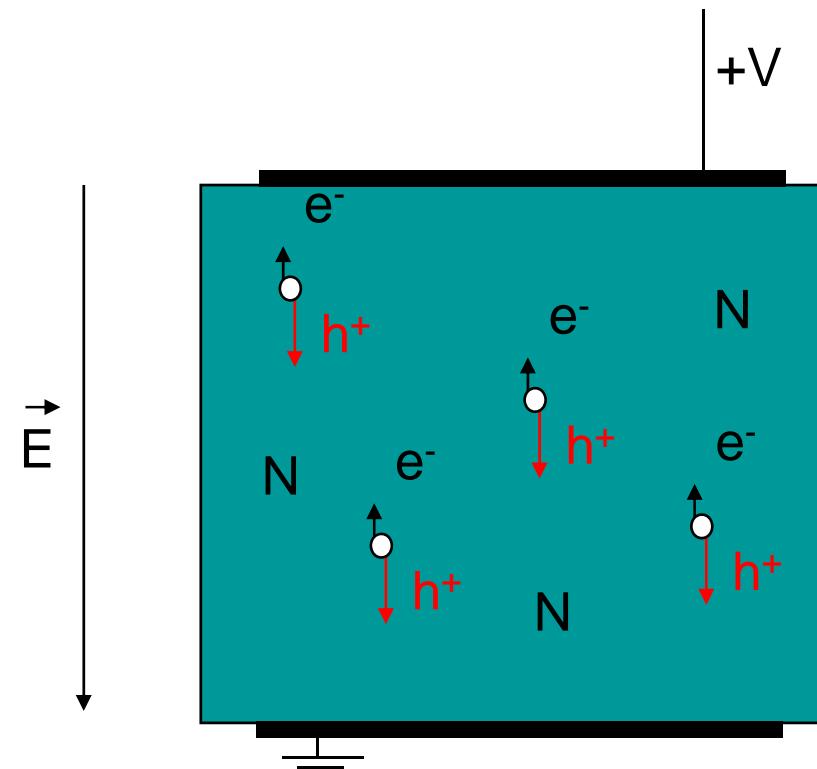
2 ways :

Get the carriers out !



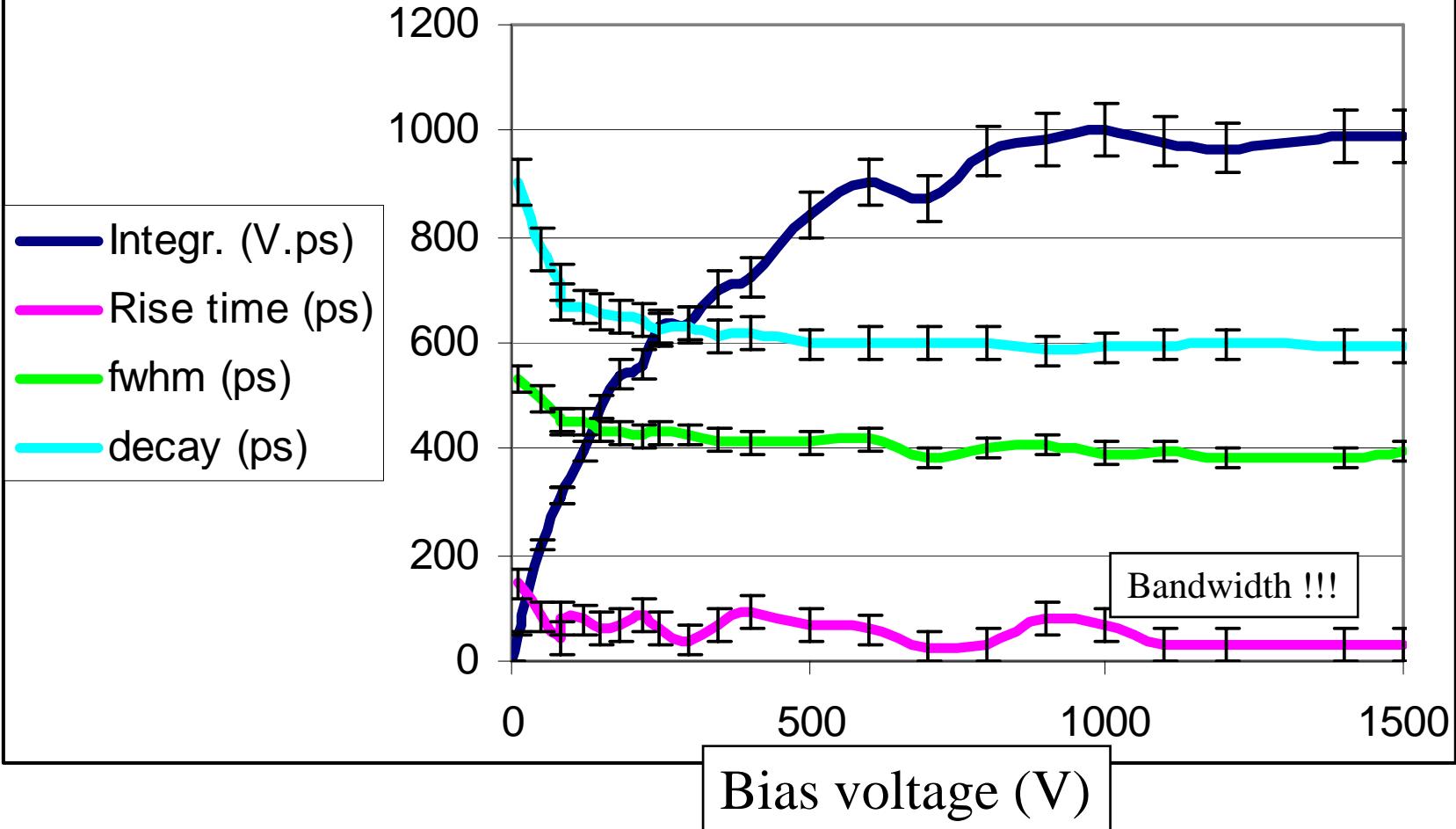
→ high drift distances @ high fields ?

Kill the carriers !



→ Nitrogen = recombination centre

Polycrystalline structure with N impurities



Conclusions

👉 Detectors :

- Controlling the material characteristics with respect to the growth conditions is necessary for radiation detector fabrication
- Pre-optimisation of the devices is necessary
(defects priming, impurities etc)

👉 Devices readily available for extreme hostile environments and few specific applications :

- for neutron detection in the core of nuclear reactors
- for alpha activity monitoring in acids
- for ultra-fast pulse monitoring

👉 Indeed : performances of SC unmatched by polyX materials
But still size and availability remains challenging

Partners and collaborators...

Applications



Growth and material characterisation



Project partners ... etc

